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Author and Subject Index

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Author Index (Vol. 114, 1967)

Aboaf, J. A. Deposition and Properties of Aluminum Oxide Obtained by Pyrolytic Decomposition of an Aluminum Alkoxide, 948

Aia, M. A. Structure and Luminescence of the Phosphate-Vanadates of Yttrium, Gadolinium, Lutetium, and Lanthanum, 367

Structure and Stoichiometry of Nickel Hydroxides in Sintered Nickel Positive Electrodes, 418

Akiyama, Akitane, *et al.* Theory of Organic Corrosion Inhibitors, II. Electrochemical Characteristics of Iron in Acidic Solutions Containing Ring-Substituted Anilines, 1006

Albon, N., *et al.* Growth Mechanism of Vapor Deposited Germanium Films, 102

Albright, L. F., and Davitt, H. J. Fuel Cell Oxidation of Hydrogen on Movable, Partially Submerged Platinum Anodes, 531

Alexander, E. G., *et al.* Behavior of Large-Scale Surface Perturbations during Silicon Epitaxial Growth, 1154

Allen, B. C., and Ownby, P. D. (d), 1269

Allen, F. G., *et al.* Studies of Sodium in SiO_2 Films by Neutron Activation and Radiotracer Techniques, 662

Allendorf, H. D., and Rosner, D. E. Kinetics of the Attack of High-Temperature Molybdenum and Tungsten by Atomic Oxygen, 305

Almaula, Satish, and Austin, L. G. Experimental Study of the Mode of Operation of Porous Gas-Diffusion Electrodes with Hydrogen Fuel, 927

Alwitt, R. S. Anodic Oxidation of Aluminum in the Presence of a Hydrated Oxide, 843

Andersen, T. N., *et al.* Cation Effects on the Potentials of Zero Charge of Gold, Silver, and Mercury Electrodes, 72

Pressure Effects on the Electrical Properties of Polycrystalline Boron, 805

Angell, C. A. Fundamental Limitations on the Low-Temperature Operation of Electrolytic Devices, 1033

Antill, J. E., and Warburton, J. B. Oxidation of Nickel by Carbon Dioxide, 1215

Arad, Y., *et al.* Hydrodimerization of Acrylonitrile, 899

Austin, L. G., and Almaula, Satish. Experimental Study of the Mode of Operation of Porous Gas-Diffusion Electrodes with Hydrogen Fuel, 927

Avella, F. J. Cathodoluminescence of Terbium-Activated Indium Orthoborate (d), 652

Avella, F. J., *et al.* Rare Earth Cathodoluminescence in $InBO_3$ and Related Orthoborates, 613

Aven, M., and Garwacki, W. Ohmic Electrical Contacts to P-Type ZnTe and $ZnSe_xTe_{1-x}$, 1063

Baizer, M. M., and Petrovich, J. P. Electrolytic Reductive Coupling. XV. Electroreductions of Aqueous Concentrated Solutions of Diethyl Maleate in the Presence of Sodium or Tetraethylammonium Cations, 1023

Baizer, M. M., and Wagenknecht, J. H. Electrochemical Reduction of Cyanoalkyldimethylsulfonium Ions, 1095

Baker, C. T., and Trachtenberg, Isaac. Conductivity of KOH and KOH-ZnO Electrolytes from 36° to −66°C, 1045

Banks, Ephraim, and Gashurov, Gleb. Role of Copper in the Transformation of Hexagonal Zinc Sulfide, 1143

Banter, J. C. Incorporation of Ions in Anodic Oxide Films on Zirconium and Their Effect on Film Behavior, 508

Barber, H. D., and Heasell, E. L. Metallic Etching of Indium Antimonide and Germanium, 635

Barnartt, Sidney, and Johnson, C. A. On the Ratio Method of Analysis of Potentiostatic Current-Time Curves for Planar Electrodes, 1256

Barradas, R. G., and Valeriote, E. M. L. Improvement of a Square-Wave Technique for Capacitance Measurements, 593

Bartholomew, R. F., and Kozlowski, T. R. Solvent Properties of Molten $NaNO_2$ Using a Freezing Point Technique, 937

Bartlett, H. E., and Johnson, K. E. Cathode Processes in Molten Nitrates and Nitrites, 64

Electrochemical Studies in Molten Li_2CO_3-Na_2CO_3, 457

Bartlett, R. W. Platinum Oxidation Kinetics with Convective Diffusion and Surface Reaction, 547

Bartlett, R. W., *et al.* Influence of Carbon Transport Kinetics on Solution Growth of β-Silicon Carbide Crystals, 1149

Bates, H. E., and Weinstein Martin. Solidification of Bi_2Te_3 and Its Solid Solutions with Bi_2Se_3 and Sb_2Te_3 under the Influence of Ultrasonic Agitation, 259

Baukus, J., *et al.* Studies of the Defect Structure of Nonstoichiometric Rutile, TiO_{2-x}, 172

Bean, K. E., and Gleim, P. S. Some Properties of Vapor Deposited SiC, 1158

Bean, K. E., *et al.* Some Properties of Vapor Deposited Silicon Nitride Films Using the SiH_4-NH_3-H_2 System, 733

Bechtoldt, C. J. *et al.* Electron Diffraction Studies of Active, Passive, and Transpassive Oxide Films Formed on Iron, 994

Beck, T. R. Stress Corrosion Cracking of Titanium Alloys, I. Ti:8-1-1 Alloy Aqueous Solutions, 551

Beer, S. Z. Extraction of III-V Intermetallic Compounds from Metallic Matrices, 634

Behr, B., *et al.* (d), 1263

Beltzer, M. Low-Temperature Intermediate pH Fuel Cell Electrolytes, 1200

BenDaniel, D. J., and Will, F. G. Effect of Hydrogen Absorbed by Electrode and Electrolyte on Hydrogen Coverage, 909; (d) 916; Rebuttal, 1271

Berkeley, J. F., *et al.* Vapor Deposition of Tungsten by Hydrogen Reduction of Tungsten Hexafluoride; Process Variables and Properties of the Deposit, 561

Berkowitz-Mattuck, J. B. High-Temperature Oxidation, IV. Zirconium and Hafnium Carbides, 1030

Bernard, W. J. Charge-Discharge Mechanisms in Electrolytic Capacitors, (d), 648

Bezirjian, O. H., *et al.* Pressure Effects on the Electrical Properties of Polycrystalline Boron, 805

Bhaskara Rao, M. L. Electrochemical Studies on Lead in Organic Electrolytes, 665

Formation and Discharge of Copper Chloride in an Organic Electrolyte, 13

Bidwell, L. R. Free Energy of Formation of Cupric Oxide, 30

Biedermann, E. Travelling Solvent Defects on Silicon Wafers, 207

Biegler, T. Area Changes of a Smooth Platinum Electrode, 1261

Biegler, T., and Koch, D. F. A. Adsorption and Oxidation of Methanol on a Platinum Electrode, 904; (c), 1221

Biery, J. C. Surface Tensions of Co-Ce and Pu-Co-Ce Alloys as Determined from Frozen Menisci, 225; (d), 1269

Bikerman, J. J. (d), 651

Black, J. F. Occurrence and Identification of Precipitates in Zinc-Diffused GaAs, 1292

Black, J. F., and Jungbluth, E. D. Decorated Dislocations and Sub-Surface Defects Induced in GaAs by the In-Diffusion of Zinc, 188

Precipitates Induced in GaAs by the In-Diffusion of Zinc, 181; Addendum, 297

Blasse, G., and Bril, A. Fluorescence of Eu^{3+}-Activated Garnets Containing Pentavalent Vanadium, 250

Fluorescence of Rhodium-Activated Aluminum Oxide, 1306

Blasse, G., and de Vries, J. On the Eu^{3+} Fluorescence of Mixed Metal Oxides, VI. Temperature Dependence of the Fluorescence, 875

Blum, S. E. Source of Elemental Iodine for Vapor Transport Studies, 639

Blum, S. E., *et al.* Preparation and Properties of Large, Solution Grown GaP Crystals, 1303

Blumenthal, R. N., *et al.* Studies of the Defect Structure of Nonstoichiometric Rutile, TiO_{2-x}, 172

Boardman, P. J., *et al.* Penetration of Electrophoretic Deposits into Cylindrical Tubes, 445

Bockris, J. O'M., *et al.* Mechanism of Oxygen Reduction at Platinum in Alkaline Solutions with Special Reference to H_2O_2, 1107

Permeation of Electrolytic Hydrogen through Platinum (d), 650

Role of Hydrogen Peroxide in Oxygen Reduction at Platinum in H_2SO_4 Solution, 466

Bode, D. D., Jr., *et al.* Cation Effects on the Potentials of Zero Charge of Gold, Silver, and Mercury Electrodes, 72

Boden, David, *et al.* Alkaline Manganese Dioxide Electrode, I. The Discharge Process, 415

Bogenschütz, A. F., *et al.* Activation Energies in the Chemical Etching of Semiconductors in HNO_3-HF-CH_3COOH, 970

Boggs, W. E., *et al.*, Effects of Crystallographic Orientation and Oxygen Pressure on the Oxidation of Iron, 32

Bogren, E. C., *et al.* Mixed Conduction in $Zr_{0.85}$ $Ca_{0.15}$ $O_{1.85}$ and $Th_{0.85}$ $Y_{0.15}$ $O_{1.925}$ Solid Electrolytes, 752

Borrello, S. R., and Cronin, G. R. Epitaxial InAs on InAs Substrates, 1078

Bowman, D., and Kamath, G. S. Preparation and Properties of Epitaxial Gallium Phosphide, 192

Boyd, D. R., *et al.* Printable Insulated-Gate Field-Effect Transistors, 96

Bracht, W. R., and Sullivan, M. V. Chemical Polishing of Cadmium Sulfide, 295

Bradley, W. W., and Uhlig, H. H. Effect of Heating Single Crystal Copper in H_2 and N_2 on Thin-Film Oxidation Kinetics, 669

Breitenstein, A. M., and Cairns, E. J. Kinetics of Propane Adsorption on Platinum in Hydrofluoric Acid, 764

Transport of Hydrogen to Cylindrical Anodes in Stirred Electrolytes, 349

Breiter, M. W. Electrochemical Formation and Dissolution of Different Types of Copper Layers on Platinum, 1125

Brenner, Abner, and Sligh, J. L. Galvanostalametry: A Technique for Chemical Analysis, 461

Brenner, Abner, *et al.* Determination of the Composition of Complexes and Their Instability Constant by Calorimetry, II. The Complex in Fused Potassium Chloride and Cadmium Chloride, 131

Vapor Deposition of Tungsten by Hydrogen Reduction of Tungsten Hexafluoride; Process Variables and Properties of the Deposit, 561

Bril, A., and Blasse, G. Fluorescence of Eu^{3+}-Activated Garnets Containing Pentavalent Vanadium, 250

Fluorescence of Rhodium-Activated Aluminum Oxide, 1306

Bril, A., and Wanmaker, W. L. (d), 652

Brixner, L. H. Fluorescence and Cathodoluminescence of Eu^{+3} in Some Alkali and Alkaline Earths-Yttrates and Gadolinates as Hosts, 252

Segregation Coefficients of the Rare Earth Niobates in $CaMoO_4$, 108

(c) Correction

(d) Discussion

(ed) Editorial

Pages in Each Issue (Vol. 114, 1967)

Month	Technical Pages	Non-technical Pages
January	1-112	1C-16C
February	113-208	17C-32C
March	209-298	33C-90C
April	299-414	91C-110C
May	415-530	111C-130C
June	531-654	131C-150C
July	655-762	151C-174C
August	763-880	175C-228C
September	881-978	229C-250C
October	979-1082	251C-268C
November	1085-1194	269C-286C
December	1195-1314	287C-310C

Brock, A. J., *et al.*, Anodic Oxidation of Alloys, 145
Brook, P. A., *et al.* Anodic Dissolution of Electrodeposited Nickel, 821
Brouwer, G. Control of the Surface Potential of Germanium by Means of a Variable pH Electrolyte Containing Hydrogen Peroxide and Potassium Chloride, 743
Brown, D. M., *et al.* New Masking Technique for Semiconductor Processing, 730
Brown, J. J. Manganese-Activated Luminescence in the $MgO-Al_2O_3-Ga_2O_3$ System, 245
Brown, R., and Rockett, J. A. Performance of Flooded Porous Fuel Cell Electrodes (*d*), 650
Bruins, P. F., and Wallace, R. A. Fused-Acetamide Thermal Cells, 212
Fused-Organic Electrolytes for Thermal Cells, 209
Brummer, K. D. N. Hydrogen Evolution on Single Crystal GaAs Electrodes, 1274
Bubar, S. F., and Vermilyea, D. A. Deformation of Passive Films, 882
Buchanan, E. B., Jr., and Seago, J. L. Metal Membrane Electrodes, 595
Buck, T. M., *et al.* Studies of Sodium in SiO_2 Films by Neutron Activation and Radiotracer Techniques, 862
Burkhardt, P. J. Tracer Evaluation of Hydrogen in Steam-Grown SiO_2 Films, 196
Burmeister, R. A., Jr., and Stevenson, D. A. Phase Equilibria in the Cd-Se System, 394
Burrows, Brian, *et al.* Impurity Effects in the Pre-Electrolysis of Caustic Electrolytes, 1104
Busen, K. M., and Shaw, E. R. Macroscopic Defects in Epitaxial Silicon, 872

Cagnina, S. F., and Snow, E. H. Properties of Gold Doped MOS Structures, 1165
Cairns, E. J., and Breitenstein, A. M. Kinetics of Propane Adsorption on Platinum in Hydrofluoric Acid, 764
Transport of Hydrogen to Cylindrical Anodes in Stirred Electrolytes, 349
Cairns, E. J., and McInerney, E. J. High Activity Platinum Electrocatalysts for the Direct Anodic Oxidation of Saturated Hydrocarbons, 980
Calvert, J. P., and Kruger, Jerome. Ellipsometric-Potentiostatic Studies of Iron Passivity, I. Anodic Film Growth in Slightly Basic Solutions, 43; (*d*), 1265
Cannon, W. A., and Toy, M. S. Nitrosyl Fluoride Electrolytes, 940
Cante, C. J., *et al.* Mechanism of the Absorption Induced Electrode Potential Cells, I. Nature of the Potential, 319
Carruthers, J. R. Radial Solute Segregation in Czochralski Growth, 959
Temperature Oscillations in Czochralski Crystal Growth, 1077
Cartledge, G. H. Noncathodic Effects of the Permanganate Ion in the Anodic Passivation of Iron, 39
Casey, H. C., Jr. Investigation of Inhomogeneities in GaAs by Electron-Beam Excitation, 153
Casey, H. C., Jr., and Kaiser, R. H. Analysis of N-Type GaAs with Electron-Beam-Excited Radiative Recombination, 149
Casey, J. J., *et al.* Chemical Vapor Deposition of Mo onto Si, 201
Cathey, L., and Smith, P. K. Preparation and Electrical Resistance of Single Crystals β-US_2, 973
Catlin, Avery, and Matthews, D. B. Electrochemical Aspects of the Interaction Between Materials and Blood, 221
Cauge, T. P. *et al.* Preparation and Properties of Thin Film Silicon-Nitrogen Compounds Produced by a Radio Frequency Glow Discharge Reaction, 713
Chen, W. H., and Chen, W. S. Impurity Redistribution in a Semiconductor during Thermal Oxidation, 1297
Chen, W. S., and Chen, W. H. Impurity Redistribution in a Semiconductor during Thermal Oxidation, 1297
Chiang, Ping-Wang, *et al.* Phase Diagram of the Pseudo-Binary System Ag_2Te-In_2Te_3 and Semiconducting Properties of $AgIn_5Te_{14}$, 759
Chiang, Y. S., *et al.* Vapor Grown SiAs Crystals, 761
Chu, T. L., and Gruber, G. A. Large Area Silicon Junctions by Epitaxial Growth Technique, 522
Chu, T. L., *et al.* Preparation and Properties of Amorphous Silicon Nitride Films, 717
Cline, J. E., and Schwartz, S. Determination of the Thickness of Aluminum on Silicon by X-Ray Fluorescence, 605
Cohen, M., and Markovac, V. Anodic Deposition of Iron Oxide Films on Iron, 674
Anodic Deposition of Iron Oxide Films on Platinum, 678
Collins, F. C., and Nakayama, T. Transport Processes in the Thermal Growth of Metal and Semiconductor Oxide Films, 167
Collins, F. C., and Schrager, M. Cationic Migration in Silicon Dioxide Films on Silicon, 624
Condit, R. H., *et al.* Nuclear Activation Technique for Detecting Nitrogen-15 Tracer in Solids, 1100
Connolly, J. F., *et al.* Recrystallization of Supported Platinum, 241
Conrad, R. W., *et al.* Preparation of Epitaxial $Ga_xIn_{1-x}As$, 164
Coriell, S. R., *et al.* Calculation of Currents of Local Galvanic Cells, 782
Cowgill, M. G., and Smeltzer, W. W. Oxidation Properties of a Zirconium-2.7 w/o Niobium Alloy in the Temperature Range 300°-500°C, 1089
Craig, S. E., Jr., *et al.* Behavior of Large-Scale Surface Perturbations during Silicon Epitaxial Growth, 1154
Cronin, G. R., and Borrello, S. R. Epitaxial InAs on InAs Substrates, 1078
Cusano, D. A., and Potter, R. M. Luminescence Efficiency of Silicon Carbide Doped with Boron and Nitrogen, 848

Daley, H. O., Jr., *et al.* Thermal Temperature Coefficient of the Calomel Electrode Potential between 0° and 70°C, I. Experimental Results in Aqueous Potassium, Sodium, Lithium, Calcium Chlorides and in Hydrochloric Acid, 578
Dalton, J. V., *et al.* Studies of Sodium in SiO_2 Films by Neutron Activation and Radiotracer Techniques, 862
D'Amico, J., and Lehovec, K. Kinetics of Tantalum Corrosion in Aqueous Electrolytes, I. 363; II. 495
Damjanovic, A., and Wong, M. K. Y. On the Mechanism of Oyxgen Evolution at Iridium Electrodes, 592
Damjanovic, A., *et al.* Mechanism of Oxygen Reduction at Platinum in Alkaline Solutions with Special Reference to H_2O_2, 1107
Role of Hydrogen Peroxide in Oxygen Reduction at Platinum in H_2SO_4 Solution, 466
Datta, R. K. Bismuth in Yttrium Vanadate and Yttrium Europium Vanadate Phosphors, 1057
Luminescent Behavior of Bismuth in Rare-Earth Oxides, 1137
Davis, R. J. Oxide Growth and Capacitance on Preirradiated Zircaloy-2 and Zirconium, 124
Davitt, H. J., and Albright, L. F. Fuel Cell Oxidation of Hydrogen on Movable, Partially Submerged Platinum Anodes, 531
Dayal, Y., *et al.* Peroxide Etching of Germanium, 88
Deal, B. E. *et al.* Characteristics of the Surface-State Charge (Q_{ss}) of Thermally Oxidized Silicon, 266
de Bethune, A. J., *et al.* Thermal Temperature Coefficient of the Calomel Electrode Potential between 0° and 70°C, I. Experimental Results in Aqueous Potassium, Sodium, Lithium, Calcium Chlorides and in Hydrochloric Acid, 578
Dekker, A., *et al.* (*d*) 648
Delahay, Paul. Recollections and Reflections (Palladium Medal Address), 293C
Delaney, R. A., and Kaiser, H. D. Polycrystalline Zinc Oxide Dielectrics, 833
Deng, E., *et al.* Anodic Dissolution of Cadmium, 424
Dennis, J., and Henisch, H. K. Nucleation and Growth of Crystals in Gels, 263
de Vries, J., and Blasse, G. On the Eu^{3+} Fluorescence of Mixed Metal Oxides. VI. Temperature Dependence of the Fluorescence, 875
DeWit, David, *et al.* Silver Oxide Electrode Processes, 1196
Dey, A. N. Electrochemical Studies on the Effect of Water in Nonaqueous Electrolytes, 823
Diefenderfer, A. J., and Rogers, L. B. Polarographic Reductions of Benzyl Halides. A Correction, 942
Dignam, M. J. and Huggins, D. A. Kinetic Study of the Heterogeneous Reactions of Metallic Sodium with Chlorine and Bromine, 117
Dirkse, T. P., *et al.* Silver Oxide Electrode Processes, 1196
Distéche, A., and Distéche, S. Effect of Pressure on the Dissociation of Carbonic Acid from Measurements with Buffered Glass Electrode Cells, The Effects of NaCl,KCl,Mg^{++},Ca^{++},$SO_4^{=}$, and of Boric Acid with Special Reference to Sea Water, 330
Distéche, S., and Distéche, A. Effect of Pressure on the Dissociation of Carbonic Acid from Measurements with Buffered Glass Electrode Cells, The Effects of NaCl,KCl,Mg^{++},Ca^{++},$SO_4^{=}$, and of Boric Acid With Special Reference to Sea Water, 330
Donahue, F. M., and Nobe, Ken. Consecutive Electrode Reactions in the Dissolution Kinetics of Iron, 682
Theory of Organic Corrosion Inhibitors, III. LFER Correlation of Inhibition of Armco Iron by Ring-Substituted Anilines, 1012
Donahue, F. M., *et al.* Theory of Organic Corrosion Inhibitors, II. Electrochemical Characteristics of Iron in Acidic Solutions Containing Ring-Substituted Anilines, 1006
Doty, W. R., and Riley, B. J. Study of the Inclusion of a Radioactive Addition Agent in Bright Nickel, 50
Draley, J. E., and Mori, Shiro. Oxide Dissolution and Its Effect on the Corrosion of 1100 Aluminum in Water at 70°C, 352
Draley, J. E., *et al.* Corrosion of 1100 Aluminum in Water from 50° to 95°C, 353
Low-Pressure Oxidation of Zirconium, 1086
Dubpernell, G. (*d*), 650
Dumin, D. J. Epitaxial Growth of Germanium on Single Crystal Spinel, 749

Earl, W. B., and Hagyard, T. Potential of Aluminum in Aqueous Chloride Solutions, 694
Elliott, G. R. B., and Lemons, J. F. Activities of Molten Tin Alloys from EMF Measurements, 935
Engeler, W. E., *et al.* New Masking Technique for Semiconductor Processing, 730
Ensanian, Minas. Electrochemical and Related Phenomena under Weightless Conditions, I. Flowing Electrolyte Thermocells, 1243
Evans, B., and Pasternak, R. A. Adsorption, Absorption, and Degassing in the Oxygen-Niobium System at Very Low Pressure, 452
Evans, S., and Keller, R. Low-Temperature Battery System Study Using a Mixture of HF and N_2O_4, 655
Eyring, H., *et al.* Cation Effects on the Potentials of Zero Charge of Gold, Silver, and Mercury Electrodes, 72
Pressure Effects on the Electrical Properties of Polycrystalline Boron, 805

Faeth, P. A. Effect of Various Optical Radiations and Water Vapor on the Trapping Spectrum of CdS, 511
Faita, G., *et al.* Standard Potentials of the Cl_2/Cl^- Electrode at Various Temperatures with Related Thermodynamic Functions, 340
Faktor, M. M., *et al.* Preliminary Study of the Chemical Polishing of α-Corundum Surfaces with Vanadium Pentoxide, 356
Faletti, D. W., and Gackstetter, M. A. On the Electrolytic Conductivity of Electrolytes Simulating Those Found in Silver Chloride-Magnesium, Sea Water Activated Batteries, 299
Faust, J. W., Jr., *et al.* Twin Configurations in FCC Dendrites, 1311
Ferguson, J. M., *et al.* Substructures in Oxide Scales on Nickel, Cobalt, and Nickel-Cobalt Alloys, 535
Feucht, D. L., *et al.* Ohmic Contacts to GaAs by a Simple Low Temperature Alloying Process, 408
Fiddyment, D. G., *et al.* Preliminary Study of the Chemical Polishing of α-Corundum Surfaces with Vanadium Pentoxide, 356
Finne, R. M., and Klein, D. L. Water-Amine-Complexing Agent System for Etching Silicon, 965
Fischer, D. F., and Schnizlein, J. G. Kinetics of Oxidation of Plutonium Metal and a Plutonium-3.4 a/o Aluminum Alloy at Temperatures from 140° to 550°C, 23

Flannery, R. J., *et al.* Recrystallization of Supported Platinum, 241

Foley, C. L. *et al.* Electron Diffraction Studies of Active, Passive, and Transpassive Oxide Films Formed on Iron, 994

Foster, L. M., *et al.* Preparation and Properties of Large, Solution Grown GaP Crystals, 1303

France, W. D., Jr. Specimen Holder for Precise Electrochemical Polarization Measurements on Metal Sheets and Foils. 818

Frankenthal, R. P. On the Passivity of Iron-Chromium Alloys. I. Reversible Primary Passivation and Secondary Film Formation, 542

Franklin, T. C. (d), 648

Franklin, T. C., and Hudson, P. E. Absorption of Electrolytic Hydrogen by Nickel and Iron-Nickel Alloys, 568

Fujii, C. T., and Meussner, R. A. Carburization of Fe-Cr Alloys During Oxidation in Dry Carbon Dioxide, 435

Fullenwider, M. A., *et al.* Permeation of Electrolytic Hydrogen through Platinum, (d), 650

Fuller, C. S., and Wolfstirn, K. B. Electrical and Transport Properties of Cu in InAs, 856

Gackstetter, M. A., and Faletti, D. W. On the Electrolytic Conductivity of Electrolytes Simulating Those Found in Silver Chloride-Magnesium, Sea Water Activated Batteries, 299

Garfinkel, M., *et al.* New Masking Technique for Semiconductor Processing, 730

Garnache, R. R., *et al.* Chemical Vapor Deposition of Mo onto Si, 201

Garwacki, W. Ohmic Electrical Contacts to P-Type ZnTe and $ZnSe_xTe_{1-x}$, 1063

Gashurov, Gleb, and Banks, Ephraim. Role of Copper in the Transformation of Hexagonal Zinc Sulfide, 1143

Gashurov, Gleb, and Levine, A. K. Low-Temperature Synthesis of Manganese Activated Zinc Silicate of Superior Crystallinity, 378

Gatos, H. C. (ed) Electronic Materials Here and in the USSR, 253C

Our Society's Name, 155C

A Technical Society Must Not Grow Old, 135C

Gatos, H. C., and Witt, A. F. Determination of Microscopic Rates of Growth in Single Crystals, 413

Gatos, H. C., *et al.* Impurity Distribution in Single Crystals, III. Impurity Heterogeneities in Single Crystals Rotated during Pulling from the Melt, 738

Genshaw, M. A., *et al.* Mechanism of Oxygen Reduction at Platinum in Alkaline Solutions with Special Reference to H_2O_2, 1107

Role of Hydrogen Peroxide in Oxygen Reduction at Platinum in H_2SO_4 Solution, 466

Gileadi, E., *et al.* Permeation of Electrolytic Hydrogen through Platinum, (d), 650

Gilfrich, J. V., *et al.* Chemical Polish That Reveals Compositional Variations in $PbSe_{(1-x)}Te_x$, 632

Gillooly, G. R., *et al.* Stoichiometry of Luminescent Apatites, 956

Gleim, P. S., and Bean, K. E. Some Properties of Vapor Deposited SiC, 1158

Gleim, P. S., *et al.* Some Properties of Vapor Deposited Silicon Nitride Films Using the SiH_4-NH_3-H_2 System, 733

Gnanamuthu, D. S., and Petrocelli, J. V. Generalized Expression for the Tafel Slope and the Kinetics of Oxygen Reduction on Noble Metals and Alloys, 1036

Godard, H. P. Oxide Film Growth over Five Years on Some Aluminum Sheet Alloys in Air of Varying Humidity at Room Temperature, 354

Greene, G. W., *et al.* Annealing Behavior of Fine-Grained Nickel Electrodeposits, 449

Gregor, L. V., and Hu, S. M. Silicon Nitride Films by Reactive Sputtering, 826

Grieveson, P., and Turkdogan, E. T. Kinetics of Nitrogen Transfer through an Iron Surface, 59

Griffith, P. G., and Peebles, J. R. Lumped Parameter Electrical Model for Predicting Concentration Transients in a Reversible Transference Cell, 917

Grove, A. S. *et al.* Characteristics of the Surface-State Charge (Q_{ss}) of Thermally Oxidized Silicon, 266

Grubb, W. T., and Lazarus, M. E. Carbon Dioxide Determination during the Galvanostatic Oxidation of Adsorbed Propane Intermediates, 360

Gruber, G. A., and Chu, T. L. Large Area Silicon Junctions by Epitaxial Growth Technique, 522

Gruber, G. A., *et al.* Preparation and Properties of Amorphous Silicon Nitride Films, 717

Gulbransen, E. A., and Tallman, R. L. Crystal Morphology and Mechanisms of Growth of Alpha-Fe_2O_3 Whiskers on Iron, 1227

Gutmann, F., *et al.* Solid-State Electrochemical Cells Based on Charge Transfer Complexes, 323

Haas, W., *et al.* Vapor Grown SiAs Crystals, 761

Hagyard, T., and Earl, W. B. Potential of Aluminum in Aqueous Chloride Solutions, 694

Halden, F. A., *et al.* Influence of Carbon Transport Kinetics on Solution Growth of β-Silicon Carbide Crystals, 1149

Hampson, N. A., and Larkin, D. Double Layer Capacitance in Aqueous Solution, II. Polycrystalline Cadmium, 933; (c), 1099

Hampson, N. A., *et al.* Double Layer Capacitance in Aqueous Solution, I. Polycrystalline Silver, 817

Handy, R. M., and Scala, L. C. Electrical and Structural Properties of Langmuir Films, (d), 646

Haneman, D., and Russell, G. J. Vacuum Thermal Etching of Germanium and Silicon Surfaces, 398

Haradome, Miyoshi, and Kawashima, Hirokuni. (Cd,Zn)S Photoconductive Sintered Layer, 1072

Harrell, S. A., *et al.* Measurement of the Retention of Fluoride by Silicon and Silicon Dioxide Surfaces, 867

Harrison, J. A., *et al.* Some Problems in Electrodeposition, (d), 1263

Harvey, W. W. Gallium Arsenide Electrode Behavior, 472

Hashimoto, Norikazu, and Koga, Yasushi. Si-WSi_2-Si Epitaxial Structure. 1189

Hauser, J. R., and Wortman, J. J. (d), 1313

Hauser, V. E., and van Gelder, W. Etching of Silicon Nitride in Phosphoric Acid with Silicon Dioxide as a Mark, 869

Heasell, E. L., and Barber, H. D. Metallic Etching of Indium Antimonide and Germanium, 635

Hed, A. Z., and Tannhauser, D. S. Contribution to the Mn-O Phase Diagram at High Temperature, 314

Heijenbrok, M. G. J., *et al.* (d), 648

Heine, M. A., and Pryor, M. J. Passivation of Aluminum by Chromate Solutions, 1001

Heinen, K. G., *et al.* Measurement of the Retention of Fluoride by Silicon and Silicon Dioxide Surfaces, 867

Hemmat, Naim, and Weinstein, Martin. Closed System Vapor Growth of Bulk CdS Crystals from the Elemental Constituents, 851

Growth of CdS from Liquid Cd Solution, 403

Henisch, H. K., and Dennis, J. Nucleation and Growth of Crystals in Gels, 263

Hermann, A. M., *et al.* Solid-State Electrochemical Cells Based on Charge Transfer Complexes, 323

Heumann, F. K., *et al.* New Masking Technique for Semiconductor Processing, 730

Heunisch, G. W. Closed Tube Apparatus for the Deposition of Silicon Oxide, 642

Hillman, E. E., *et al.* Photovoltaic Behavior of the TCNE-THF Solution Charge-Transfer Complex, 1054

Hillner, E. Further Observations on the Oxidation of Zirconium in Dry Oxygen, 237

Hills, G. J., and Kinnibrugh, D. R. Pressure Coefficients of the Hydrogen Electrode Reaction, (d), 651

Himes, R. C., *et al.* Growth Mechanism of Vapor Deposited Germanium Films, 102

Himmel, Lawrence, *et al.* Nuclear Activation Technique for Detecting Nitrogen-15 Tracer in Solids, 1100

Hintermann, H. E., *et al.* DTA and X-ray Studies of Electroless Nickel, 442

Hirthe, W. M., *et al.* Studies of the Defect Structure of Nonstoichiometric Rutile, TiO_{2-x}, 172

Holmstrom, R., and Oldham, W. G. Growth and Etching of Si through Windows in SiO_2, 381

Holt, J. B., *et al.* Nuclear Activation Technique for Detecting Nitrogen-15 Tracer in Solids, 1100

Holt, M. L., and Voltz, R. E. Electrodeposition of Tc^{99} from Aqueous Solution, 128

Horn, F. H. Evaluation of Electronic Grade Silicon and Trichlorosilane by a Frozen Drop Method, 1307

Horowitz, H. H. (d), 650

Houston, Bland, *et al.* Chemical Polish That Reveals Compositional Variations in $PbSe_{(1-x)}Te_x$, 632

Hoyt, P. L., *et al.* Preparation of Epitaxial $Ga_xIn_{1-x}As$, 164

Hu, S. M., and Gregor, L. V. Silicon Nitride Films by Reactive Sputtering, 826

Hu, S. M., and Kerr, D. R. Observation of Etching of n-Type Silicon in Aqueous HF Solutions, 414

Hudson, P. E., and Franklin, T. C. Absorption of Electrolytic Hydrogen by Nickel and Iron-Nickel Alloys, 568

Huggins, D. A., and Dignam, M. J. Kinetic Study of the Heterogeneous Reactions of Metallic Sodium with Chlorine and Bromine, 117

Hunter, J. W., *et al.* Stoichiometry of Luminescent Apatites, 956

Hwang, S. T., and Parravano, G. Transient Response of Chemically Interacting Solid-Gas Systems, I. Theoretical Considerations, 478; II. Reduction Oxidation Reactions on Cobalt Ferrite, 482

Ibl, N., and Schadegg, K. Surface Roughness Effects in the Electrodeposition of Copper in the Limiting Current Range, 54; (d), 1267

Imaizumi, Rikizo, *et al.* Method of Growing CuCl Single Crystals with Flux, 388; (d), 1314

Ing, S. W., Jr., *et al.* Vapor Grown SiAs Crystals, 761

Jadus, D. K., *et al.* Ohmic Contacts to GaAs by a Simple Low Temperature Alloying Process, 408

Jaffe, H. (d), 1314

James, S. D. Electrochemical Activation of Platinum Electrodes, 1113

Use of Nonlinear Circuits for the Acquisition of Electrode Kinetic Data, 1129

James, W. J., *et al.* Anodic Dissolution of Cadmium, 424

Anodic Dissolution of Zinc in Potassium Nitrate, 885

Mechanism of the Electrooxidation of Acetylene on Gold, 572

Jasinski, Raymond, and Malachesky, Paul. Performance of a Silver-Gold (10%) Alloy in a Concentrated Caustic Electrolyte, 1258

Performance of Silver-Palladium Alloys in a Concentrated Caustic Electrolyte, 1239

Jasinski, Raymond, *et al.* Impurity Effects in the Pre-Electrolysis of Caustic Electrolytes, 1104

Javet, Philippe, and Nanis, Leonard. Overpotential-Time Variation for Galvanostatic Charging with Potential Dependent Capacitance, 810

Jenkins, D. B. *et al.* Anodic Dissolution of Electrodeposited Nickel, 821

Jennings, T. A., *et al.* Gas Phase Anodization of Tantalum, 1134

Johnson, C. A., and Barnartt, Sidney. On the Ratio Method of Analysis of Potentiostatic Current-Time Curves for Planar Electrodes, 1256

Johnson, J. W., *et al.* Anodic Dissolution of Cadmium, 424

Mechanism of the Electrooxidation of Acetylene on Gold, 572

Johnson, K. E., and Bartlett, H. E. Cathode Processes in Molten Nitrates and Nitrites, 64

Electrochemical Studies in Molten Li_2CO_3-Na_2CO_3, 457

Jones, Shannon. (d), 647

Jorgensen, P. J. Comments on the Paper "Transport Processes in the Thermal Oxidation of Silicon," 820

Jungbluth, E. D., and Black, J. F. Decorated Dislocations and Sub-Surface Defects Induced in GaAs by the In-Diffusion of Zinc, 188

Precipitates Induced in GaAs by the In-Diffusion of Zinc, 181; Addendum, 297

Kachik, R. H., *et al.* Effects of Crystallographic Orientation and Oxygen Pressure on the Oxidation of Iron, 32

Kahan, Daniel, *et al.* Twin Configurations in FCC Dendrites, 1311

Kaiser, H. D., and Delaney, R. A. Polycrystalline Zinc Oxide Dielectrics, 833

Kaiser, R. H., and Casey, H. C., Jr. Analysis of N-Type GaAs with Electron-Beam-Excited Radiative Recombination, 149

Kaldis, E., *et al.* Cd_4SiS_6 and Cd_4SiSe_6. New Ternary Compounds; Synthesis, Photoconductive and Fluorescent Properties, 1074

Kamath, G. S., and Bowman, D. Preparation and Properties of Epitaxial Gallium Phosphide, 192

Kampwirth, R., *et al.* Peroxide Etching of Germanium, 88

Kassner, T. F. Rate of Solution of Rotating Tantalum Disks in Liquid Tin, 689

Kawashima, Hirokuni, and Haradome, Miyoshi. (Cd,Zn)S Photoconductive Sintered Layer, 1072

Keir, D. S., *et al.* Galvanic Corrosion Characteristics of Aluminum Alloyed with Group IV Metals, 777

Keller, R., and Evans, S. Low-Temperature Battery System Study Using a Mixture of HF and N_2O_4, 655

Kemula, W., *et al.* (d), 1263

Kennedy, D. T., and Russ, M. J. Effects of Double Insulating Layers on the Electroluminescence of Evaporated ZnS:Mn Films, 1066

Kerr, D. R., and Hu, S. M. Observation of Etching of n-Type Silicon in Aqueous HF Solutions, 414

Khoo, S. W. *et al.* Anodic Oxidation of Alloys, 145

King, C. V. (*ed*). Brief Communications, 5C

Naming of Names, 21C

Kinnibrugh, D. R., and Hills, G. J. Pressure Coefficients of the Hydrogen Electrode Reaction, (d), 651

Klein, D. L., and Finne, R. M. Water-Amine-Complexing Agent System for Etching Silicon, 965

Kober, F. P. Infrared Spectroscopic Investigation of Charged Nickel Hydroxide Electrodes, 215

Koch, D. F. A., and Biegler, T. Adsorption and Oxidation of Methanol on a Platinum Electrode, 904; (c), 1221

Koga, Yasushi, and Hashimoto, Norikazu. Si-WSi_2-Si Epitaxial Structure, 1189

Kondo, Yoshihiro, *et al.* Method of Growing CuCl Single Crystals with Flux, 388; (d), 1314

Kozlowski, T. R., and Bartholomew, R. F. Solvent Properties of Molten $NaNO_2$ Using a Freezing Point Techniques, 937

Kraitchman, J., and Oroshnik, J. Anodic Oxide Growth Behavior on Silicon, 405

Kraus, Herbert, *et al.* $Cd_xHg_{1-x}Te$ Films by Cathodic Sputtering, 616

Krausbauer, L., *et al.* Cd_4SiS_6 and Cd_4SiSe_6, New Ternary Compounds; Synthesis, Photoconductive and Fluorescent Properties, 1074

Krebs, W. M., and Roe, D. K. Investigations of Electrocrystallization at Silver Electrodes, 892

Kronick, P. L., *et al.* Photovoltaic Behavior of the TCNE-THF Solution Charge-Transfer Complex, 1054

Kruger, Jerome, and Calvert, J. P. Ellipsometric-Potentiostatic Studies of Iron Passivity, I. Anodic Film Growth in Slightly Basic Solutions, 43; (d), 1265

Kruger, Jerome, and Yolken, H. T. Thermal Regeneration of Oxide Covered Iron {100} and {110} Surfaces, 796

Kruger, J. *et al.* Electron Diffraction Studies of Active, Passive, and Transpassive Oxide Films Formed on Iron, 994

Krumme, J. P., *et al.* Thermal Expansion Coefficients and Lattice Parameters between 10° and 65°C in the System GaP-GaAs, 640

Krusemark, W., *et al.* Activation Energies in the Chemical Etching of Semiconductors in HNO_3-HF-CH_3COOH, 970

Lai, S. C., *et al.* Anodic Dissolution of Cadmium, 424

Langelan, H. C. and Shepherd, C. M. High Rate Battery Electrodes, 8

Langer, A., and Patton, J. T. Coulogravimetric Study of the Sintered Silver Electrode in 1 Molar Potassium Hydroxide, 113

Larkin, D., and Hampson, N. A. Double Layer Capacitance in Aqueous Solution, II. Polycrystalline Cadmium, 933; (c), 1099

Larkin, D., *et al.* Double Layer Capacitance in Aqueous Solution, I. Polycrystalline Silver, 817

Larrabee, G. B., *et al.* Measurement of the Retention of Fluoride by Silicon and Silicon Dioxide Surfaces, 867

Lassota, D. T., and Moest, R. R. Carrier-Concentration Profiles of N-Type Sn and Te Doped Epitaxial GaAs Films, 110

Lazarus, M. E., and Grubb, W. T. Carbon Dioxide Determination during the Galvanostatic Oxidation of Adsorbed Propane Intermediates, 360

Leach, J. S. L., and Saunders, S. R. J. Some Aspects of the Mechanism of Hydrogen Evolution at a Mild Steel Electrode, (d), 648

Lee, C. H., *et al.* Preparation and Properties of Amorphous Silicon Nitride Films, 717

Lee, W. T., and Munir, Z. A. Torsion-Effusion and Torsion-Langmuir Studies of Zinc Telluride, 1236

Legat, W. H., and Russell, L. K. Physical Description of the Anisotropic Stress Effect in the Silicon P-N Junction Cantilever Transducer, 277; (d), 1313

Lehmann, W. Emission Spectra of Impurity Activated (ZnCd) (S, Se, Te) Phosphors, III. Self-Activated Phosphors, 83

Lehovec, K., and D'Amico, J. Kinetics of Tantalum Corrosion in Aqueous Electrolytes, I. 363; II. 495

Lemons, J. F., and Elliott, G. R. B. Activities of Molten Tin Alloys from EMF Measurements, 935

Levine, A. K., and Gashurov, Gleb. Low-Temperature Synthesis of Manganese Activated Zinc Silicate of Superior Crystallinity, 378

Levine, H. A., *et al.* Wettability Measurements on Rough, High-Energy Surfaces, 877

Levitan, J., *et al.* Low-Pressure Oxidation of Zirconium, 1086

Levitt, R. S., and Zwicker, W. K. Infrared Spectra of Silicon Nitride Deposited on Gallium Arsenide, 1192

Levy, M., *et al.* Hydrodimerization of Acrylonitrile, 899

Lizlovs, E. A. Mechanism of the Corrosion Inhibition of Stainless Steel in Sulfuric Acid by Sodium Molybdophosphate, 1015

Löcherer, K. H., *et al.* Activation Energies in the Chemical Etching of Semiconductors in HNO_3-HF-CH_3COOH, 970

Loess, R. E. and Youngdahl, C. A. Instrumentation for Potentiostatic Corrosion Studies in Distilled Water, 489

Loess, R. E., *et al.* Corrosion of 1100 Aluminum in Water from 50° to 95°C, 353

Longhi, P., *et al.* Standard Potentials of the Cl_2/Cl^- Electrode at Various Temperatures with Related Thermodynamic Functions, 340

Loud, N. A. S., *et al.* Thermal Temperature Coefficient of the Calomel Electrode Potential between 0° and 70°C, I. Experimental Results in Aqueous Potassium, Sodium, Lithium, Calcium Chlorides and in Hydrochloric Acid, 578

Lovrecek, B., and Markovac, V. Studies of the Electrochemical Kinetics of Indium, III. Systems In + $InCl_3$ and In + Combined Sulfate-Chloride Electrolyte, (d), 1263

Lussow, R. O., *et al.* Wettability Measurements on Rough, High-Energy Surfaces, 877

Maget, H. J. R., and Roethlein, R. J. Oxygen Reduction on a Partially Immersed Rotating Platinum Cathode, 1043

Maire, P. A., *et al.* DTA and X-ray Studies of Electroless Nickel, 442

Malachesky, Paul, and Jasinski, Raymond. Performance of a Silver-Gold (10%) Alloy in a Concentrated Caustic Electrolyte, 1258

Performance of Silver-Palladium Alloys in a Concentrated Caustic Electrolyte, 1239

Malachesky, Paul, *et al.* Impurity Effects in Pre-Electrolysis of Caustic Electrolytes, 1104

Manasevit H. M., and Morritz, F. L. Gas Phase Etching of Sapphire with Sulfur Fluorides, 204

Markby, R. E., *et al.* Electrochemical Reduction of Aromatic Hydrocarbons in Ethylenediamine, (c), 1119

Markovac, V., and Cohen, M. Anodic Deposition of Iron Oxide Films on Iron, 674

Anodic Deposition of Iron Oxide Films on Platinum, 678

Markovac, V., and Lovrecek, B. Studies of the Electrochemical Kinetics of Indium, III. Systems In + $InCl_3$ and In + Combined Sulfate-Chloride Electrolyte, (d), 1263

Martin, D. D., *et al.* Preparation of Epitaxial $Ga_xIn_{1-x}As$, 164

Mason, D. R., *et al.* Phase Diagram of the Pseudo-Binary System Ag_2Te-In_2Te_3 and Semiconducting Properties of $AgIn_5Te_{11}$, 759

Mathers, J. E., *et al.* Energy Transfer and Fluorescence Processes in Bi^{3+} and Eu^{3+} Activated YVO_4, 953

Matthews, D. B., and Catlin, Avery. Electrochemical Aspects of the Interaction Between Materials and Blood, 221

Mazur, R. G. Resistivity Inhomogeneities in Silicon Crystals, 255

Mazza, B., *et al.* (d), 652, 1267

McCloskey, J. P. Electrograph Method for Locating Pinholes in Thin Silicon Dioxide Films, 643

McDonald, J. E., and Schroeder, C. F. Adherence and Porosity in Ion Plated Gold, 889

McInerney, E. J., and Cairns, E. J. High Activity Platinum Electrocatalysts for the Direct Anodic Oxidation of Saturated Hydrocarbons, 980

McIntyre, T., *et al.* Electrochemical Reduction of N-p-Nitrobenzylaniline, 588

McIntyre, T. W., and Wawzonek, S. Electrolytic Oxidation of Aromatic Amines, 1025

McLean, J. D., and Timnick, Andrew. Charge-Transfer Coefficients for Aqueous Cd (II) Evaluated by Large Amplitude A-C Polarography, 1130

Large Amplitude A-C Polarography of Aqueous Cd (II), 239

McNeill, W., *et al.* Gas Phase Anodization of Tantalum, 1134

Mehta, R. R., *et al.* Preparation and Properties of Thin Film Silicon-Nitrogen Compounds Produced by a Radio Frequency Glow Discharge Reaction, 713

Meieran, E. S. Reflection X-Ray Topography of GaAs Deposited on Ge, 292

Mellors, G. W., and Senderoff, S. Electrodeposition of Coherent Deposits of Refractory Metals, V. Mechanism for the Deposition of Molybdenum from a Chloride Melt, 556; VI. Mechanism of Deposition of Molybdenum and Tungsten from Fluoride Melts, 586

Metzger, W. H., Jr., *et al.* Determination of the Composition of Complexes and Their Instability Constant by Calorimetry, II. The Complex in Fused Potassium Chloride and Cadmium Chloride, 131

Meussner, R. A., and Fujii, C. T. Carburization of Fe-Cr Alloys During Oxidation in Dry Carbon Dioxide, 435

Meyers, B. L., *et al.* Recrystallization of Supported Platinum, 241

Middelhoek, A., *et al.* (d), 648

Mikus, F. F., *et al.* Energy Transfer and Fluorescence Processes in Bi^{3+} and Eu^{3+} Activated YVO_4, 953

Miller, I. R., *et al.* Hydrodimerization of Acrylonitrile, 899

Mitchell, A. H., and Salomon, R. E. Permeation of Isolated Anodic Zirconium Oxide Films by Potassium Nitrate, 599; (c), 772

Mochel, V. D. Red Emitting Al_2O_3 Based Phosphors, (d), 647

Mochimaru, Fusako, and Takamura, Tsutomu. Catalytic Decomposition and Anodic Current-Potential Characteristics of Methanol on Active Palladium in Alkaline Solution, 1251

Moest, R. R., and Lassota, D. T. Carrier-Concentration Profiles of N-Type Sn and Te Doped Epitaxial GaAs Films, 110

Mohilner, D. M., *et al.* Electrochemical Reduction of Aromatic Hydrocarbons in Ethylenediamine, (c), 1119

Montgomery, K. M., and Wynveen, R. A. Air Depolarized Electrolytic Oxygen Generator, 589

Moore, Charles (*ed*) Why Publish Symposium Proceedings?, 95C

Moore, T. L., *et al.* Thermodynamic Interaction between Zinc and the Dilute Solutes Antimony, Bismuth, and Cadmium in Solution in Liquid Lead, 800

Morgan, Evan, *et al.* Mechanism of the Absorption Induced Electrode Potential Cells, I. Nature of the Potential, 319

Mori, Shiro, and Draley, J. E. Oxide Dissolution and Its Effect on the Corrosion of 1100 Aluminum in Water at 70°C, 352

Mori, Shiro, *et al.* Corrosion of 1100 Aluminum in Water from 50° to 95°C, 353

Morizane, K., *et al.* Impurity Distribution in Single Crystals, III. Impurity Heterogeneities in Single Crystals Rotated during Pulling from the Melt, 738

Morley, J. R., *et al.* Double Layer Capacitance in Aqueous Solution, I. Polycrystalline Silver, 817

Morlotti, R., and Pizzini, S. Thermodynamic and Transport Properties of Stoichiometric and Nonstoichiometric Nickel Oxides, 1179

Morritz, F. L., and Manasevit, H. M. Gas Phase Etching of Sapphire with Sulfur Fluorides, 204

Muller, R. H. Optical Studies of Electrolyte Films on Gas Electrodes, (d), 651

Munir, Z. A., and Lee, W. T. Torsion-Effusion and Torsion-Langmuir Studies of Zinc Telluride, 1236

Mussinger, W., *et al.* Activation Energies in the Chemical Etching of Semiconductors in HNO_3-HF-CH_3COOH, 970

Mussini, T., *et al.* Standard Potentials of the Cl_2/Cl^- Electrode at Various Temperatures with Related Thermodynamic Functions, 340

Naber, C. T. Recrystallization of Germanium Thin Films on Insulating Substrates by Electron Beam Zone Melting, 406

Nakayama, T., and Collins, F. C. Transport Processes in the Thermal Growth of Metal and Semiconductor Oxide Films, 167

Nanis, Leonard, and Javet, Philippe. Overpotential-Time Variation for Galvanostatic Charging with Potential Dependent Capacitance, 810

Nelson, W. E., *et al.* Influence of Carbon Transport Kinetics on Solution Growth of β-Silicon Carbide Crystals, 1149

Newman, John. Diffusion Layer on a Rotating Disk Electrode, 239

Newns, G. R., *et al.* Preliminary Study of the Chemical Polishing of α-Corundum Surfaces with Vanadium Pentoxide, 356

Niedrach, L. W., and Tochner, M. Studies of Hydrocarbon Fuel Cell Anodes by the Multipulse Potentiodynamic Method, III. Behavior of Saturated Hydrocarbons on Conducting Porous Teflon Electrodes with a Phosphoric Acid Electrolyte, 17, (d), 1265; IV. Effect of Various Electrolytes on the Behavior of Hydrocarbons on Conducting Porous Teflon Electrodes, 233

Nobe, Ken, and Donahue, F. M. Consecutive Electrode Reactions in the Dissolution Kinetics of Iron, 682

Theory of Organic Corrosion Inhibitors, III. LFER Correlation of Inhibitors of Armco Iron by Ring-Substituted Anilines, 1012

Nobe, Ken, *et al.* Theory of Organic Corrosion Inhibitors, II. Electrochemical Characteristics of Iron in Acidic Solutions Containing Ring-Substituted Anilines, 1006

Nonaka, Tsutomu, and Sugino, Kiichiro. Electrolytic Reduction of Acrylonitrile to Allylamine, 1255

Norr, M. K., *et al.* Chemical Polish That Reveals Compositional Variations in $PbSe_{(1-x)}Te_x$, 632

Notoya, Takenori, and Sato, Norio. Measurements of the Anodic Oxide Film Growth on Iron for Hours, 585

O'Brien, R. N. Rotating Disk Electrode, Hydrodynamic Boundary and Diffusion Layers by Laser Interferometry, 710

O'Donnell, P. M. Kinetics of the Fluorination of Beryllium, 1206

Kinetics of the Fluorination of Iron, 218

Ogburn, Fielding, *et al.* Calculation of Currents of Local Galvanic Cells, 782

Twin Configurations in FCC Dendrites, 1311

Okabe, Takahiro, *et al.* Method of Growing CuCl Single Crystals with Flux, 388; (d), 1314

Okajima, K., *et al.* Thermodynamic Interaction between Zinc and the Dilute Solutes Antimony, Bismuth, and Cadmium in Solution in Liquid Lead, 800

O'Kane, D. F., *et al.* Phase Diagram of the Pseudo-Binary System Ag_2Te-In_2Te_3 and Semiconducting Properties of $AgIn_5Te_{14}$, 759

Oldham, W. G., and Holmstrom, R. Growth and Etching of Si through Windows in SiO_2, 381

Olsen, D. A., *et al.* Penetration of Electrophoretic Deposits into Cylindrical Tubes, 445

Ong, J. N., Jr. Chemical Notation for Defect Solid State Chemistry, 1080

Onstott, E. I. Polarization at Impervious and Porous Bromine Redox Electrodes, 709

Oroshnik, J., and Kraitchman, J. Anodic Oxide Growth Behavior on Silicon, 405

Otto, E. M. Equilibrium Pressures of Oxygen over Oxides of Lead at Various Temperatures, (d), 647

Ownby, P. D., and Allen, B. C. (d), 1269

Panish, M. B. Ga-P-Te System, 1161

Ternary Condensed Phase Diagram of the Ga-As-Te System, 91

Ternary Condensed Phase Systems of Gallium and Arsenic with Group 1B Elements, 516

Paris, B., *et al.* Growth Mechanism of Vapor Deposited Germanium Films, 102

Parker, S. G., *et al.* $Cd_xHg_{1-x}Te$ Films by Cathodic Sputtering, 616

Printable Insulated-Gate Field-Effect Transistors, 96

Parodi, J. A. Electronic Paramagnetic Resonance Study of the Chemistry of Mn^{++} during the Formation of Fluorapatite, 370

Parravano, G., and Hwang, S. T. Transient Response of Chemically Interacting Solid-Gas Systems, I. Theoretical Considerations, 478; II. Reduction Oxidation Reactions on Cobalt Ferrite, 482

Pasternak, R. A., and Evans, B. Adsorption, Absorption, and Degassing in the Oxygen-Niobium System at Very Low Pressure, 452

Patterson, J. W., *et al.* Mixed Conduction in $Zr_{0.85}Ca_{0.15}O_{1.85}$ and $Th_{0.85}Y_{0.15}O_{1.925}$ Solid Electrolytes, 752

Patton, J. T., and Langer, A. Coulogravimetric Study of the Sintered Silver Electrode in 1 Molar Potassium Hydroxide, 113

Pawel, R. E. Effect of Anodic Films on the Gaseous Oxidation of Tantalum, II. Films Formed in Phosphoric Acid Solutions, 1222

Pearson, C., *et al.* Anodic Oxidation of Alloys, 145

Pedeferri, P., *et al.* (d), 652, 1267

Peebles, J. R., and Griffith, P. G. Lumped Parameter Electrical Model for Predicting Concentration Transients in a Reversible Transference Cell, 917

Pehlke, R. D., *et al.* Thermodynamic Interaction between Zinc and the Dilute Solutes Antimony, Bismuth, and Cadmium in Solution in Liquid Lead, 800

Pellissier, G. E., *et al.* Effects of Crystallographic Orientation and Oxygen Pressure on the Oxidation of Iron, 32

Petrocelli, J. V., and Gnanamuthu, D. S. Generalized Expression for the Tafel Slope and the Kinetics of Oxygen Reduction on Noble Metals and Alloys, 1036

Petrovich, J. P., and Baizer, M. M. Electrolytic Reductive Coupling, XV. Electroreductions of Aqueous Concentrated Solutions of Diethyl Maleate in the Presence of Sodium or Tetraethylammonium Cations, 1023

Pickering, H. W., and Wagner, C. Electrolytic Dissolution of Binary Alloys Containing a Noble Metal, 698

Piersma, B. J., *et al.* On the Activity of Platinum Catalysts in Solution, I. Effects of Thermal Treatment and Chemical Etching on the Pt-O/Hydrogen Specific Reaction Rate, 1120

Potentiostatic Current-Potential Measurements on a Platinum Electrode in a High-Purity Closed System, 343

Pink, F., *et al.* Propagation of Growth Striae in GaAs Epitaxial Films, 879

Piontelli, R., *et al.* (d), 652, 1267

Pizzini, S., and Morlotti, R. Thermodynamic and Transport Properties of Stoichiometric and Nonstoichiometric Nickel Oxide, 1179

Plaisance, T. *et al.* Electrochemical Reduction of N-*p*-Nitrobenzylaniline, 588

Plaskett, T. S., *et al.* Preparation and Properties of Large, Solution Grown GaP Crystals, 1303

Pliskin, W. A. Fused Glass Penetration into Thermally Grown Silicon Dioxide Films, 620

Pliskin, W. A., and Valletta, R. M. Preparation and Characterization of Manganese Oxide Thin Films, 944

Poling, G. W. Infrared Studies of Protective Films Formed by Acetylenic Corrosion Inhibitors, 1209

Potter, R. M., and Cusano, D. A. Luminescence Efficiency of Silicon Carbide Doped with Boron and Nitrogen, 848

Prager, Stephen, *et al.* Penetration of Electrophoretic Deposits into Cylindrical Tubes, 445

Prener, J. S. Growth and Crystallographic Properties of Calcium Fluor- and Chlorapatite Crystals, 77

Primak, W., *et al.* Peroxide Etching of Germanium, 88

Pryor, M. J., and Heine, M. A. Passivation of Aluminum by Chromate Solutions, 1001

Pryor, M. J., *et al.* Galvanic Corrosion Characteristics of Aluminum Alloyed with Group IV Metals, 777

Pyle, T., and Roberts, C. (d), 651

Rabatin, J. G., *et al.* Stoichiometry of Luminescent Apatites, 956

Rairden, J. R. Anodic Oxidation of Yttrium Thin Films, 75

Raleigh, D. O. Rapid Solid-Electrochemical Method for Studying High-Temperature Diffusion in Metals, 493

Rand, M. J. Nitric Oxide Process for the Deposition of Silica Films, 274

Randin, J.-P., *et al.* DTA and X-ray Studies of Electroless Nickel, 442

Rangarajan, S. K., *et al.* Some Problems in Electrodeposition, (d), 1236

Rapp, R. A., *et al.* Mixed Conduction in $Zr_{0.85}Ca_{0.15}O_{1.85}$ and $Th_{0.85}Y_{0.15}O_{1.925}$ Solid Electrolytes, 752

Read, H. J. (ed) Are We a Healthy Society?, 115C

Information Required, 37C

Read, H. J. (Presidential Address) The Role of Metallurgy in Electrochemistry, 159C

Reed, J. L., *et al.* Anodic Dissolution of Zinc in Potassium Nitrate, 885

Mechanism of the Electrooxidation of Acetylene on Gold, 572

Reed, M. W., and Schwemer, W. C. Porous Carbon Fuel Cell Electrodes from Polymer Precursors, 582

Reedy, H. E., *et al.* Ohmic Contacts to GaAs by a Simple Low Temperature Alloying Process, 408

Reid, W. E., Jr., *et al.* Vapor Deposition of Tungsten by Hydrogen Reduction of Tungsten Hexafluoride; Process Variables and Properties of the Deposit, 561

Rembaum, A., *et al.* Solid-State Electrochemical Cells Based on Charge Transfer Complexes, 323

Reucroft, P. J., *et al.* Photovoltaic Behavior of the TCNE-THF Solution Charge-Transfer Complex, 1054

Revesz, A. G. Anodic Oxidation of Silicon in KNO_3-N-Methylacetamide Solution: Interface Properties, 629

Reynolds, R. A. Phase Relations and Thermoelectric properties of the Alloy Systems SnTe-Bi_2Te_3 and PbTe-Sb_2Te_3, 526

Reynolds, R. A., *et al.* Phase Equilibria in the Zinc-Tellurium System, 1281

Riggs, B. A. Vacuum-Deposited Thin Films of the Type PbS_xSe_{1-x}, 708

Riley, B. J., and Doty, W. R. Study of the Inclusion of a Radioactive Addition Agent in Bright Nickel, 50

Roberts, C., and Pyle, T. (d), 651

Rockett, J. A., and Brown, R. Performance of Flooded Porous Fuel Cell Electrodes, (d), 650

Roe, D. K., and Krebs, W. M. Investigations of Electrocrystallization at Silver Electrodes, 892

Roethlein, R. J., and Maget, H. J. R. Oxygen Reduction on a Partially Immersed Rotating Platinum Cathode, 1043

Rogers, L. B., and Diefenderfer, A. J. Polarographic Reductions of Benzyl Halides, A Correction, 942

Root, C. G., *et al.* Nonelectrolytic Deposition of Titanium on Columbium Alloys from Fused Salts, 1018

Rosano, H. L., *et al.* Mechanism of the Absorption Induced Electrode Potential Cells, I. Nature of the Potential, 319

Rosner, D. E., and Allendorf, H. D. Kinetics of the Attack of High-Temperature Molybdenum and Tungsten by Atomic Oxygen, 305

Rubenstein, M. Thermal Expansion Coefficients and Lattice Parameters between 10° and 65°C in the System GaP-GaAs, 640

Rüetschi, Paul. Solubility and Diffusion of Hydrogen in Strong Electrolytes and the Generation and Consumption of Hydrogen in Sealed Primary Batteries, 301

Ruff, A. W., Jr., *et al.* Twin Configurations in FCC Dendrites, 1311

Runyan, W. R., *et al.* Behavior of Large-Scale Surface Perturbations during Silicon Epitaxial Growth, 1154

Some Properties of Vapor Deposited Silicon Nitride Films Using the SiH_4-NH_3-H_2 System, 733

Russ, M. J., and Kennedy, D. I. Effects of Double Insulating Layers on the Electroluminescence of Evaporated ZnS:Mn Films, 1066

Russell, G. J., and Haneman, D. Vacuum Thermal Etching of Germanium and Silicon Surfaces, 398

Russell, L. K., and Legat, W. H. Physical Description of the Anisotropic Stress Effect in the Silicon P-N Junction Cantilever Transducer, 277 (*d*), 1313

Sakamoto, Hitoshi. Electroluminescence of Lead-Containing Zinc Sulfide Films, 725

Saleen, M., *et al.* Anodic Dissolution of Electrodeposited Nickel, 821

Salmon, H. I., *et al.* Determination of the Composition of Complexes and Their Instability Constant by Calorimetry, II. The Complex in Fused Potassium Chloride and Cadmium Chloride, 131

Salomon, Mark. Primary and Solvent Isotope Effects in the Anodic Evolution of Oxygen, 922

Salomon, R. E., and Mitchell, A. H. Permeation of Isolated Anodic Zirconium Oxide Films by Potassium Nitrate, 599 (c), 772

Salomon, R. E., *et al.* Gas Phase Anodization of Tantalum, 1134

Salvi, G. R., *et al.* Thermal Temperature Coefficient of the Calomel Electrode Potential between 0° and 70°C, I. Experimental Results in Aqueous Potassium, Sodium, Lithium, Calcium Chlorides and in Hydrochloric Acid, 578

Sato, Norio, and Notoya, Takenori. Measurements of the Anodic Oxide Film Growth on Iron for Hours, 585

Saunders, S. R. J., and Leach, J. S. L. Some Aspects of the Mechanism of Hydrogen Evolution at a Mild Steel Electrode, (d), 648

Saurer, E. *et al.* DTA and X-ray Studies of Electroless Nickel, 442

Scala, L. C., and Handy, R. M. Electrical and Structural Properties of Langmuir Films, (d), 646

Schadegg, K., and Ibl, N. Surface Roughness Effects in the Electrodeposition of Copper in the Limiting Current Range, 54; (d), 1267

Schmidt, P. F., and Wonsidler, D. R. Conversion of Silicon Nitride Films to Anodic SiO_2, 603

Schnizlein, J. G., and Fischer, D. F. Kinetics of Oxidation of Plutonium Metal and a Plutonium-3.4 a/o Aluminum Alloy at Temperatures from 140° to 550°C, 23

Schrager, M., and Collins, F. C. Cationic Migration in Silicon Dioxide Films on Silicon, 624

Schroeder, C. F., and McDonald, J. E. Adherence and Porosity in Ion Plated Gold, 889

Schuldiner, Sigmund, (d), 916

Schuldiner, Sigmund, and Warner, T. B. Rapid Electronic Switching between Potentiostatic and Galvanostatic Control, 359

Schuldiner, Sigmund, *et al.* On the Activity of Platinum Catalysts in Solution, I. Effects of Thermal Treatment and Chemical Etching on the Pt-O/Hydrogen Specific Reaction Rate, 1120

Potentiostatic Current-Potential Measurements on a Platinum Electrode in a High-Purity Closed System, 343

Schwartz, B. Chemical Etching of Germanium in the System HF-H_3O_2-H_2O, 285

Schwartz, S., and Cline, J. E. Determination of the Thickness of Aluminum on Silicon by X-Ray Fluorescence, 605

Schwemer, W. C., and Reed, M. W. Porous Carbon Fuel Cell Electrodes from Polymer Precursors, 582

Sciola, J., *et al.* Propagation of Growth Striae in GaAs Epitaxial Films, 879

Seago, J. L., and Buchanan, E. B., Jr. Metal Membrane Electrodes, 595

Seltzer, M. S., *et al.* Growth Mechanism of Vapor Deposited Germanium Films, 102

Senderoff, S., and Mellors, G. W. Electrodeposition of Coherent Deposits of Refractory Metals, V. Mechanism for the Deposition of Molybdenum from a Chloride Melt, 556; VI. Mechanism of Deposition of Molybdenum and Tungsten from Fluoride Melts, 586

Sharpe, T. F. Application of Ultraviolet Analytical Techniques to Lead Acid Systems, 232

Shaw, E. R., and Busen, K. M. Macroscopic Defects in Epitaxial Silicon, 872

Shepherd, C. M., and Langelan, H. C. High Rate Battery Electrodes, 8

Shoemaker, Richard, *et al.* Silver Oxide Electrode Processes, 1196

Shropshire, J. A. Catalysis of the Electrochemical Oxidation of Formaldehyde and Methanol by Perrhenate, 773 (d), 1265

Sihvonen, Y. T., *et al.* Printable Insulated-Gate Field-Effect Transistors, 96

Simmons, J. A., *et al.* Calculation of Currents of Local Galvanic Cells, 782

Simon, A. C. Stress Corrosion in the Grids of the Lead-Acid Storage Battery, 1

Sklar, M. *et al.* Characteristics of the Surface-State Charge (Q_{ss}) of Thermally Oxidized Silicon, 266

Sligh, J. L., and Brenner, Abner. Galvanostalametry: A Technique for Chemical Analysis, 461

Smeltzer, W. W., and Cowgill, M. G. Oxidation Properties of a Zirconium-2.7 w/o Niobium Alloy in the Temperature Range 300°-500°C, 1089

Smith, J. P., *et al.* $Cd_xHg_{1-x}Te$ Films by Cathodic Sputtering, 616

Smith, P. K., and Cathey, L. Preparation and Electrical Resistance of Single Crystals of β-US_2, 973

Smyth, D. M. Heat-Treatment of Anodic Oxide Films on Tantalum, VI. The Effect of Chemical Thinning, 723

Snow, E. H., and Cagnina, S. F. Properties of Gold Doped MOS Structures, 1165

Snow, E. H., *et al.* Characteristics of the Surface-State Charge (Q_{ss}) of Thermally Oxidized Silicon, 266

Snow, R. J., and Welch, B. J. Repeatability of the Anode Effect in Cryolite-Alumina Melts, (d), 652

Soga, Minoru, *et al.* Metnod of Growing CuCl Single Crystals with Flux, 388; (d), 1314

Sovers, O. J., *et al.* Rare Earth Cathodoluminescence in $InBO_3$ and Related Orthoborates, 613

Sperry, P. R., *et al.* Galvanic Corrosion Characteristics of Aluminum Alloyed with Group IV Metals, 777

Spink, J. A. (d), 646

Steinman, J. B., *et al.* Nonelectrolytic Deposition of Titanium on Columbium Alloys from Fused Salts, 1018

Stern, K. H. Glass-Membrane Potentials in Mixed Anion Melts, 1257

Sternberg, H. W., *et al.* Electrochemical Reduction of Aromatic Hydrocarbons in Ethylenediamine, (c), 1119

Stetson, A. R., *et al.* Nonelectrolytic Deposition of Titanium on Columbium Alloys from Fused Salts, 1018

Stevenson, D. A., and Burmeister, R. A., Jr. Phase Equilibria in the Cd-Se System, 394

Stevenson, D. A., *et al.* Phase Equilibria in the Zinc-Tellurium System, 1281

Stickler, R., and Wolley, E. D. Formation of Precipitates in Gold Diffused Silicon, 1287

Straumanis, M. E., *et al.* Anodic Dissolution of Zinc in Potassium Nitrate, 885

Thermal Expansion Coefficients and Lattice Parameters between 10° and 65°C in the System GaP-GaAs, 640

Stringer, John. Rate-Controlling Processes in the High-Temperature Oxidation of Tantalum, 428

Stroud, D. G., *et al.* Phase Equilibria in the Zinc-Tellurium System, 1281

Struthers, J. D., *et al.* Studies of Sodium in SiO_2 Films by Neutron Activation and Radiotracer Techniques, 862

Sugino, Kiichiro, and Nonaka, Tsutomu. Electrolytic Reduction of Acrylonitrile to Allylamine, 1255

Sugiyama, Kohzoh, *et al.* Chemical Vapor Deposition of Titanium Carbide Coatings on Iron, 1230

Sullivan, M. V., and Bracht, W. R. Chemical Polishing of Cadmium Sulfide, 295

Sumka, H. J., *et al.* Annealing Behavior of Fine-Grained Nickel Electrodeposits, 449

Sunners, Brian. Control of Photoconductive Properties in Cadmium Selenide, 390

Swann, R. C. G., *et al.* Preparation and Properties of Thin Film Silicon-Nitrogen Compounds Produced by a Radio Frequency Glow Discharge Reaction, 713

Swaroop, B., and Wagner, J. B., Jr. Oxidation of Copper and Copper-Gold Alloys in CO_2 at 1000°C, I. Linear Kinetics, 685

Swiggard, E. M. Liquid Encapsulation Zone Refining (LEZOR), 976

Swinkels, D. A. J. Impurity Effects in High Current Density Cl_2 Electrodes, 812

Takahashi, Takehiko, *et al.* Chemical Vapor Deposition of Titanium Carbide Coatings on Iron, 1230

Takamura, Tsutomu, and Mochimaru, Fusako. Catalytic Decomposition and Anodic Current-Potential Characteristics of Methanol on Active Palladium in Alkaline Solution, 1251

Takayanagi, Shigetoshi, and Yoshioka, Satoshi. Deposition of Silicon Nitride Films by the Silane-Hydrazine Process, 962

Tallman, R. L., and Gulbransen, E. A. Crystal Morphology and Mechanisms of Growth of Alpha-Fe_2O_3 Whiskers on Iron, 1227

Tannhauser, D. S., and Hed, A. J. Contribution to the Mn-O Phase Diagram at High Temperature, 314

Taraszewska, J., *et al.* (d), 1263

Taylor, R. C. Epitaxial Deposition of GaAs in an Argon Atmosphere, 410

Tedmon, C. S., Jr. High-Temperature Oxidation of Fe-Cr Alloys in the Composition Range of 25-95% Cr, 788

Terry, L. E., and Williams, J. D. Textural and Electrical Properties of Vacuum-Deposited Germanium Films, 158

Thirsk, H. R., *et al.* Some Problems in Electrodeposition, (d), 1236

Timnick, Andrew, and McLean, J. D. Charge-Transfer Coefficients for Aqueous Cd (II) Evaluated by Large Amplitude A-C Polarography, 1130

Large Amplitude A-C Polarography of Aqueous Cd (II), 239

Tochner, M., and Niedrach, L. W. Studies of Hydrocarbon Fuel Cell Anodes by the Multipulse Potentiodynamic Method, III. Behavior of Saturated Hydrocarbons on Conducting Porous Teflon Electrodes with a Phosphoric Acid Electrolyte, 17, (d), 1265; IV. Effect of Various Electrolytes on the Behavior of Hydrocarbons on Conducting Porous Teflon Electrodes, 233

Toma, S. Z., *et al.* Energy Transfer and Fluorescence Processes in Bi^{3+} and Eu^{3+} Activated YVO_4, 953

Tomita, Kensuke, *et al.* Chemical Vapor Deposition of Titanium Carbide Coatings on Iron, 1230

Toy, M. S. Corrosion Resistance of Platinum, Copper Nickel, and Tantalum in Liquid Oxygen Difluoride, 706

Kolbe Electrosynthesis of Polydifluoromethylene, 1042

Toy, M. S., and Cannon, W. A. Nitrosyl Fluoride Electrolytes, 940

Trachtenberg, Isaac. Paul Delahay: 1967 Palladium Medalist. 291C

Trachtenberg, Isaac, and Baker, C. J. Conductivity of KOH and KOH-ZnO Electrolytes from 36° to −66°C, 1045

Turkdogan, E. T., and Grieveson, P. Kinetics of Nitrogen Transfer through an Iron Surface, 59

Uhlig, H. H. (d), 1265

Uhlig, H. H., and Bradley, W. W. Effect of Heating Single Crystal Copper in H_2 and N_2 on Thin-Film Oxidation Kinetics, 689

Valeriote, E. M. L., and Barradas, R. G. Improvement of a Square-Wave Technique for Capacitance Measurements, 593

Valletta, R. M., and Pliskin, W. A. Preparation and Characterization of Manganese Oxide Thin Films, 944
Valyocsik, E. W. Germanium Oxidation in Nitric Acid, 176
Van Drunen, C. J., *et al.* Low-Pressure Oxidation of Zirconium, 1086
van Gelder, W., and Hauser, V. E. Etching of Silicon Nitride in Phosphoric Acid with Silicon Dioxide as a Mask, 869
Van Uitert, L. G. Characterization of Energy Transfer Interactions between Rare Earth Ions, 1048
Vaszko, B., *et al.* Substructures in Oxide Scales on Nickel, Cobalt, and Nickel-Cobalt Alloys, 535
Venuto, C. J., *et al.* Alkaline Manganese Dioxide Electrode, I. The Discharge Process, 415
Verderber, R. R., *et al.* Chemical Vapor Deposition of Mo onto Si, 201
Vermilyea, D. A., and Bubar, S. F. Deformation of Passive Films, 882
Vofsi, D., *et al.* Hydrodimerization of Acrylonitrile, 899
Voltz, R. E., and Holt, M. L. Electrodeposition of Tc^{99} from Aqueous Solution, 128
Vratny, F. Deposition of Tantalum and Tantalum Oxide by Superimposed RF and D-C Sputterings, 505

Wagenknecht, J. H., and Baizer, M. M. Electrochemical Reduction of Cyanoalkyldimethylsulfonium Ions, 1095
Wagner, C., and Pickering, H. W. Electrolytic Dissolution of Binary Alloys Containing a Noble Metal, 698
Wagner, J. B., Jr., and Swaroop, B. Oxidation of Copper and Copper-Gold Alloys in CO_2 at 1000°C, 685
Wallace, R. A., and Bruins, P. F. Fused-Acetamide Thermal Cells, 212
Fused-Organic Electrolytes for Thermal Cells, 209
Wang, P., *et al.* Propagation of Growth Striae in GaAs Epitaxial Films, 879
Wanmaker, W. L., and Bril, A. (d), 652
Warburton, J. B., and Antill, J. E. Oxidation of Nickel by Carbon Dioxide, 1215
Warner, J. S. Free Energy of Formation of Palladium Oxide, 68
Warner, T. B., and Schuldiner, Sigmund, Rapid Electronic Switching between Potentiostatic and Galvanostatic Control, 359
Warner, T. B., *et al.* On the Activity of Platinum Catalysts in Solution, I. Effects of Thermal Treatment and Chemical Etching on the Pt-O/Hydrogen Specific Reaction Rate, 1120
Potentiostatic Current-Potential Measurements on a Platinum Electrode in a High-Purity Closed System, 343
Warnock, R. V., *et al.* Nonelectrolytic Deposition of Titanium on Columbium Alloys from Fused Salts, 1018
Wawzonek, S., and McIntyre, T. W. Electrolytic Oxidation of Aromatic Amines, 1025
Wawzonek, S. *et al.* Electrochemical Reduction of N-p-Nitrobenzylaniline, 588
Weil, R., *et al.* Annealing Behavior of Fine-Grained Nickel Electrodeposits, 449
Weinstein, Martin, and Bates, H. E. Solidification of Bi_2Te_3 and Its Solid Solutions with Bi_2Se_3 and Sb_2Te_3 under the Influence of Ultrasonic Agitation, 259
Weinstein, Martin, and Hemmat, Naim. Closed System Vapor Growth of Bulk CdS Crystals from the Elemental Constituents, 851
Growth of CdS from Liquid Cd Solution, 403
Weissman, E. Y. Structural Studies of Porous Electrodes, 658; (c), 977
Welch, B. J., and Snow, R. J. Repeatability of the Anode Effect in Cryolite-Alumina Melts, (d), 652
Weller, P. F. Optical Spectra of Ytterbium in CdF_2, 609
Wender, I., *et al.* Electrochemical Reduction of Aromatic Hydrocarbons in Ethylenediamine, (c), 1119
White, W. B. (d), 647
Whittle, D. P., and Wood, G. C. Complex Scale Formation on an Iron-18% Chromium Alloy, 986
Whittle, D. P., *et al.* Substructures in Oxide Scales on Nickel, Cobalt, and Nickel-Cobalt Alloys, 535
Widmer, R., *et al.* Cd_4SiS_6, and Cd_4SiSe_6, New Ternary Compounds; Synthesis, Photoconductive and Fluorescent Properties, 1074
Wiggins, C. S., *et al.* Rare Earth Cathodoluminescence in $InBO_3$ and Related Orthoborates, 613
Will, F. G. Phenomena at an Electrode Covered with an Electrolyte Film, 138
Will, F. G., and BenDaniel, D. J. Effect of Hydrogen Absorbed by Electrode and Electrolyte on Hydrogen Coverage, 909; (d), 916; Rebuttal, 1271
Williams, J. D., and Terry, L. E. Textural and Electrical Properties of Vacuum-Deposited Germanium Films, 158
Williams, Richard. Chemistry and Electrical Properties of the Interface Between ZnSe and an Electrolyte, 1173
Wirtz, L. H., *et al.* Wettability Measurements on Rough, High-Energy Surfaces, 877
Wisler, D., *et al.* Alkaline Manganese Dioxide Electrode, I. The Discharge Process, 415
Witt, A., *et al.* Impurity Distribution in Single Crystals, III. Impurity Heterogeneities in Single Crystals Rotated during Pulling from the Melt, 738
Witt, A. F. Study of Impurity Heterogeneities in InSb by Means of a Permanganate Etchant, 298
Witt, A. F., and Gatos, H. C. Determination of Microscopic Rates of Growth in Single Crystals, 413
Wolfstirn, K. B., and Fuller, C. S. Electrical and Transport Properties of Cu in InAs, 856
Wolley, E. D., and Stickler, R. Formation of Precipitates in Gold Diffused Silicon, 1287
Wong, M. K. Y., and Damjanovic, A. On the Mechanism of Oxygen Evolution at Iridium Electrodes, 592
Wonsidler, D. R., and Schmidt, P. F. Conversion of Silicon Nitride Films to Anodic SiO_2, 603
Wood, G. C., and Whittle, D. P. Complex Scale Formation on an Iron-18% Chromium Alloy, 986
Wood, G. C. *et al.* Anodic Oxidation of Alloys, 145
Substructures in Oxide Scales on Nickel, Cobalt, and Nickel-Cobalt Alloys, 535
Wortman, J. J., and Hauser, J. R. (d), 1313
Wright, G. A. (d), 1263
Wylie, R. B., *et al.* Alkaline Manganese Dioxide Electrode, I. The Discharge Process, 415
Wynveen, R. A., and Montgomery, K. M. Air Depolarized Electrolytic Oxygen Generator, 589

Yeakley, R. L., *et al.* Some Properties of Vapor Deposited Silicon Nitride Films Using the SiH_4-NH_3-H_2 System, 733
Yolken, H. T., and Kruger, Jerome. Thermal Regeneration of Oxide Covered Iron {100} and {110} Surfaces, 796
Yoshioka, Satoshi, and Takayanagi, Shigetoshi. Deposition of Silicon Nitride Films by the Silane-Hydrazine Process, 962
Youngdahl, C. A., and Loess, R. E. Instrumentation for Potentiostatic Corrosion Studies in Distilled Water, 489

Zeliger, H. I. Fuel Cell Performance as a Function of Catalyst Surface Area, 144
New Air Electrode for Fuel Cells, 236
Zwicker, W. K., and Levitt, R. S. Infrared Spectra of Silicon Nitride Deposited on Gallium Arsenide, 1192

Index to Authors of Abstracts of Papers Presented at Society Meetings

Abens, S. G., F'67, 194C
Aboaf, J. A., F'67, 275C
Agosto, William, S'67, 61C
Aia, M. A., S'67, 75C
Ainslie, N., S'67, 142C
Akasaki, I., S'67, 53C, 64C
Alexander, E. G., S'67, 62C, 65C
Ali, S. I., F'67, 200C
Alwitt, R. S., F'67, 204C
Amster, R. L., S'67 , 61C
Anderson, F. P., S'67, 69C
Anderson, J. D., S'67, 67C
Anderson. R. A., F'67, 195C
Andreades, S., S'67, 66C
Ang, Choh-Yi, S'67, 54C
Anton, J. R., S'67, 71C
Aramaki, Kunitsugu, F'67, 201C
Arguello, C., F'67, 207C
Armington, A. F., S'67, 147C
Aronson, B. S., S'67, 144C
Arouete, S., F'67, 196C
Arvia, A. J., F'67, 194C
Asai, Komei, F'67, 195C
Asano, Hidejiro, F'67, 216C
Asch, Georges, F'67, 295C
Aso, M., F'67, 200C
Atkinson, Gordon, F'67, 197C
Atkinson, J. T. N., S'67, 58C
Avella, F. J., S'67, 60C
Axelrod, N. N., S'67, 55C, 59C
Baizer, M. M., S'67, 67C
Baker, J. B., F'67, 203C
Bakish, R., F'67, 205C
Baldi, A. L., F'67, 213C
Baldrey, J. A., S'67, 59C, 70C
Balk, P., F'67, 212C
Bard, A. J., S'67, 65C
Barrett, Jerry, S'67, 72C
Barry, B. T. K., F'67, 216C
Barry, M. L., F'67, 211C
Bartlett, H. E., S'67, 71C
Bartlett, J. H., F'67, 196C
Bartlett, N. S., F'67, 195C
Bates, H. E., S'67, 76C
Bauer, E. J., F'67, 203C
Bazzarre, D. F., F'67, 215C
Beals, David, F'67, 195C
Beck, T. R., S'67, 57C, 69C, F'67, 201C
Beer, S. Z., S'67, 65C, F'67 213C
Beesley, J. P., F'67, 204C
Benard, J., F'67, 202C
BenDaniel, D. J., S'67, 76C
Bennion, D. N., F'67, 193C
Berkenblit, M., F'67, 210C
Bernhard, William, F'67, 208C
Blair, J. W., S'67, 62C
Blake, B. E., F'67, 202C
Blech, I. A., S'67, 142C, F'67, 276C
Blocher, J. M., Jr., F'67, 214C
Blum, S. E., S'67, 146C
Blurton, K. F., F'67, 196C
Bockris, J. O'M., S'67, 57C
Boddy, P. J., S'67, 56C
Boden, David, S'67, 68C
Bon, C. K., S'67, 69C
Bond, A. P., F'67, 199C
Borders, E. Z., F'67, 205C
Boros, J., S'67, 59C
Boult, E. H., S'67, 73C
Bowen, R. J., S'67, 72C
Bracco, D. J., S'67, 61C
Bracken, R. C., S'67, 145C, F'67, 213C
Bradhurst, D. H., F'67, 201C
Brandis, E., S'67, 145C
Breiter, M. W., S'67, 74C
Brenner, Abner, F'67, 210C
Brill-Edwards, Harry, F'67, 213C
Brixey, J. C., Jr., F'67, 212C
Broadbent, R. H., F'67, 204C
Brockman, I. H., F'67, 203C
Brodd, R. J., S'67, 71C
Brookes, H. C., S'67, 69C
Brown, D., F'67, 274C

S'67 = Spring Meeting, 1967 (Dallas)
F'67 = Fall Meeting, 1967 (Chicago)

Brown, E. A., S'67, 66C
Brown, R. A., S'67, 61C
Brown, Ralph, S'67, 76C
Brummer, S. B., S'67, 74C
Bubar, S. F., F'67, 201C
Buchanan, B., S'67, 63C
Bunzow, D. A., F'67, 274C
Burbank, Jeanne, S'67, 74C, F'67, 197C
Burger, F. J., F'67, 206C
Burkhardt, P. J., S'67, 143C
Burgess, R. R., S'67, 144C, F'67, 276C
Burrage, P. M., F'67, 277C
Burrows, Brian, F'67, 194C
Busen, K. M., S'67, 144C
Butler, J. N., S'67, 67C, F'67, 193C
Byrne, J. J., F'67, 194C
Caban-Zeda, H. P., S'67, 58C, F'67, 273C
Cadoff, I. B., S'67, 53C
Caffrey, R. E., S'67, 142C, F'67, 275C
Cagnina, S. F., F'67, 275C
Cahan, B. D., S'67, 76C
Cahill, K., S'67, 74C
Cairns, E. J., S'67, 69C, F'67, 195C
Campos, M., F'67, 207C
Cantril, J. M., F'67, 209C
Carbauh, V. A. J., F'67, 208C
Carosella, F'67, 277C
Carroll, S., F'67, 195C
Carter, W. A., F'67, 216C
Casey, H. C., Jr., S'67, 146C
Casey, J. J., F'67, 274C
Castro, P. L., F'67, 273C
Catlin, Avery, F'67, 208C
Cauge, T. P., S'67, 53C, 62C, F'67, 273C, 274C
Cecil, Olin, S'67, 64C
Chaikin, S. W., S'67, 59C
Chang, C. C., S'67, 73C
Chapman, C. M., F'67, 203C
Chhabra, D., S'67, 142C
Chiarenzelli, R. V., F'67, 203C
Chicotka, R. J., S'67, 146C
Childers, M. G., F'67, 214C
Chopra, K. L., S'67, 53C
Chou, N., F'67, 212C
Choudhury, P. Rai, S'67, 65C
Chu, C. K., S'67, 145C
Chu, T. L., S'67, 62C, F'67, 273C
Cohen, G. L., F'67, 197C
Cohen, L. A., S'67, 66C
Cohen, M., F'67, 200C
Colby, J. W., S'67, 142C
Coleman, M. G., F'67, 276C
Collins, D. R., F'67, 275C
Comas, J. K., F'67, 277C
Conway, B. E., S'67, 65C
Cook, E. H., S'67, 69C
Cook, N. C., F'67, 215C
Cosgrove. J. F., S'67, 61C
Cowgill, M. G., F'67, 202C
Cowher, M. E., S'67, 147C
Cox, W. P., S'67, 142C, 143C
Craig, H. L., Jr., S'67, 76C
Crane, J. S., F'67, 210C
Criscione, J. M., S'67, 77C
Cross, J. D., F'67, 206C
Culp, J. D., F'67, 215C
Cunningham, J. A., S'67, 54C
Cuomo, J. J., S'67, 146C
Dalin, G. A., F'67, 197C, 198C
Damm, E. P., Jr., F'67, 209C
Datta, R. K., S'67, 147C
Davidson, K. V., S'67, 77C
Dautzenberg, W. G., S'67, 63C
Deal, B. E., F'67, 273C
Decker, D. R., S'67, 63C
Decosterd, J. P., F'67, 275C
Delchar, T., S'67, 73C
DeSmet, D. J., F'67, 200C
Dewey, R. D., S'67, 76C
Dey, A. N., F'67, 194C
Dignam, M. J., S'67, 56C
DiPietro, M. A., S'67, 147C
Dirkse, T. P., F'67, 196C
Dolan, R., S'67, 63C
Donald, D. K., F'67, 208C
Doo, V. Y., F'67, 275C
Doremus, R. H., S'67, 55C
D'Orsay, E., F'67, 193C
Dorsey, G. A., Jr, S'67, 58C
Douglass, D. L., F'67, 202C
Draughn, R. A., F'67, 208C
Dreiner, Rudolf, S'67, 57C
Driscoll, J. S., F'67, 194C
Drobek, J., S'67, 142C
Drum, C. M., S'67, 144C
Dumin, D. J., S'67, 53C
Dunn, C. G., S'67, 57C
Dyer, L. D., S'67, 145C
Dyson, W. H., F'67, 196C
Egan, T. F, F'67, 203C
Eide, J. E., F'67, 210C
Eisenberg, M., F'67, 193C
Elder, J. P., F'67, 196C
Elgan, D. L., F'67, 274C
Elving, P. J., S'67, 68C
Engeler, W., F'67, 273C
Epner, Martin, F'67, 213C
Epstein, Barry, S'67, 66C
Ernick, F. G., S'67, 63C
Esch, R. P., S'67, 143C
Euler, K. J., S'67, 69C
Evans, J. D., F'67, 215C
Eversteyn, F. C., S'67, 143C
Fairfield, J. M., S'67, 145C
Fang, F. F., F'67, 212C
Farha, F., Jr., S'67, 68C
Faust, J. W., Jr., S'67, 59C
Fehlner, F. P., F'67, 204C
Felten, E. J., F'67, 214C
Fergusson, R. R., S'67, 65C
Feucht, D. L., S'67, 64C
Fitzgerald, B., F'67, 215C
Fitzgibbons, W. A., S'67, 144C
Flatley, D. W., F'67, 275C
Foltz, R. L., F'67, 203C
Ford, M. M., F'67, 273C
Fosnocht, B. A., F'67, 215C
Foster, L. M., S'67, 146C
Foster, M. S., F'67, 195C
Foster, N. F., S'67, 54C
Francombe, M. H., S'67, 54C, 59C, 65C
Franklenthal, R. P., S'67, 74C, F'67, 201C
Franklin, T. C., S'67, 72C
Freitag, W. O., S'67, 60C
French, E. C., S'67, 75C
Frieser, R. C., F'67, 276C
Fujimura, Z., F'67, 205C
Fukuda, Masataro, F'67, 195C
Gabor, T., F'67, 214C
Gadd, J. D., F'67, 214C
Gaines, G. B., F'67, 203C
Galli, G., F'67, 276C
Gambino, R. J., S'67, 146C
Gandel, M. G., F'67, 198C
Gardner, E. E., F'67, 274C
Garfinkel, M., F'67, 274C
Gashurov, Gleb, S'67, 60C
Gates, H. R., S'67, 63C
Gatos, H. C., S'67, 63C
Gebhardt, J. J., S'67, 77C
Genshaw, M. A., S'67, 57C
Gereth, R., S'67, 147C, F'67, 211C
Germer, L. H., S'67, 73C
Gillette, R. B., S'67, 57C
Giner, J., S'67, 70C
Gittler, F. L., S'67, 63C
Glaeser, W. A., F'67, 203C
Glendinning, W. B., S'67, 144C
Glossbrenner, E. W., F'67, 202C
Gnanamuthu, D. S., S'67, 72C
Goetzberger, A., S'67, 62C, 273C
Goldstein, R. M., F'67, 205C
Gokhale, B. V., S'67, 63C
Goodkin, J., F'67, 198C
Goudswaard, B., F'67, 204C
Graham, L. D., F'67, 214C
Gray, P., F'67, 274C
Greenstein, E., F'67, 273C
Gregor, L. V., S'67, 143C
Grens, E. A., II, S'67, 69C
Grochowski, E. G., S'67, 63C
Gross, Bernhard, F'67, 206C
Grosskreutz. J. C., F'67, 201C
Grossman, J. J., S'67, 53C
Grotheer, M. P., S'67, 69C
Guelke, R. W., S'67, 69C
Guggenheim, H. J., S'67, 55C
Gulbransen, E. A., S'67, 75C
Gunderson, J. M., F'67, 215C
Haberecht, Rolf, S'67, 64C
Hackerman, Norman, F'67, 200C, 201C
Hagel, W. C., S'67, 77C
Hale, J. M., S'67, 56C, 66C
Hall, H. J., F'67, 209C
Hamakawa, Yoshihiro, F'67, 213C
Hamer, W. J., F'67, 193C
Hamilton, D. W., S'67, 57C
Haneta, Y., S'67, 143C
Hara, T., S'67, 53C, 64C
Harris, W. S., S'67, 71C
Harrison, J. H., S'67, 72C
Haruta, K., S'67, 58C
Harvey, J. A., F'67, 193C
Hashimoto, M., S'67, 64C
Heine, V., F'67, 273C
Heller, H. B., S'67, 144C
Herrmann, C. C., F'67, 193C
Hersch, P. A., F'67, 197C
Hersh, H. N., S'67, 60C
Hesson, J. C., F'67, 195C
Heynes, M. S. R., S'67, 63C
Hickam, W. M., S'67, 74C
Hickmott, T. W., S'67, 55C
Higgins, J. J., S'67, 77C
Higuchi, H., F'67, 212C
Hiyama, S., F'67, 206C
Hine, Fumio, S'67, 69C
Hirata, Y., S'67, 67C
Hobson, M. C., Jr., F'67, 200C
Hoffmann, A. K., S'67, 66C
Hokanson, J. L., S'67, 58C
Holly, F. J., F'67, 207C, 208C
Holmes, R. W., F'67, 193C
Horiuchi, Shiro, F'67, 207C
Horvath, J., F'67, 201C
Horve, L. A., S'67, 76C
Hovel, H. J., F'67, 211C
Hotz, M. C. B., S'67, 69C
Howard, A. M., F'67, 195C
Howard, J. K., S'67, 142C, F'67, 277C
Hsueh, Y. W., S'67, 63C
Hu, S. M., S'67, 145C
Huber, F., S'67, 56C
Hudock, P., S'67, 64C
Hueber, Bernard, F'67, 203C
Hull, E. M., F'67, 211C
Hunger, H. F., S'67, 65C
Hunt, J. B., F'67, 194C
Hurd, R. M., S'67, 75C
Husted, D. G., S'67, 58C
Hutchinson, C. O., F'67, 209C
Ibl, N., S'67, 57C, F'67, 205C
Ing, D. W., S'67, 62C, 145C
Inoue, K., F'67, 215C
Irving, S. M., F'67, 213C
Isaacs, H. S., F'67, 205C
Isoe, S., S'67, 66C
Itoh, Takuji, S'67, 72C
Iwamoto, R. T., S'67, 68C
Jackson, W., Jr., F'67, 195C
Jadus, D. K., S'67, 64C
James, S. D., S'67, 73C
James, W. J., F'67, 196C
Januzzi, N., F'67, 206C
Jasinski, Raymond, S'67, 67C, F'67, 194C, 195C
Javet, Philippe, S'67, 75C
Jelsma, L. F., F'67, 274C
Jennings, T. A., S'67, 58C, 167C
Jentgen, R. L., F'67, 203C
Jepsen, D., S'67, 142C
Johnson, K. E., S'67, 71C
Jones, D. A., F'67, 199C
Jones, E. E., F'67, 214C
Jones, R. L., F'67, 202C
Kamada, Minoru, F'67, 216C
Kang, H. Y., F'67, 197C
Kamiyama, T., F'67, 212C
Kannam, P. J., S'67, 63C
Kanz, W. L., S'67, 59C
Katan, T., S'67, 70C
Katsoulis, E. G., F'67, 197C
Kawamata, M., S'67, 67C
Keralla, J. A., F'67, 197C
Keyzer, H., F'67, 206C
Kelley, F. J., S'67, 71C
King, R. C., S'67, 147C
Kirkland, Susan, F'67, 194C
Kissel, J. W., F'67, 203C
Klein, G. P., S'67, 57C, 60C
Klein, Richard, S'67, 61C
Klem, C. G., F'67, 277C
Klerer, Julius, S'67, 60C
Klokholm, E., S'67, 58C, 59C
Kmieciak, H. A., F'67, 214C
Kober, F. P., S'67, 75C, F'67, 196C, 273C
Koch, D. F. A., S'67, 73C
Koloffenstein, T., S'67, 144C
Kolthoff, I. M., S'67, 67C
Korinek, G. J., S'67, 58C
Kornfeld, W., S'67, 144C
Kornhaas, R. J., F'67, 205C
Kozawa, A., S'67, 75C
Kressel, Henry, S'67, 61C
Krier, C. A., F'67, 215C
Kruger, Jerome, S'67, 74C
Kruishoop, J. C. W., S'67, 60C
Kummer, D. L., F'67, 215C
Kuper, A. B., S'67, 58C, F'67, 273C
Kuppinger, R. E., F'67, 193C
Kuwana, Theodore, S'67, 66C
LaBarbera, J. S., F'67, 214C
LaClaire, P. A., S'67, 144C
Ladd, G. O., S'67, 64C
Lander, J. J., F'67, 197C
Lange, W. H., F'67, 195C
Lawrence, J. E., F'67, 212C
Lawver, J. E., F'67, 209C
Leach, J. S. Ll., F'67, 201C
Lee, C. H., S'67, 62C
Lee, H. H., F'67, 216C
Legat, W. H., S'67, 64C, 142C
Lehmann, Willi, S'67, 62C
Lehmkuhl, Herbert, S'67, 66C
Lehovec, Kurt, S'67, 55C
Leibenguth, J. L., F'67, 200C
Leidheiser, Henry, Jr., F'67, 202C
Lerner, S., F'67, 198C
Lesk, I. A., S'67, 144C

Levine, H. A., F'67, 277C
Levy, Milton, F'67, 199C
Liang, C. C., F'67, 197C
Lieberman, M. L., S'67, 55C
Light, T. B., F'67, 210C, 211C
Lightstone, J. B., F'67, 200C
Lilly, A. C., Jr., F'67, 207C
Lindley, W. T., F'67, 274C
Littlehailes, J. D., S'67, 69C
Littman, F. E., S'67, 69C
Lizlovs, E. A., F'67, 199C
Locker, L. D., F'67, 213C
Lowitz, D. A., F'67, 206C
Ludwig, Frank, S'67, 72C
Lui, Kenneth, F'67, 210C
Lussow, R. O., F'67, 213C
Lynn, Scott, S'67, 69C
MacArthur, D. M., F'67, 198C
MacChesney, J. B., S'67, 55C
MacDonald, I. A., S'67, 58C
MacKenna, E. L., S'67, 142C, 143C
Mader, S., S'67, 53C
Maget, H. J. R., S'67, 70C
Maki, M., F'67, 212C
Maiachesky, P., F'67, 195C
Manasevit, H. M., F'67, 213C
Manchester, K. E., F'67, 212C
Mancini, F. P., F'67, 274C
Manenc, J., F'67, 202C
Mann, J. E., S'67, 62C
Mansfield, F., F'67, 198C
Mapes, William, F'67, 195C
Marcantonio, J., S'67, 77C
Marcus, R. B., S'67, 59C
Marcy, E. L., S'67, 63C
Marincic, L., S'67, 65C
Marincic, N., F'67, 197C
Mariner, R. V., S'67, 59C
Marino, J., S'67, 63C
Marlett, E. M., S'67, 67C
Marston, P. J., S'67, 70C
Martius, U., F'67, 200C
Mascarenhas, S., F'67, 206C, 207C
Mathers, J. E., S'67, 67C, 147C
Matsuda, F. A., S'67, 67C
Matukura, Y., F'67, 212C
McAllister, W. A., S'67, 61C
Mc Breen, James, F'67, 197C
McDowell, J. R., F'67, 207C
McIntyre, J. D. E., S'67, 72C
McIntyre, T. W., S'67, 66C
McLouski, R. M., F'67, 212C
McNeil, G., F'67, 275C
McNeill, W., S'67, 58C, 167C
McWilliams, G. E., F'67, 194C
Mehta, R. R., S'67, 53C, 62C, F'67, 273C, 274C
Meieran, E. S., S'67, 142C, F'67, 276C
Meikleham, Virginia, F'67, 210C
Michelson, C. E., S'67, 56C
Michielli, R. F., S'67, 68C
Mikus, F. F., S'67, 147C
Miller, B., F'67, 198C, 199C
Miller, E. P., F'67, 209C
Miller, L. L., S'67, 66C
Milnes, A. G., F'67, 211C
Mitsumata, Tadayasu, F'67, 195C
Miura, Y., F'67, 212C
Moll, J. L., S'67, 54C
Moore, J. B., Jr., F'67, 202C
Mori, K., F'67, 215C
Morris, J. D., F'67, 275C
Morrissey, R. J., F'67, 204C
Morritz, F. L., S'67, 146C
Mott, N. F., S'67, 54C
Moudy, L. A., F'67, 276C
Mroczkowski, F'67, 277C
Muehlhaeusser, M., F'67, 205C
Mueller, W. A., F'67, 199C, 200C
Murphy, P. V., F'67, 207C, 208C
Murray, Lawrence, S'67, 61C
Mutter, W. E., S'67, 59C
Naber, C. T., S'67, 53C
Naito, Kiyoaki, F'67, 207C
Naito, Masahiko, S'67, 72C
Nakanuma, S., S'67, 143C
Nakai, Yasuo, F'67, 211C
Nakamura, Z., F'67, 200C
Namikata, T., F'67, 206C
Nancollas, G. H., S'67, 68C
Nanis, Leonard, S'67, 70C, 75C
Narayan, R., F'67, 200
Neher, M. B., F'67, 203C
Neipert, M. P., S'67, 69C
Nejedlik, J. F., F'67, 214C
Neuenschwander, Ernst, S'67, 77C
Newkirk, J. B., S'67, 77C
Newman, John, S'67, 70C
Nicollian, E. H., S'67, 62C
Nishimatsu, S., F'67, 212C
Niskanen, E., F'67, 200C
Nitto, Hajime, F'67, 216C
Nobe, Ken, S'67, 76C, F'67, 199C
Noble, P. J. W., S'67, 70C
Noreika, A. J., S'67, 62C, 65C
Nunoshita, Masahiro, F'67, 213C
Oblas, D. W., S'67, 61C
O'Connor, J. J., S'67, 147C
Ohno, Minoru, F'67, 211C
Ohta, Masaya, S'67, 62C, F'67, 211C
Okada, Hideya, F'67, 215C
Okinaka, Y., F'67, 198C
Olofsen, P. O., F'67, 211C
Olsen, H., S'67, 64C
Ord, J. L., S'67, 57C, 74C, F'67, 200C
Ortner, Martin, F'67, 215C
Oswin, H. G., F'67, 186C, 197C
Palilla, F. C., S'67, 60C
Palumbo, D. T., S'67, 61C
Panish, M. B., S'67, 146C
Panzer, R. E., F'67, 194C
Papazian, S. A., F'67, 210C
Park, R. L., S'67, 73C
Parker, S. G., F'67, 211C
Parry, J. M., S'67, 70C
Parry, S. J. S., S'67, 71C
Parzuchowski, R. S., F'67, 214C
Pawel, R. E., F'67, 202C
Pawlowski, H. D., F'67, 212C
Payne, Richard, S'67, 67C
Peck, W. F., Jr., S'67, 72C
Peekema, R. M., F'67, 204C
Pemsler, J. P., F'67, 200C, 214C
Perlman, M. M., F'67, 206C, 207C, 208C
Peters, T. E., S'67, 61C
Petrocelli, J. V., S'67, 72C, F'67, 209C
Petrovich, J. P., S'67, 67C
Pfeil, R. W., F'67, 203C
Phelps, John, S'67, 65C
Phillips, D. L., F'67, 216C
Pickard, W. F., F'67, 209C
Piersma, B. J., S'67, 72C, 73C, 75C
Pilla, A. A., F'67, 193C
Plank, P. P., F'67, 214C
Plaskett, T. S., S'67, 146C
Pliskin, W. A., S'67, 143C
Plumlee, W. W., F'67, 205C
Pohl, H. A., F'67, 209C, 210C
Polick, S. G., S'67, 60C
Poling, G. W., S'67, 74C
Pollack, G. P., F'67, 185C
Popat, P. V., F'67, 196C
Poponiak, M. R., F'67, 275C
Potter, J. F., S'67, 55C
Powers, R. A., S'67, 75C
Powers, R. W., F'67, 196C
Prahacs, S., F'67, 199C
Priceman, S., F'67, 214C
Pringle, J. P. S., S'67, 56C
Przybyla, F., S'67, 71C
Puri, O. P., F'67, 208C
Radvila, Peter, F'67, 196C
Raleigh, D. O., S'67, 76C
Rand, M. J., S'67, 62C
Randall, J. J., Jr., S'67, 56C
Rao, M. L. B., S'67, 68C, F'67, 193C
Rapperport, E. J., F'67, 214C
Reddy, A. K. N., S'67, 57C
Redmond, J. P., F'67, 215C
Reed, J. L., F'67, 196C
Reese, W. E., F'67, 204C
Reedyk, C. W., F'67, 207C, 208C
Regh, J., F'67, 277C
Reid, G. H., S'67, 68C
Reisman, A., F'67, 210C
Revitz, M., F'67, 275C
Riley, R. E., S'67, 77C
Rinker, R. G., S'67, 69C
Robbins, H., S'67, 64C
Roberts, J. F., S'67, 62C
Robinson, Myron, F'67, 208C
Robinson, V. M., S'67, 76C
Robinson, W. L., S'67, 59C
Roosild, S., S'67, 63C
Root, C. B., F'67, 194C
Rosa, C. J., S'67, 77C
Rosenberg, W. D., F'67, 274C
Rosengarten, F., F'67, 276C
Ross, R. F., S'67, 142C
Rosvold, W. C., S'67, 64C
Rottersman, M. H., S'67, 59C
Roughan, P. E., F'67, 212C, 276C
Rowlette, J. J., F'67, 198C
Rubin, E. J., F'67, 198C
Rudd, E. J., S'67, 65C
Russell, C. A., F'67, 202C
Russell, L. K., S'67, 64C
Sachs, J. T., F'67, 198C
St. John, G. A., S'67, 59C
Salkind, A. J., F'67, 196C
Salomon, M., S'67, 72C
Salomon, R. E., S'67, 58C
Sama, L., F'67, 214C
Santhanam, K. S. V., S'67, 65C
Sarian, S., S'67, 77C
Sasaki, H., F'67, 206C
Sato, K., S'67, 144C
Scarr, R. F., S'67, 75C
Schaap, W. B., S'67, 68C
Schechter, D. L., S'67, 69C
Schmidt, P. F., S'67, 55C
Schmidt, R., S'67, 144C
Schnieder, C. P., F'67, 274C
Schreier, L. A., F'67, 196C
Schumann, P. A., Jr., F'67, 274C
Schuster, L. K., F'67, 216C
Schwan, H. P., F'67, 210C
Schwartz, N., S'67, 55C
Schwuttke, G. H., S'67, 145C, F'67, 274C, 277C
Schuldiner, Sigmund, S'67, 72C, 73C, 75C
Scott, J. R., S'67, 76C
Sebisty, J. J., F'67, 216C
Sedgwick, T. O., F'67, 275C
Seiger, H. N., F'67, 198C
Selim, R. G., S'67, 68C
Serad, G., S'67, 58C
Sessler, G. M., F'67, 208C
Sewell, P. B., S'67, 73C
Shallcross, F. V., S'67, 54C
Shaw, D. W., S'67, 146C
Shepheard, R. G., S'67, 142C
Shimotake, H., S'67, 69C, F'67, 195C
Shiraishi, M., F'67, 212C
Shirn, G. A., S'67, 55C
Sholette, W. P., F'67, 196C
Shrader, R. E., S'67, 61C
Silvertri, V. J., S'67, 64C, F'67, 211C
Simmons, J., S'67, 58C
Sinder, R. M., S'67, 144C
Singh, S., F'67, 208C
Simon, A. C., F'67, 195C
Sivertsen, David, S'67, 64C
Slager, J. E., S'67, 67C
Sligh, J. L., F'67, 210C
Sloka, W. E., S'67, 71C
Smart, W. H., S'67, 72C
Smeltzer, W. W., F'67, 202C
Smith, J., F'67, 276C
Smith, S. M., S'67, 70C
Smith, V. V., F'67, 195C
Smyrl, W. H., S'67, 68C
Smyth, D. M., S'67, 55C
Snow, E. H., F'67, 275C
Snowball, R. F., F'67, 204C
Solos, L. P., F'67, 204C
Sommers, H. A., S'67, 71C
Sopher, R. P., S'67, 142C
Sovers, Ojars, S'67, 60C
Spencer, W. J., S'67, 58C
Spong, A. H., S'67, 69C
Sprague, J. W., S'67, 63C, F'67, 195C
Sprokel, G. J., S'67, 145C
Staal, P. W., S'67, 67C
Steidel, C. A., S'67, 57C
Strack, H. A., F'67, 276C
Straumanis, M. E., F'67, 196C
Strier, M. P., S'67, 69C
Su, Tsung-yuan, S'67, 67C
Sugano, G., F'67, 215C
Suginohara, Y., F'67, 210C
Sugiyama, Kohzoh, S'67, 77C
Swann, R. C. G., S'67, 53C, 62C, F'67, 274C
Swann, Sherlock, Jr., S'67, 66C
Swiggard, E. M., S'67, 146C
Swinkels, D. A. J., S'67, 71C
Szedon, J. R., S'67, 59C, 62C, F'67, 273C
Szpak, S., S'67, 70C
Takahashi, Takehiko, S'67, 77C
Takiguchi, Shuichiro, F'67, 216C
Tallman, R. L., S'67, 75C
Tan, S., S'67, 59C
Taub, J. M., S'67, 77C
Tavarusko, A., F'67, 205C
Taylor, H. L., S'67, 58C
Teague, E. C., S'67, 62C
Terner, E., S'67, 143C
Thaller, L. H., F'67, 194C
Thirsk, H. R., S'67, 73C
Thomas, R. C., S'67, 63C
Thomas, R. N., S'67, 65C
Thomas, W. H., S'67, 67C
Thourson, T. L., F'67, 209C
Tilley, D. E., F'67, 206C
Tobias, C. W., S'67, 68C
Tobias, R. F., F'67, 199C
Tokuyama, T., F'67, 212C
Tolliver, D. L., F'67, 275C
Toma, S. Z., S'67, 147C
Tomita, Kensuke, S'67, 77C
Toni, J. E. A., F'67, 193C
Tong, A. H., F'67, 275C
Toy, S. M., F'67, 201C
Tramposch, R. F., F'67, 211C
Tricklebank, S. B., S'67, 71C
Trivich, Dan, F'67, 213C
Tucker, C. W., Jr., S'67, 73C
Tung, S. K., S'67, 142C, 275C
Tvarusko, A., S'67, 57C
Uhlig, H., F'67, 198C, 201C

Urbach, H. B., S'67, 72C
Urban, Zeljko, F'67, 207C
Vaaler, L. E., S'67, 71C
Vagnard, G., F'67, 202C
van der Grinten, W. J., F'67, 197C
van Loon, P. G. G., S'67, 63C
van Someren, Lawrence, F'67, 208C
Van Uitert, L. G., S'67, 60C
Vermilyea, D. A., S'67, 55C, F'67, 201C
Vincent, C. A., S'67, 68C
Visco, R. E., S'67, 68C
Viswanathan, S., F'67, 206C
Voelker, M. W., S'67, 71C
Vromen, B. H., S'67, 54C
Wagenknecht, J. H., S'67, 67C
Wakefield, G. F., F'67, 215C
Walczak, D. A., S'67, 145C
Wald, F., S'67, 76C
Wales, C. P., F'67, 197C
Walker, I. F. M., S'67, 55C
Walker, P., S'67, 62C
Wallace, R. A., F'67, 207C
Wallmark, J. T., F'67, 275C
Warner, T. B., S'67, 72C, 73C, 75C
Watanabe, C. K., F'67, 199C
Wawzonek, S., S'67, 66C, 67C
Weaver, C., S'67, 54C
Weinberg, N. L., S'67, 66C
Weinstein, Martin, S'67, 76C
Weissbart, J., S'67, 72C
Wenning, G. T., F'67, 204C
West, Hiry, F'67, 196C
West, J. E., F'67, 208C
Westwood, A. R. C., F'67, 199C
Whitehurst, Claudia, F'67, 198C
Whitfield, M. G., F'67, 214C
Whitley, J. H., F'67, 203C
Wiedmer, M., S'67, 57C
Wiggins, C. S., S'67, 60C
Wikstrom, L. L., S'67, 75C
Wiley, J. S., F'67, 205C
Wilkins, B. R., S'67, 63C
Will, F. G., S'67, 76C
Willardson, R. K., S'67, 64C, 74C
Williams, D. L., F'67, 194C
Willihnganz, E., F'67, 195C
Wilson, J. R., S'67, 58C
Winsel, A., S'67, 70C
Witt, A. F., S'67, 63C
Wolosin, S. M., F'67, 214C
Wonsidler, D. R., S'67, 142C
Woodhall, B. J., S'67, 69C
Wu, Ning-Gau, F'67, 204C
Yamaguchi, Jiro, F'67, 207C, 213C
Yamamoto, Kazuo, F'67, 215C
Yanagase, K., F'67, 210C
Yanagase, T., F'67, 210C
Yanagida, I., F'67, 200C
Yao, N. P., F'67, 193C
Yarish, M., F'67, 273C
Yeargar, J. R., S'67, 58C
Yeager, Ernest, S'67, 72C
Yeh, T. H., F'67, 274C
Yonezaki, Shigeru, F'67, 216C
Young, L., S'67, 56C
Yuan, Q. K., F'67, 204C
Zahnow, E. W., S'67, 66C
Zalar, S. M., S'67, 54C
Zanowick, R. L., S'67, 146C
Zaplatynsky, Isidor, F'67, 200C
Zeitman, S. A., S'67, 59C
Zurosky, Walter, F'67, 193C

Subject Index (Vol. 114, 1967)

Absorption
  Electrolytic hydrogen by nickel. 568
  Hydrogen by electrode and electrolyte. 909, d. 916, d. 1271
  Oxygen-niobium system. Low-pressure. 452
Absorption spectra
  Ultraviolet. In lead-acid battery. 232
  Ytterbium in cadmium fluoride. 609.
Acetamide
  Electrolyte for thermal cell. 209, 212
Acetylene
  Corrosion inhibitor. Infrared spectrum. 1209
  Electrooxidation on gold. 572
Acids
  See Carbonic acid. Phosphoric acid
Acrylonitrile
  Electrolytic reduction. 1255
  Hydrodimerization. 899
Activation
  Electrochemical. Of platinum. 1113
Activity
  Molten tin alloys. 935
  Platinum catalysts in solution. 1120
Adiponitrile
  Formation by electrolysis of acrylonitrile. 899
Adsorption
  Methanol on platinum electrode. 904, cor. 1221
  Oxygen-niobium system. Low-pressure. 452
  Propane on platinum in acid. 764
  Pseudocapacitance. In consecutive electrode process. 682
Alcohols
  See Methanol
Alkali gadolinates
  Hosts for europium fluorescence. 252
Alkali yttrates
  Hosts for europium fluorescence. 252
Alkaline earth yttrates
  Hosts for europium fluorescence. 252
N-allyl quinaldinium bromide
  Nickel plating brightener. 50
Alloy
  Aluminum
    Galvanic corrosion. 777
    Oxide film growth. 354
  Aluminum-tin. 777
  Aluminum-plutonium. *See* Plutonium-aluminum, *below*
  Antimony-lead. *See* Lead-antimony, *below*
  Arsenic-gallium-indium. *See* Gallium-indium-arsenic, *below*
  Binary. Noble metal. 698
  Cerium-cobalt. *See* Cobalt-cerium, *below*
  Cerium-plutonium-cobalt. *See* Plutonium-cobalt-cerium, *below*
  Chromium-iron. *See* Iron-chromium, *below*
  Cobalt-cerium. 225, d. 1269
  Cobalt-nickel. *See* Nickel-cobalt, *below*
  Cobalt-plutonium-cerium. *See* Plutonium-cobalt-cerium, *below*
  Columbium. 1018
  Copper-gold. 685, 698
  Copper-zinc. 698
  Gallium-indium-arsenic. 164
  Gold-copper. *See* Copper-gold, *above*
  Gold-silver. *See* Silver-gold, *below*
  Indium-gallium-arsenic. *See* Gallium-indium-arsenic, *above*
  Iron-chromium. 435, 542, 682, 788, 986
  Iron-nickel. 568
  Lead. 800
  Lead-antimony. 1
  Nickel-cobalt. 535
  Nickel-iron. *See* Iron-nickel, *above*
  Niobium. 145
  Niobium-zirconium. *See* Zirconium-niobium, *below*
  Palladium-silver. *See* Silver-palladium, *below*
  Plutonium-aluminum. 23
  Plutonium-cobalt-cerium. 225, d. 1269
  Silver-gold. 493, 1258
  Silver-palladium. 1239
  Tin. 935
  Tin-aluminum. *See* Aluminum-tin, *above*
  Titanium. 551
  Zinc-copper. *See* Copper-zinc, *above*
  Zircaloy-2. 124
  Zirconium-niobium. 1089
Aluminate. *See* Spinel
Aluminum
  Anodic oxidation in presence of hydrated oxide. 843
  Deposition on silicon. 605
  Passivation by chromate solutions. 1001
  Potential in chloride solutions. 694
Aluminum alkoxide
  Thermal decomposition. 948
Aluminum alloy
  Galvanic corrosion. 777
  Oxide film growth over five years. 354
  See also Plutonium-aluminum alloy
Aluminum oxide
  Dissolution rate. Effect on corrosion. 352
  From aluminum alkoxide. 948
  Passive films on aluminum by chromate. 1001
  Phosphors. Red-emitting. d. 646
  Rhodium-activated. Fluorescence. 1396
  See also Corundum. Magnesium oxide-aluminum oxide-gallium oxide system. Sodium aluminum fluoride-aluminum oxide system
Aluminum-tin alloy
  Electrochemical behavior. 777
Aluminum 1100
  Corrosion. 352, 353
Amines
  Aromatic. Electrolytic oxidation. 1025
  See also Ethylene diamine
Aniline
  Effect on iron corrosion in acid. 1006, 1012
  Electrolytic oxidation in acetonitrile. 1025
Anisotropic stress effect
  In silicon junction transducer. 277, d. 1313
Annealing
  Nickel electrodeposits. 449
  Vacuum. Oxide film regeneration. 796
Anode
  Cylindrical. Mass transport of hydrogen. 349
  Effect in cryolite-alumina melts. d.652
  Fuel cell. Hydrogen oxidation. 531
  Graphite. Impervious. 709
  Hydrocarbon fuel cells. 17, d.1265, 233
  Hydrogen transport. 349
  Platinum. Movable, partially submerged. 531
  See also Films, Anodic. Passivation, Anodic
Anodic deposition
  Iron oxide films on iron. 674
  Iron oxide films on platinum. 678
Anodic dissolution
  Cadmium. 424
  Nickel. Electrodeposited. 821
  Zinc in potassium nitrate. 885
Anodic oxidation
  Alloys. 145
  Aluminum in presence of hydrated oxide. 843
  Electrocatalysts for. 980
  Passive iron. 674
  Silicon in potassium nitrate-n-methylacetamide. 629
  Silver in caustic electrolyte. 1239
  Silver-palladium alloys. 1239
  Tantalum. Gas phase. 1134
  Yttrium thin films. 75
Anodic oxide
  Growth behavior on silicon. 405
  Growth measurement on iron. 585
Anodic polarization
  Aluminum. 694
  Iron. Kinetics. 682
Antimonide
  See Indium antimonide
Antimony
  Thermodynamic interaction with zinc. 800
  See also Lead-antimony alloy
Antimony telluride
  Solid solutions with bismuth telluride. 259
  See also Lead telluride-antimony telluride system
Apatite
  Luminescent. Stoichiometry. 956
  See also Calcium chlorapatite. Calcium fluorapatite. Manganese fluorapatite
Arsenic
  See Gallium-arsenic-copper system. Gallium-arsenic gold system. Gallium-arsenic-silver system. Gallium-arsenic-tellurium system. Gallium-indium-arsenic alloys
Arsenide
  See Gallium arsenide. Indium arsenide. Silicon arsenide

Battery
  Electrodes. High rate. 8
  Grids. Lead-antimony. Corrosion. 1
  Lead-acid
    Corrosion of grids. 1
    Ultraviolet absorbance. 232
  Low-temperature system. 655
  Silver chloride-magnesium with sea water electrolyte. 299
  Storage. Lead-acid. 1
  See also Cell

Benzyl halides
Polarographic reduction. 942
Beryllium
Fluorination. Kinetics. 1206
Bismuth
Activator of rare earth oxides. 1137
Activator of yttrium vanadate phosphors. 1057
Thermodynamic interaction with zinc. 800
Bismuth selenide
Solid solutions with bismuth telluride. 259
Bismuth telluride
Solid solutions with bismuth selenide and antimony telluride. 259
Solidification. Effect of ultrasonic agitation. 259
See also Tin telluride-bismuth telluride system
Blood plasma
Electrolysis. 221
Book reviews. 25C, 102C, 121C, 167C, 243C, 278C, 302C
Borate
See Indium orthoborate. Orthoborate
Boron
Polycrystalline. Pressure effects. 805
Brief Communications. ed. 5C
Brightener
For nickel plating. Radioactive tracers. 50
Bromide
See N-allylquinaldinium bromide
Butyrolactone
Electrolyte. Behavior of lead. 665

Cadmium
Anodic dissolution. 424
Aqueous system. Alternating current polarography. 239, 1130
Double layer capacitance in solution. 933, cor. 1099
Polycrystalline. 933, cor. 1099
Thermodynamic interaction with zinc. 800
Cadmium chloride
See Potassium chloride-cadmium chloride system
Cadmium fluoride
Ytterbium-doped. Optical spectra. 609
Cadmium mercury telluride
Films prepared by cathodic sputtering. 616
Cadmium selenide
Photoconductive properties. Control. 390
See also Zinc cadmium selenide
Cadmium-selenium system
Phase equilibria. 394
Cadmium silicoselenide
Synthesis and properties. 1074
Cadmium silicosulfide
Synthesis and properties. 1074
Cadmium sulfide
Chemical polishing. 295
Growth from liquid cadmium solution. 403
Single crystals. Closed system vapor growth. 851
Trapping spectrum. 511
Vapor growth from elements. 851
See also Zinc cadmium sulfide
Cadmium zinc sulfide
Photoconductive sintered layer. 1072
Calcium chlorapatite
Crystal growth and crystallographic properties. 77
Calcium fluorapatite
Crystal growth and crystallographic properties. 77
Calcium halophosphate
Phosphors. Chemical analysis. 956
Calcium molybdate
Rare earth niobates in. Segregation coefficients. 108
Calcium oxide
See Zirconium calcium oxide
Calomel
See Mercurous chloride
Capacitance
Double layer
Polycrystalline cadmium. 933, cor. 1099
Polycrystalline silver. 817
Irradiated zirconium and Zircaloy-2. 124
Measurements of double layer. Square-wave technique. 593
Potential dependent. 810
See also Adsorption pseudocapacitance
Capacitor
See Electrolytic capacitor
Carbide
See Hafnium carbide. Silicon carbide. Titanium carbide. Zirconium carbide
Carbon
Electrode. Porous for fuel cell. 582
See also Anode, Graphite
Carbon dioxide
Determination during propane oxidation. 360
Oxidation of nickel. 1215
Carbonate
See Lithium carbonate-sodium carbonate. Propylene carbonate
Carbonic acid
Dissociation. Effect of pressure. 330
Carburization
Iron-chromium alloys. 435
Carrier-concentration profiles
Epitaxial gallium arsenide films. 110
Catalysis
Oxidation of formaldehyde and methanol. 773
See also Electrocatalyst
Catalyst
Platinum. Activity in solution. 1120
See also Electrocatalyst
Cathode
Charge transfer complexes. In solid-state cell. 323
Copper chloride. In organic electrolyte cell. 13
Platinum. Rotating. Oxygen reduction. 1043
Processes in molten nitrates and nitrites. 64
See also Sputtering, Cathodic
Cathodic polarization
Aluminum. 694
Cathodic reduction
Oxygen
On noble metals and alloys. 1036
On platinum. 1043
Cathodoluminescence
Europium
In orthoborates. 613
In yttrates and gadolinates. 252
Terbium
In indium orthoborate. d.652
In orthoborates. 613
Cationic migration
In silicon dioxide films on silicon. 624
Cell
Absorption-induced electrode potential. 319
Buffered glass electrode. 330
Local electrolytic. Current calculation. 782
Local galvanic. Current calculation. 782
Organic electrolyte. With copper chloride cathode. 13
Solid-state electrochemical. 323
Transference. Concentration transients. 917
See also Battery. Fuel cell. Thermal cell. Thermogalvanic cell
Cerium
See Cobalt-cerium alloys. Plutonium-cobalt-cerium alloys
Charge-discharge mechanism
In electrolytic capacitors. d. 648
Charge transfer
Coefficients for cadmium. 1130
Charging
Galvanostatic. Overpotential-time variation. 810
Chloride
See Cadmium chloride. Cuprous chloride. Lead chloride. Mercurous chloride. Polyvinylidene chloride. Potassium chloride
Chlorine
Electrodes. High current density porous. Impurity effects. 812
Chromium
See Iron-chromium alloys
Circuit
See Nonlinear circuit
Cobalt
Oxide scales. Substructures. 535
See also Nickel-cobalt alloys. Plutonium-cobalt-cerium alloys
Cobalt-cerium alloys
Surface tensions determined from frozen menisci. 225, d.1269
Cobalt ferrite
Oxidation with nitrous oxide. 482
Reduction with carbon monoxide. 482
Columbium alloys
Deposition of titanium on. 1018
Complexes
Composition and equilibrium constant determined by calorimetry. 131
Conduction
Mixed. In solid electrolytes. 752
Conductivity
Potassium hydroxide and potassium hydroxide-zinc oxide electrolytes. 1045
See also Electrical conductivity. Photoconductive properties
Copper
Corrosion resistance in oxygen difluoride. 706
Electrodeposition. Effect of surface roughness. 54, d. 1267
Layers in platinum. Formation and dissolution. 1125
Oxidation
In carbon dioxide. 685
Kinetics. 669
Role in transformation of hexagonal zinc sulfide. 1143
Single crystal. Heating in hydrogen and nitrogen. Effect on kinetics. 669
Solubility and diffusion in indium arsenide. 856
See also Cupric . . . Cuprous . . . Gallium-arsenic copper system
Copper-gold alloys
Electrolytic dissolution. 698
Oxidation in carbon dioxide. 685
Copper-zinc alloy
Electrolytic dissolution. 698
Corrosion
Aluminum alloys. 777
Aluminum 1100
Effect of oxide dissolution. 352
In water below boiling point. 353
Galvanic. Of aluminum alloys. 777
In distilled water. Potentiostatic studies. 489
Inhibition
By acetylenic compounds. 1209
Of iron in sulfuric acid. 1006, 1012
Of steel in sulfuric acid. 1015
Inhibitors. Organic. 1006, 1012
Potentiostatic studies. Instrumentation. 489
Resistance of platinum, copper, nickel, and tantalum in oxygen difluoride. 706
Storage battery grids. 1
Stress. In lead-acid battery grids. 1
Tantalum in aqueous electrolytes. 363, 495
Zirconium and Zircaloy-2. Enhancement by irradiation. 124
See also Passivation. Stress corrosion cracking
Corundum
Chemical polishing with vanadium pentoxide. 356
Cracking
See Stress corrosion cracking
Cryolite
See Sodium aluminum fluoride
Crystal growth
Calcium chlorapatite. 77
Calcium fluorapatite. 77
Cuprous chloride single crystals. 388
In gels. 263
Iron oxide whiskers on iron. 1227
Microscopic rate. 413
Silicon carbide. Influence of carbon transport kinetics. 1149
See also Czochralski growth
Crystal orientation
Effect on oxidation of iron. 32
Crystallization
See Electrocrystallization
Crystallographic defects
See Inhomogeneities
Crystallographic properties
Calcium chlorapatite. 77
Calcium fluorapatite. 77
Crystals
Impurity heterogeneities from rotation. 738
Nucleation in gels. 263
Cuprous chloride
Cathode in organic electrolyte cell. 13
Formation and discharge in organic electrolyte cell. 13
Single crystal growth with flux. 388, d.1314
Cuprous oxide
Thin film growth. 669
Cupric oxide
Free energy of formation. 30
Current
Calculation for local galvanic cells. 782
See also Direct current . . .
Current-potential characteristics
Methanol on palladium. 1251
Cyanoalkyldimethylsulfonium ions
Electrochemical reduction. 1095
Czochralski growth
Radial solute segregation. 959
Temperature oscillations. 1077

DTA. *See* Differential thermal analysis
Defect solid state chemistry. Chemical no-

tation. 1080
Degassing
In oxygen-niobium system. 452
Dendrites
Of fcc metals. Twin configuration. 1311
Deposition
Inks for insulated-gate transistors. 96
Tantalum and tantalum oxide by cathodic sputtering. 505
Titanium on columbium alloys. 1018
See also Anodic deposition. Electrodeposition. Electrophoretic deposition. Epitaxial deposition. Ion deposition. Vacuum deposition. Vapor deposition.
Dielectric
Films. Anodization. 603
Zinc oxide. Polycrystalline. 833
Diethyl maleate
Electroreduction and hydrodimerization. 1023
Differential thermal analysis
Electroless nickel. 442
Nickel hydroxide structure. 418
Phase diagrams in gallium-arsenic ternary systems. 516
Diffraction. *See* Electron diffraction
Diffusion
Zinc into gallium arsenide. 181, 297
Dimethylformamide
Solvent for mercuric salts. 634
Dinitrogen tetroxide
See Hydrogen fluoride-nitrogen tetroxide
Direct current polarization technique
In study of mixed conduction in solid electrolytes. 752
Discharge
See Charge-discharge mechanism. Radio-frequency glow discharge reaction
Dissolution
See Anodic dissolution. Electrolytic dissolution

EPR. *See* Electronic paramagnetic resonance
Electrical conductivity
Sea-water electrolytes. 299
Electrical contact
Ohmic. Lithium-diffused. 1063
Electrical double layer
Capacitance measurements. Square-wave technique. 593
Electrocatalyst
Platinum. For anodic oxidation of hydrocarbons. 980
Electrochemical Society
Awards
Acheson Medal Award. 242C, 260C, 276C, 302C
Colin Garfield Fink Fellowship. 15C, 28C, 78C
ECS Fellowship Award. 15C, 28C, 78C, 80C
Edward Weston Fellowship. 15C, 28C, 78C, 239C
F. M. Becket Memorial Award. 119C, 257C
Francis Mills Turner Memorial Award. 165C.
Palladium Medal Award. 219C, 291C
Summer Fellowship Awards. 218C, 258C
Young Author's Prize. 165C
Change of name. *ed.* 155C, 295C
Constitution. 298C
Cooperation of members. *ed.* 115C
Division news
Battery. 24C, 166C
Corrosion. 10C, 166C
Dielectrics and Insulation. 99C, 219C, 295C
Electrodeposition. 10C, 242C
Electro-Organic. 99C, 220C
Electronics. 166C
Electrothermics and Metallurgy. 24C, 99C, 220C
Industrial Electrolytic. 100C
Theoretical Electrochemistry. 24C, 166C
Obituaries
Armin O. Apelt. 278C
Oliver W. Brown. 167C
Ernest John Dobbs. 101C
Robert A. Ehrhardt. 300C
Jaroslav Heyrovsky. 148C
John T. Owen. 86C
Garrett W. Thiessen. 258C
Reginald V. Williams. 243C
Officers. 239C
Position at frontiers of science and technology. *ed.* 135C
Publications
Journal on microfilm. 9C
Questionnaire to Journal readers. *ed.* 37C, *ed.* 115C
Symposia proceedings. *ed.* 95C
Section news
Boston. 100C, 119C, 220C, 258C
Chicago. 10C, 86C, 100C, 119C, 147C, 220C
Cleveland. 220C
Columbus. 278C, 295C
Detroit. 10C, 85C, 101C, 119C, 165C, 220C
Indianapolis. 86C, 119C, 147C, 241C
Midland. 23C, 119C, 165C, 222C
National Capital. 10C, 222C
New York Metropolitan. 165C, 221C
Niagara Falls. 222C
North Texas. 295C
Ontario-Quebec. 23C, 101C
Pacific Northwest. 24C, 119C, 166C, 241C
Philadelphia. 222C
Pittsburgh. 241C
San Francisco. 24C, 101C, 148C, 222C
South Texas. 86C, 119C, 278C
Southern California-Nevada. 258C
Electrocrystallization
At silver electrodes. 892
Electrode
Air. For fuel cells. 236
Battery. High-rate. 8
Bromine redox. Porous. 709
Calomel potential. Thermal temperature coefficient. 578
Chlorine. High current density. Impurity effects. 812
Chlorine-chloride ion. Standard potential. 340
Covered by electrolyte film. 138
Flooded porous. For fuel cells. d. 648
Fuel cell
Porous. 658
Porous carbon. From polymer precursors. 582
Porous gas-diffusion. 927
Gallium arsenide
Behavior. 472
Hydrogen evolution. 1274
Gas. Electrolyte films. Optical studies. d. 651
Gas-diffusion. Method of operation. 927
Gold. Potential of zero charge. 72
Hydrogen. Reaction. Pressure coefficients. d. 651
Hydrogen absorption. 909, d. 916, d. 1271
Impervious. Polarization. 709
Iridium. Oxygen evolution. 592
Kinetic data. By use of nonlinear circuits. 1129
Manganese dioxide. Discharge process. 415
Mercury. Potential of zero charge. 72
Metal membrane. 595
Nickel. Sintered. 418
Nickel hydroxide. Infrared spectroscopy. 215
Noble metal. Oxygen reduction. 1036
Planar. Potentiostatic current-time curves. 1256
Platinum
Area changes. 1261
Electrochemical activation. 1113
Potential measurements in closed system. 343
Propane adsorption. Kinetics. 764
Porous
For batteries. 8
Gas-diffusion. Operation. 927
Measurements. 658
Reactions. Consecutive. 682
Rotating disk
Analysis of oxygen reduction. 466
Diffusion layer. 239
Studied by laser interferometry. 710
Silver
Electrocrystallization. 892
Potential of zero charge. 72
Sintered. Couligravimetric study. 113
Silver oxide. Processes. 1196
Steel. Hydrogen evolution. d.648
Teflon. Porous. In hydrocarbon fuel cells. 17, d. 1265, 233
See also Anode. Cathode
Electrodeposition
Copper. Effects of surface roughness. 54, d. 1267
Molybdenum
From chloride melt. 556
From fluoride melt. 586
Problems. d. 1263
Refractory metals. Coherent deposits. 556, 586
Technetium from aqueous solution. 128
Tungsten from fluoride melt. 586
Electrograph method. For location of pinholes in silicon dioxide films. 643
Electroluminescence
Zinc sulfide films containing lead. 725
Zinc sulfide films containing manganese. Effect of silicon oxide layers. 1066
Electrolysis
See Pre-electrolysis
Electrolyte
Caustic. Pre-electrolysis. Impurity effects. 1104
Fuel cell. Low-temperature. 1200
Fused acetamide. For thermal cells. 212
Fused organic. For thermal cells. 209
Hydrogen absorption. 909, d.916
Hydrogen fluoride-dinitrogen tetroxide. For low-temperature battery system. 655
Low-temperature operation. Limitations. 1033
Nitrosyl fluoride. 940
Nonaqueous. Effect of water. 823
Organic. Behavior of lead. 665
Phosphoric acid. 17, d.1265
Potassium hydroxide. Conductivity. 1045
Potassium hydroxide-lead oxide. Conductivity. 1045
Sea-water battery. 299
Solid. Mixed conduction. 752
Thermal cells
Fused acetamide. 212
Fused organic. 209
Electrolytic capacitors. Charge-discharge mechanisms. d. 648
Electrolytic dissolution
Copper-gold alloys. 698
Copper-zinc alloys. 698
Electrolytic oxidation
Anilines in acetonitrile. 1025
Electrolytic reduction
Acrylonitrile to allylamine. 1255
Electrolytic reductive coupling
Diethyl maleate. 1023
Electron beam zone melting. For recrystallization of germanium films. 406
Electron diffraction. Studies of iron oxide films. 994
Electron transfer. Photoinduced. In tetracyanoethylene solutions. 1054
Electronic materials. In U.S.A. and U.S.S.R. *ed.* 253C
Electronic paramagnetic resonance. Study of manganese ion during apatite formation. 370
Electronic switching. Between potentiostatic and galvanostatic control. 359
Electrooxidation
Acetylene on gold. 572
Formaldehyde by perrhenate. 773
Methanol by perrhenate. 773
Electrophoretic deposition. Penetration into cylindrical tubes. 445
Ellipsometry. In study of thermal regeneration of iron oxide films. 796
Ellipsometric-potentiostatic studies. Of iron passivity. 43, d. 1265
Emission spectra
Of impurity-activated zinc and cadmium sulfides, selenides and tellurides. 83
Energy transfer. Interactions between rare earth ions. 1048
Epitaxial deposition
Gallium arsenide in argon. 410
Gallium arsenide on gallium arsenide. 879
Epitaxial films
Gallium arsenide on germanium. 292
Gallium arsenide. Tin- and tellurium-doped. 110
Germanium. Growth mechanism. 102
Epitaxial growth
Formation of large area silicon junctions. 522
Germanium on single crystal spinel. 749
Silicon. Behavior of surface perturbations. 1154
Equilibrium pressure
Oxygen over lead oxides. d. 647
Etching
Gas phase. Sapphire with sulfur fluorides. 204
Germanium
By hydrogen peroxide. 88
By nitric acid-hydrofluoric acid-acetic acid. 970
In hydrogen fluoride-hydrogen peroxide-water system. 285
Metallic. Of indium antimonide and germanium. 635

Permanganate in study of indium antimonide impurity distribution. 298
Sapphire. With sulfur fluorides. 204
Silicon
By nitric acid-hydrofluoric acid-acetic acid system. 970
By water-amine-complexing agent system. 965
In hydrogen fluoride. 414
Vacuum thermal. Of germanium and silicon. 398
Ethylene diamine. Reduction of hydrocarbons in. cor. 1119
Europium
Activating agent for garnet phosphors. 250
Activating agent for indium orthoborate. 613
Europium vanadate. *See* Yttrium europium vanadate
Extraction
Intermetallic compounds from metallic matrices. 634
Ferric oxide
Films
Active, passive and transpassive. 994
Anodic deposition
On iron. 674
On platinum. 678
Electron diffraction studies. 994
Thermal regeneration. 796
Whiskers on iron. Morphology. 1227
Ferrite
See Cobalt ferrite
Film
Active. 994
Aluminum oxide. From aluminum alkoxides. 948
Amorphous. Silicon nitride. 717
Anodic
Effect on tantalum oxidation. 1222
Ellipsometric-potentiometric studies. 43
Cadmium mercury telluride. Deposition by cathodic sputtering. 616
Deformation. 882
Dielectric. Anodization. 603
Electrolyte. On gas electrodes. d. 651
Ferric oxide. Electron diffraction studies. 994
Germanium
Vacuum-deposited. 158
Vapor-deposited. 102
Gold. Ion-plated. 889
Langmuir. Electrical and structural properties. d. 646
Molybdenum. In masking of dielectric films. 730
Passivating. On iron-chromium alloys. 542
Passive. 994
Deformation. 882
Protective. By acetylenic corrosion inhibitors. 1209
Silicon dioxide
On silicon. Cationic migration. 624
Penetration by fused glass. 620
Silicon nitride
By reactive sputtering. 826
Conversion to silicon dioxide. 603
Deposition by silane-hydrazine process. 962
Preparation and properties. 717
Vapor deposition from silane-ammonia-hydrogen system. 733
Transpassive. 994
Zinc sulfide
Evaporated. Effect of insulating layers on electroluminescence. 1066
Lead-containing. Electroluminescence. 725
See also Epitaxial film. Oxide film. Thin film
Film growth
Aluminum oxide on aluminum alloys. 354
Anodic. Ellipsometric-potentiostatic studies. 43, d. 1265
Fluorescence
Europium-activated garnets. 250
Europium-activated mixed metal oxides. 875
Europium in yttrates and gadolinates. 252
Rhodium-activated aluminum oxide. 1396
Fluorescent spectra
Ytterbium in cadmium fluoride. 609
Fluoride
Retention by silicon and silicon dioxide. 867
See also Cadmium fluoride. Hydrogen fluoride. Nitrosyl fluoride. Oxygen difluoride. Sodium aluminum fluoride. Sulfur fluorides
Fluorine
Reaction with beryllium. Kinetics. 1206
Reaction with iron. Kinetics. 218
Formaldehyde
Electrooxidation by perrhenate. 773
Free energy of formation
Cupric oxide. 30
Palladium oxide. 68
Frozen drop method. For evaluation of silicon and trichlorosilane. 1307
Frozen menisci. In determination of surface tension. 225, d. 1269
Fuel cell
Air electrode. 236
Anodes
Platinum. Hydrogen oxidation on. 531
Movable, partially submerged. 531
Electrodes
Flooded. Porous. d. 650
Porous. Measurements. 658
Porous carbon. From polymer precursors. 582
Electrolytes. Low-temperature. 1200
Hydrogen. Anodes studied by multipulse potentiodynamic method. 17, d. 1265, 233
Performance as function of catalyst area. 144

Gallium-arsenic-copper system
Phase diagram. 516
Gallium-arsenic-gold system
Phase diagram. 516
Gallium-arsenic-silver system
Phase diagram. 516
Gallium-arsenic-tellurium system
Phase diagram. 91
Gallium arsenide
Defects induced by zinc diffusion. 188
Electrode
Behavior. 472
Single crystal. Hydrogen evolution. 1274
Epitaxial deposition in argon. 410
Epitaxial film
On gallium arsenide. 879
On germanium. X-ray topography. 292
Tin- and tellurium-doped. 110
Inhomogeneities studied by electron beam excitation. 149, 153
Ohmic contacts by alloying. 408
Precipitates induced by zinc diffusion. 188
Quantum efficiency. 149
Spontaneous emission spectral shape. 149
Substrate
For epitaxial deposition of gallium arsenide. 879
For silicon nitride. 1192
Zinc-diffused. 181, 188, 1292
See also Gallium phosphide-gallium arsenide system
Gallium-indium-arsenic alloys. Epitaxial. 164
Gallium oxide
See Magnesium oxide-aluminum oxide-gallium oxide system
Gallium phosphide
Crystals. Large, solution-grown. 1303
Epitaxial. Preparation and properties. 192
Gallium phosphide-gallium arsenide system
Thermal expansion coefficients. 640
Gallium-phosphorus-tellurium system
Phase diagram. 1161
Galvanostalametry. Technique for chemical analysis. 461
Garnet
Europium-activated phosphor. 250
Gas
See Degassing. Solid-gas system
Germanium
Epitaxial growth on spinel. 749
Etching
By hydrogen peroxide. 88
By nitric acid-hydrofluoric acid-acetic acid. 970
In hydrogen fluoride-hydrogen peroxide-water system. 285
Metallic. 635
Vacuum thermal. 398
Oxidation in nitric acid. 176
Substrate for epitaxial gallium arsenide. 292
Surface potential controlled by variable pH electrolyte. 743
Thin films recrystallized by electron beam zone melting. 406
Vacuum-deposited films. Textural and electrical properties. 158
Vapor deposition. Growth mechanism. 102
Glass
Fused. Penetration into silicon dioxide. 620
Membrane. Potentials in mixed anion melts. 1257
Gold
Diffusion into silicon. Precipitate formation. 1287
Dopant for metal-oxide-silicon structures. 1165
Electrode
Electrooxidation of acetylene. 572
Potential of ze. charge. 72
Films. Ion-plated. 889
Ion-plated. Adherence and porosity. 889
See also Copper-gold alloy. Gallium-arsenic-gold system. Silver-gold alloy
Growth
See Crystal growth. Czochralski growth. Epitaxial growth. Film growth. Oxide growth. Thermal growth. Vapor growth
Growth mechanism
Vapor-deposited germanium films. 102
Growth rate. Microscopic. In single crystals. 413

Hafnium carbide.
Oxidation. High-temperature. 1030
Halide
See Bromide. Benzyl halide. Chloride. Fluoride
Halophosphate
See Calcium halophosphate
Heat treatment
Anodic oxide films on tantalum. Effect of chemical, thinning. 723
Heterogeneities
In indium antimonide studied by permanganate etching. 298
See also Inhomogeneities
Hydrazine
See Silane-hydrazine process
Hydride
See Silane. Trichlorosilane
Hydrocarbon
Aromatic. Electrochemical reduction. d. 1119
Fuel cell. Anode studies. 17, d. 1265, 233
Saturated
Anodic oxidation. Electrocatalysts. 980
Behavior in fuel cells. 17, d. 1265
Hydrodimerization
Acrylonitrile. 899
Diethyl maleate. 1023
Hydrogen
Absorption
By electrode and electrolyte. d. 648
By nickel and iron-nickel alloys. 568
Electrode reaction. Pressure coefficients. d. 651
Electrolytic
Absorption by nickel. 568
Permeation through platinum. d. 650
Evolution
At mild steel electrode. d. 648
On gallium arsenide electrodes. 1274
Generation and consumption in sealed batteries. 301
Oxidation on platinum fuel cell anodes. 531
Permeation through platinum. d. 650
Solubility and diffusion in strong electrolytes. 301
Transport to cylindrical anodes. 349
Hydrogen fluoride
Radioactive tracer to measure fluoride retention by silicon. 867
Hydrogen fluoride-dinitrogen tetroxide
Electrolyte for low-temperature battery. 655
Hydrogen fluoride-hydrogen peroxide-water system. For chemical etching of germanium. 285
Hydrogen isotopes
In study of anodic evolution of oxygen. 922
Hydrogen peroxide
Etching agent for germanium. 88
Oxygen reduction at platinum. 466, 1107
See also Hydrogen fluoride-hydrogen peroxide-water system
Hydroxide
See Nickel hydroxide. Potassium hydroxide

Impurity
Distribution in single crystals. 738
Effects
In chlorine electrodes. 812
In pre-electrolysis of caustic electrolytes. 1104

Heterogeneities in rotated single crystals. 738
Redistribution in semiconductor. 1297
Indium
Electrochemical kinetics. d. 1263
See also Gallium-indium-arsenic alloy
Indium antimonide
Heterogeneities studied by permanganate etching. 298
Impurity heterogeneities. 738
Metallic etching. 635
Indium arsenide
Epitaxial. On indium arsenide substrates. 1078
Solubility and diffusion of copper in. 856
Substrate for epitaxial indium arsenide. 1078
Indium orthoborate
Europium-activated. Cathodoluminescence. 613
Terbium-activated. Cathodoluminescence. 613, d. 652
Indium telluride
See Silver indium telluride. Silver telluride-indium telluride system
Infrared spectroscopy
Charged nickel hydroxide electrodes. 215
Infrared spectrum
Protective films formed by acetylenic corrosion inhibitors. 1209
Silicon nitride on gallium arsenide. 1192
Inhomogeneities
Gallium arsenide. Studied by electron beam excitation. 149, 153
Silicon crystals. Resistivity. 255
See also Heterogeneities
Insulating layers
Double. Silicon oxide. 1066
Effect on electroluminescence of zinc sulfide films. 1066
Interface
Silicon-silicon dioxide. 629
Zinc selenide-electrolyte. 1173
Interferometry
Laser. In sudy of rotating disk electrode. 710
Iodine
Source for vapor transport studies. 635
Ion deposition
Gold films. 889
Ionic migration
See Cationic migration
Iridium
Electrodes. Oxygen evolution. 592
Iron
Anodic oxidation. 674
Anodic oxide film growth. Measurement. 585
Anodic passivation. Effects of permanganate ion. 39
Armco. Corrosion inhibition. 1006, 1012
Corrosion inhibition by aniline. 1006, 1012
In sulfuric acid. Effect of aniline. 1006, 1012
Oxidation. Effects of crystal orientation and oxygen pressure. 32
Passivation
Anodic film growth. 43, d. 1265
Ellipsometric-potentiostatic studies. 43, d. 1265
Reaction
With fluorine. Kinetics. 218
With nitrogen. Effect of oxygen. 59
Substrate
For iron oxide whiskers. 1227
For titanium carbide. 1230
See also Ferric . . . Steel
Iron-chromium alloy
Anodic polarization. Kinetics. 682
Carburization. 435
Dissolution. Kinetics. 682
Oxidation
High-temperature. 788
In dry carbon dioxide. 435
Passivity. Primary and secondary film formation. 542
Iron-nickel alloy
Absorption of electrolytic hydrogen. 568

Junction
Silicon large-area. By epitaxial growth. 522
Silicon p-n. 277

Kolbe electrosynthesis
Of polydifluoromethylene. 1042

LEZOR. *See* Liquid encapsulating zone refining
Laser
Interferometry. In study of rotating disk electrode. 710
Lead
Behavior in organic electrolytes. 655
Lead alloy
Liquid. Interaction with zinc. 800
Lead-antimony alloy
Corrosion in battery grids. 1
Lead chloride
Electrode in organic electrolyte. 665
Lead oxides
Oxygen equilibrium pressures over. d. 647
Lead selenotelluride
Compositional variations shown by chemical polishing. 632
Lead sulfoselenide
Vacuum-deposited thin films. 708
Lead telluride-antimony telluride system
Phase relations and thermoelectric properties. 526
Liquid encapsulating zone refining. 976
Lithium carbonate-sodium carbonate
Molten. Electrochemistry. 457
Luminescence
Bismuth in rare earth oxides. 1137
Magnesium oxide-aluminum oxide-gallium oxide system. 245
Manganese-activated phosphors. 245
Quantum efficiency of silicon carbide. 848
Rare earth phosphovanadates. 367
See also Cathodoluminescence. Electroluminescence
Lumped parameter electrical model. For predicting concentration transients. 917

MPP. *See* Multipulse potentiodynamic method
Magnesium aluminate. *See* Spinel
Magnesium oxide-aluminum oxide-gallium oxide system
Manganese-activated phosphors. 245
Manganese
Activator for phosphors in magnesium oxide-aluminum oxide-gallium oxide system. 245
Chemistry during fluorapatite formation. 370
Manganese dioxide
Electrode. Discharge process. 415
Thin films. Preparation. 944
Manganese fluorapatite
Chemistry during formation studied by EPR. 370
Manganese-oxygen
Phase diagram at high temperature. 314
Masking
Method for etching dielectric films using molybdenum. 730
Mass transport
Hydrogen to cylindrical anodes. 349
Materials engineering
In western and eastern countries. ed. 253C
Membrane
Glass. Potentials. 1257
Metal. Electrodes. 595
Mercurous chloride
Electrode. Potential. Thermal temperature coefficient. 578
Mercury
Electrode. Potential of zero charge. 72
Mercury telluride
See Cadmium mercury telluride
Metal-oxide semiconductor
Capacitance method for investigation of silicon-silicon dioxide interfaces. 629
Metal-oxide-silicon structure
Gold-doped. Properties. 1165
Metallurgy
Role in electrochemistry. 159C
Metals
Oxidation, Review. 139C
See also Refractory metals
Methanol
Adsorption on platinum electrode. 904, cor. 1221
Anodic current-potential characteristics. 1251
Catalytic decomposition on palladium. 1251
Electrooxidation by perrhenate. 773
Oxidation on platinum electrode. 904, cor. 1221
n-Methylacetamide
Solvent for potassium nitrate in anodic oxidation of silicon. 629
Molybdate
See Calcium molybdate
Molybdenum
Chemical vapor deposition on silicon. 201
Electrodeposition
From chloride melt. 556
From fluoride melts. 586
Film used for masking silicon nitride. 730
Reaction with oxygen at high temperature. Kinetics. 305
Molybdophosphate
See Sodium molybdophosphate
Multipulse potentiodynamic method
In studies of hydrocarbon fuel cell anodes. 17, d. 1265, 233

Neutron activation
In study of sodium in silicon dioxide. 862
Nickel
Absorption of electrolytic hydrogen. 568
Anodic dissolution. 821
Corrosion resistance in oxygen difluoride. 706
Electrode. Nickel hydroxide structure. 418
Electrodeposited
Annealing behavior. 449
Anodic dissolution. 821
Electroless. Differential thermal analysis and X-ray studies. 442
Oxidation by carbon dioxide. 1215
Oxide scales. Substructures. 535
Plating brighteners
N-allylquinaldinium bromide. 50
With radioactive tracers. 50
See also Iron-nickel alloy
Nickel-cobalt alloy
Oxide scales. Substructures. 535
Nickel hydroxide
Electrode. Infrared spectroscopy. 215
Structure and stoichiometry in electrodes. 418
Nickel oxide
Thermodynamic and transport properties. 1179
Niobate
See Rare earth niobates
Niobium
See Oxygen-niobium system
Niobium alloy
Anodic oxidation. 145
See also Zirconium-niobium alloy
Nitrate
See Potassium nitrate. Sodium nitrate
Nitride
See Silicon nitride
Nitrite
See Sodium nitrite
N-p-nitrobenzylaniline
Electrochemical reduction. 588
Nitrogen
Reaction with iron. Effect of oxygen. 59
Nitrogen-15
Tracer in solids. Detection by nuclear activation. 1100
Nitrosyl fluoride
Electrolytes. 940
Nitrous oxide
Oxidation of cobalt ferrite. 482
Process for vapor deposition of silicon dioxide film. 274
Nomenclature. Scientific. ed. 21C
Nonlinear circuit
In acquisition of electrode kinetic data. 1129
Nucleation
Of crystals in gels. 263

Ohmic contact
Gallium arsenide by alloying. 408
Organic compounds
See Acetamide. Acetylene. Acrylonitrile. Adiponitrile. N-allylquinaldinium bromide. Aluminum alkoxide. Amines. Aniline. Benzyl halides. Butyrolactone. Cyanoalkyldimethylsulfonium ions. Diethyl maleate. Dimethylformamide. Electrolyte, Fused organic. Ethylene diamine. Formaldehyde. Hydrazine. Methanol. n-Methylacetamide. N-p-nitrobenzylaniline. Polydifluoromethylene. Polyvinylidene chloride. Propane. Propylene carbonate. Tetracyanoethylene
Orthoborate
Activated by europium and terbium. Cathodoluminescence. 613
Overpotential
Variation with time for galvanostatic charging. 810
Oxidation
Aluminum alloys in air. 354

Copper
In carbon dioxide. 685
Single crystal. Rate. 669
Copper-gold alloys in carbon dioxide. 685
Germanium in nitric acid. 176
Hafnium carbide. High-temperature. 1030
Hydrogen. On platinum fuel cell anodes. 531
Iron. Effects of crystal orientation. 32
Iron-chromium alloys. High-temperature. 788
Metals. Review. 139C
Methanol on platinum electrode. 904, cor. 1221
Nickel by carbon dioxide. 1215
Platinum. Kinetics. 547
Plutonium. Kinetics. 23
Plutonium-aluminum alloy. Kinetics. 23
Propane. Carbon dioxide determination. 360
Tantalum
Gaseous. Effect of anodic films. 1222
High-temperature. Rate control. 428
Thin films. Kinetics. 669
Zirconium
In dry oxygen. 237
Low-pressure. 1086
Zirconium carbide. High-temperature. 1030
Zirconium-niobium alloy. Kinetics. 1089
See also Anodic oxidation. Electrooxidation. Thermal oxidation

Oxide
See Aluminum oxide. Anodic oxide. Carbon dioxide. Cupric oxide. Cuprous oxide. Dinitrogen tetroxide. Ferric oxide. Gallium oxide. Hydrogen peroxide. Lead oxides. Magnesium oxide. Manganese dioxide. Nickel oxide. Nitrous oxide. Palladium oxide. Rare earth oxides. Rhenium heptoxide. Silicon dioxide. Silver oxide. Tantalum pentoxide. Thallium yttrium oxide. Titanium dioxide. Vanadium pentoxide. Zinc oxide. Zirconium calcium oxide. Zirconium dioxide

Oxide film
Anodic
On iron. Growth measurement. 585
On tantalum
Dielectric properties. 723
Gas phase. 1134
Heat-treatment. 723
On zirconium
Incorporation of ions. 508
Permeation by potassium nitrate. 599, cor. 772
On iron. Thermal regeneration. 788
Metals and semiconductors. Thermal growth. 167

Oxide growth
Irradiated zirconium and Zircaloy-2. 124

Oxide scale
On nickel, cobalt, and nickel-cobalt alloys. Substructures. 535

Oxygen
Anodic evolution. Isotope effects. 922
Cathodic reduction
On noble metals and alloys. 1036
On rotating platinum. 1043
Electrolytic generator. Air-depolarized. 589
Equilibrium pressures over lead oxides. d. 647
Evolution at iridium electrodes. 592
Pressure. Effect on iron oxidation. 32
Reduction. Role of hydrogen peroxide. 466, 1107

Oxygen difluoride
Corrosion resistance of platinum, copper, nickel, and tantalum in. 706

Oxygen-niobium system
Absorption, adsorption and degassing. 452

Palladium
See Silver-palladium alloy

Palladium oxide
Free energy of formation. 68

Passivation
Aluminum by chromate solutions. 1001
Anodic. Of iron. 39
Iron
Anodic film growth. 43
Ellipsometric-potentiostatic studies. 43
Iron-chromium alloys. Primary and secondary film formation. 542

Permanganate
Etchant to study indium antimonide impurity distribution. 298
Ion. Effect on anodic passivation of iron. 39

Phase diagram
Gallium-arsenic-copper system. 516
Gallium-arsenic-gold system. 516
Gallium-arsenic-silver system. 516
Gallium-arsenic-tellurium system. 91
Gallium-phosphorus-tellurium system. 1161
Manganese-oxygen at high temperature. 314
Silver telluride-indium telluride system. 759

Phase equilibria
Cadmium-selenium system. 394
Zinc-tellurium system. 1281

Phase relations
Lead telluride-antimony telluride system. 526
Tin telluride-bismuth telluride system. 526

Phosphate
See Apatite. Halophosphate. Molybdophosphate

Phosphide
See Gallium phosphide

Phosphor
Aluminum oxide
Red-emitting. d. 647
Rhodium-activated. 1306
Calcium halophosphate. Analysis. 956
Europium-activated
Garnets. 250
Mixed metal oxides. 875
Garnets. Europium-activated. 250
Impurity-activated. 83
Magnesium oxide-aluminum oxide-gallium oxide system. Manganese-activated. 245
Manganese-activated. Luminescence. 245
Self-activated. 83
Yttrium vanadates. Bismuth-activated. 1057
Zinc cadmium selenide. Emission spectra. 83
Zinc cadmium sulfide. Emission spectra. 83
Zinc selenotelluride. Emission spectra. 83
Zinc sulfide. Emission spectra. 83
Zinc sulfoselenide. Emission spectra. 83

Phosphoric acid
Electrolyte in hydrocarbon fuel cells. 17
Etchant of silicon nitride. 869

Phosphorus
See Gallium-phosphorus-tellurium system

Phosphovanadate
See Rare earth phosphovanadates

Photoconductive properties
Cadmium selenide. Control. 390

Photovoltaic behavior
Tetracyanoethylene in tetrahydrofuran. 1054

Platinum
Anode
Fuel cell. Movable, partially submerged. 531
Hydrogen oxidation. 531
Catalysts. Activity. 1120
Cathode. Rotating. Oxygen reduction. 1043
Copper layers on. Formation and dissolution. 1125
Corrosion resistance in oxygen difluoride. 706
Deposit of ferric oxide films. 678
Electrocatalysts. For anodic oxidation. 980
Electrode
Area changes. 1261
Electrochemical activation. 1113
Hydrogen absorption. 909, d. 916, 1271
Potential measurements in closed system. 343
Propane adsorption. 764
Oxidation. Kinetics. 547
Permeation by electrolytic hydrogen. d. 650
Recrystallization. 241

Plutonium
Oxidation. Kinetics. 23

Plutonium-aluminum alloy
Oxidation. Kinetics. 23

Plutonium-cobalt-cerium alloy
Surface tensions determined from frozen menisci. 225, d. 1267

Polarization
Bromine redox electrodes. 709
Measurements on metal sheets and foils. Specimen holder. 818
See also Anodic polarization. Cathodic polarization. Direct current polarization technique

Polarography
Alternating current. Of aqueous cadmium. 239, 1130
See also Reduction, Polarographic

Polishing, Chemical
Cadmium sulfide. 295
Corundum with vanadium pentoxide. 356
To show compositional variations in lead selenotelluride. 632
See also Etching

Polydifluoromethylene
Kolbe electrosynthesis. 1042

Polymer
Precursor for porous carbon electrodes. 582

Polymerization
See Hydrodimerization

Polyvinylidene chloride
Precursor for porous carbon electrodes. 582

Porosity
Battery electrodes. 8
Ion-plated gold. 889

Potassium chloride-cadmium chloride system
Composition and equilibrium constant. 131

Potassium hydroxide
Electrolyte. Conductivity. 1045

Potassium hydroxide-zinc oxide
Electrolyte. Conductivity. 1045

Potassium nitrate
Molten. Reduction. Cathode processes. 64
Permeation of zirconium oxide films. 599, cor. 772

Potential
Absorption-induced electrode potential cells. 319
Aluminum in chloride solutions. 694
Calomel electrode. Thermal temperature coefficient. 578
Measurements on platinum electrode. 343
Standard. Of chlorine-chloride ion electrode. 340
Surface. Of germanium controlled by variable pH electrolyte. 743
See also Overpotential

Potential of zero charge
Of gold, silver, and mercury electrodes. 72

Potentiostatic current-time curves. For planar electrodes. 1256

Pre-electrolysis
Of caustic electrolytes. Impurity effects. 1104

Pressure
Coefficients of hydrogen electrode reaction. d. 651
Effects on electrical properties of boron. 805
See also Equilibrium pressure. Vapor pressure

Propane
Adsorption on platinum in hydrofluoric acid. 764
Galvanostatic oxidation. Carbon dioxide determination. 360

Propylene carbonate
Electrolyte. 13
Behavior of lead. 665

Radiofrequency glow discharge reaction
For production of silicon nitride films. 713

Radioactive tracers
Evaluation of hydrogen in silicon dioxide films. 196
Hydrogen fluoride etches. 867
Nickel plating brighteners. 50
Nitrogen-15. Detection by nuclear activation. 1100
Study of sodium in silicon dioxide films. 862

Rare earth niobates
Segregation coefficients in calcium molybdate. 102

Rare earth oxides
Bismuth-activated. 1137

Rare earth phosphovanadates
Structure and luminescence. 367

Rare earth tungstates
Energy transfer interactions. 1048

Reduction
Aromatic hydrocarbons in ethylene diamine. cor. 1119
Benzyl halides. 942
Cyanoalkyldimethylsulfonium ions. 1095
N-p-nitrobenzylaniline. 588
Oxygen on platinum. Role of hydrogen peroxide. 466, 1107
Polarographic. Of benzyl halides. 942
See also Cathodic reduction. Electrolytic reduction. Electrolytic reductive coupling.

Refractory metals
Electrodeposition of coherent deposits. 556, 586

Rhenium heptoxide
Catalyst for oxidation of formaldehyde and methanol. 773

Rhodium
Activator for aluminum oxide. 1306

Rutile
Defect structure. 172

Sapphire
Gas phase etching by sulfur fluorides. 204
Saran
Precursor for porous carbon electrodes. 582
Scale
Formation on iron-chromium alloy. 986
See also Oxide scale
Sea-water
Electrolytes. Conductivity. 299
Segregation coefficient
Of rare earth niobates in calcium molybdate. 108
Selenide
See Bismuth selenide. Cadmium selenide. Cadmium silicoselenide. Lead sulfoselenide. Zinc cadmium selenide. Zinc selenide. Zinc sulfoselenide.
Selenium
See Cadmium-selenium system
Selenotelluride
See Lead selenotelluride. Zinc selenotelluride
Semiconductor
Etching. Activation energies. 970
Impurity redistribution during thermal oxidation. 1297
Silane-hydrazine process
For deposition of silicon nitride. 733, 962
Silica
See Silicon dioxide
Silicate
See Zinc silicate
Silicide
See Tungsten silicide
Silicon
Anodic oxidation in potassium nitrate-n-methyl acetamide. 629
Crystals. Czochralski-grown. 959
Electronic grade. Evaluation. 1307
Epitaxial. Macroscopic defects. 872
Epitaxial growth. Behavior of surface perturbations. 1154
Epitaxial surface layers. Travelling solvent defects. 207
Etching
By nitric acid-hydrofluoric acid-acetic acid. 970
By water-amine-complexing agent system. 965
In hydrogen fluoride. 414
Through windows in silicon dioxide. 381
Evaluation by frozen drop method. 1307
Fluoride retention on surfaces. 867
Gold-diffused. Precipitate formation. 1287
Growth. 381
Inhomogeneities. Resistivity. 255
Junction transducer. 277, d. 1313
Junctions. Large-area. By epitaxial growth. 522
Resistivity inhomogeneities. 255
Substrate
For aluminum deposition. 605
For chemical vapor deposition of silicon. 201
For silicon dioxide films. 624
Surface defects on wafers. 207
Surface state charge. 266
Thermal oxidation
Surface state charge. 266
Transport processes. 820
Vacuum thermal etching. 398
Silicon arsenide
Crystals. Vapor-grown. 761
Silicon carbide
Boron-doped. Luminescence quantum efficiency. 848
Crystal growth. Influence of carbon transport. 1149
Luminescence quantum efficiency. 848
Nitrogen-doped. Luminescence quantum efficiency. 848
Polycrystalline. Vapor-deposited. 1158
Vapor-deposited. 1158
Silicon dioxide
Films
Deposition. Closed tube apparatus. 642
Location of pinholes by electrograph method. 643
On silicon. Cationic migration. 624
Sodium in. Studied by neutron activation and radiotracers. 862
Steam-grown. Tracer evaluation of hydrogen. 196
Thermally grown. Penetration by fused glass. 620
Vapor-deposited by nitrous oxide process. 274
Fluoride retention on surfaces. 867
Mask in etching of silicon nitride. 869
Silicon nitride
Etching by phosphoric acid. 869
Films
Amorphous. Preparation and properties. 713
By reactive sputtering. 826
Conversion to anodic silicon dioxide. 603
Deposition by silane-hydrazine process. 962
Masking by molybdenum film. 730
Thin. Preparation and properties. 713
Vapor-deposited. From silane-ammonia-hydrogen system. 733
On gallium arsenide. Infrared spectra. 1192
Production by radiofrequency glow discharge reaction. 713
Silicon-tungsten silicide-silicon
Epitaxial structure. 1189
Silicoselenide
See Cadmium silicoselenide
Silicosulfide
See Cadmium silicosulfide
Silver
Anodic oxidation. 1239
Diffusion coefficient in silver-gold alloys. 493
Electrode
Electrocrystallization. 892
Potential of zero charge. 72
Sintered. Couligravimetric study. 113
Polycrystalline. Double layer capacitance. 817
See also Gallium-arsenic-silver system
Silver-gold alloy
Diffusion of silver into. 493
Performance in caustic electrolyte. 1258
Silver indium telluride
Semiconducting properties. 759
Silver oxide
Electrode processes. 1196
Silver-palladium alloy
Anodic oxidation and performance in caustic electrolyte. 1239
Silver telluride-indium telluride system
Phase diagram. 759
Sodium
In silicon dioxide film. 862
Reactions with chlorine and bromine. 117
Sodium aluminum fluoride-aluminum oxide system
Anode effect repeatability. d. 652
Sodium carbonate
See Lithium carbonate-sodium carbonate
Sodium molybdophosphate
Corrosion inhibitor for stainless steel. 1015
Sodium nitrate
Molten. Reduction. Cathode processes. 64
Sodium nitrite
Molten. Reduction. Cathode processes. 64
Solvent properties. 937
Solid-gas system
Transient response. 478, 482
Solution
Tantalum in liquid tin. Kinetics. 689
See also Anodic dissolution. Electrolytic dissolution
Sorption
See Absorption. Adsorption
Specimen holder. For polarization measurements on metal sheets. 818
Spectra
See Absorption spectra. Emission spectra. Fluorescence spectra. Infrared spectroscopy. Infrared spectrum. Trapping spectrum
Spinel
Substrate for epitaxial growth of germanium. 749
See also Magnesium oxide-aluminum oxide-gallium oxide system
Sputtering
Cathodic
Deposition of cadmium mercury telluride. 616
Deposition of silicon nitride. 826
Deposition of tantalum and tantalum oxide. 505
Reactive. For preparation of manganese dioxide films. 944
Square-wave technique. For capacitance measurements. 593
Steel
Mild. Electrode. Hydrogen evolution. d. 648
Stainless. Corrosion inhibition. 1015
Stress
See Anisotropic stress effect
Stress corrosion cracking
Titanium alloys in salt solutions. 551
Sulfide
See Cadmium silicosulfide. Cadmium sulfide. Cadmium zinc sulfide. Uranium disulfide. Zinc cadmium sulfide. Zinc sulfide
Sulfoselenide
See Lead sulfoselenide. Zinc sulfoselenide
Sulfur fluorides
Polishing etchants for sapphire. 204
Surface
Perturbations. Effect on epitaxial growth of silicon. 1154
Roughness. Effect on electrodeposition of copper. 54, d. 1267
Surface state charge. Of thermally oxidized silicon. 266
Surface tension
Cobalt-cerium alloys. 225, d. 1269
Plutonium-cobalt-cerium alloys. 225, d. 1269
Synthesis
See Kolbe electrosynthesis

Tafel slope. Generalized expression. 1036
Tantalum
Anodic oxide films
Dielectric properties. 723
Heat-treatment. 723
Corrosion
Kinetics. 363, 495
Resistance in oxygen difluoride. 706
Deposition by cathodic sputtering. 505
Oxidation
Anodic. Gas phase. 1134
Gaseous. Effect of anodic films. 1222
High-temperature. Rate control. 428
Rotating disks. Solution rate. 689
Solution in liquid tin. Kinetics. 689
Tantalum pentoxide
Deposition by cathodic sputtering. 505
Films from gas phase oxidation of tantalum. 1134
Technetium
Electrodeposition from aqueous solution. 128
Telluride
See Antimony telluride. Bismuth telluride. Cadmium mercury telluride. Indium telluride. Lead telluride. Silver indium telluride. Silver telluride. Tin telluride. Zinc selenotelluride. Zinc telluride.
Tellurium
See Gallium-arsenic-tellurium system. Gallium-phosphorus-tellurium system. Zinc-tellurium system
Terbium
Activating agent for indium orthoborate. 613, d. 652
Terminology
See Nomenclature, Scientific
Tetracyanoethylene
In tetrahydrofuran. Photovoltaic behavior. 1054
Thallium yttrium oxide
Solid electrolyte. Mixed conduction. 752
Thermal cell
Fused acetamide. 212
Fused organic electrolytes. 209
Thermal expansion coefficient
In gallium phosphide-gallium arsenide system. 640
Thermal growth
Oxide films. Transport processes. 167
See also Thermal regeneration
Thermal oxidation
Semiconductors. Impurity redistribution. 1297
Silicon. Transport processes. 820
Thermal regeneration
Ferric oxide films by vacuum annealing. 796
Thermal temperature coefficient
Calomel electrode potential. 578
Thermodynamic interaction
Between zinc and antimony, bismuth and cadmium dissolved in liquid lead. 800
Thermodynamics
See Free energy of formation. Thermal temperature coefficient
Thermogalvanic cell
Under weightless conditions. 1243
Thin film
Germanium. Recrystallization by electron beam zone melting. 406
Lead sulfoselenide. Vacuum-deposited. 708

Manganese dioxide. Preparation. 944
Molybdenum on silicon. Vapor deposition. 201
Oxidation. Kinetics. 669
Silicon dioxide
Deposition apparatus. 642
Location of pinholes by electrograph. 643
Vapor-deposited by nitrous oxide process. 274
Silicon nitride. By radiofrequency glow discharge reaction. 713
Sodium. Chlorination and bromination. 117
Yttrium. Anodic oxidation. 75
Tin
Liquid. Tantalum dissolved in. Kinetics. 689
Molten alloys. Activities. 935
Tin telluride-bismuth telluride system
Phase relations and thermoelectric properties. 526
Titanium
Alloys. Stress corrosion cracking. 551
Deposition on columbium alloys. 1018
Titanium carbide
Vapor deposition on iron. 1230
Titanium dioxide
See Rutile
Topography. Reflection X-ray. Of gallium arsenide on germanium. 292
Torsion studies. Of zinc telluride. 1236
Transducer. Silicon p-n junction. Anisotropic stress effect. 277, d. 1313
Transfer
See Charge transfer. Electron transfer. Energy transfer
Transient response. In solid-gas systems. 478, 482
Transistor
Field-effect. Printable. 96
Transport
Processes
Thermal growth of oxide films. 167
Thermal oxidation of silicon. 820
See also Mass transport. Vapor transport
Trapping spectrum
Cadmium sulfide. Effect of optical radiations and water vapor. 511
Trichlorosilane
Evaluation by frozen drop method. 1307
Tungstate
See Rare earth tungstates
Tungsten
Electrodeposition from fluoride melts. 586
Reaction with oxygen at high temperature. Kinetics. 305
Vapor deposition from tungsten hexafluoride by hydrogen reduction. 561
Tungsten silicide
See Silicon-tungsten silicide-silicon

Ultrasonic agitation. Effect on solidification of bismuth telluride. 259
Uranium disulfide
Preparation and resistance. 973

Vacuum annealing
See Annealing, Vacuum
Vacuum deposition
Lead sulfoselenide thin films. 708
Vanadate
See Rare earth phosphovanadates. Yttrium europium vanadate. Yttrium orthovanadate
Vanadium pentoxide
Polishing agent for corundum. 356
Vapor deposition
Germanium. Low-temperature. 102
Molybdenum on silicon. 201
Silicon carbide. 1158
Silicon dioxide films by nitrous oxide. 274
Silicon nitride films from silane-ammonia-hydrogen system. 733
Titanium carbide on iron. 1230
Tungsten by hydrogen reduction of tungsten hexafluoride. 561
Vapor growth
Cadmium sulfide single crystals. Closed system. 851
Silicon arsenide crystals. 761
Vapor pressure
Zinc telluride by torsion measurements. 1236

Vapor transport
Iodine source for. 639

Water
Effect in nonaqueous electrolytes. 823
See also Sea-water
Weightless conditions. Electrochemical phenomena. 1234
Wettability. Measurements on high-energy surfaces. 877

X-ray
Fluorescence. Thickness determination of aluminum deposits. 605
Reflection topography of gallium arsenide on germanium. 292
Studies of electroless nickel. 442

Ytterbium
Optical spectra. In cadmium fluoride. 609
Yttrate
See Alkali yttrates. Alkaline earth yttrates
Yttrium
Thin films. Anodic oxidation. 75
Yttrium europium vanadate
Bismuth-activated. 1057
Yttrium orthovanadate
Bismuth-activated. 1057
Energy transfer and fluorescence. 953
Europium-activated. Energy transfer and fluorescence. 953
Yttrium oxide
See Thallium yttrium oxide

Zero charge
See Potential of zero charge

Zinc
Activity in liquid lead alloys. 800
Anodic dissolution in potassium nitrate. 885
Diffusion into gallium arsenide. 181, 297
Precipitates. 1292
Thermodynamic interaction with antimony, bismuth and cadmium in liquid lead. 800
See also Copper-zinc alloy
Zinc-cadmium selenide
Phosphor. Emission spectra. 83
Zinc-cadmium sulfide
Phosphor. Emission spectra. 83
Zinc oxide
Polycrystalline. As dielectric. 833
See also Potassium hydroxide-zinc oxide
Zinc selenide
Interface with electrolyte. 1173
Zinc selenotelluride
Ohmic contacts. 1063
Phosphor. Emission spectra. 83
Zinc silicate
Manganese-activated. Low-temperature synthesis. 378
Zinc sulfide
Hexagonal. Transformation to cubic. 1143
Lead-containing. Electroluminescence. 725
Manganese-containing. Electroluminescence. 1066
Phosphor. Emission spectra. 83
See also Cadmium zinc sulfide
Zinc sulfoselenide
Phosphor. Emission spectra. 83
Zinc telluride
Ohmic contacts. 1063
Vapor pressure measured by torsion methods. 1236
Zinc-tellurium system
Phase equilibria. 1281
Zircaloy-2
Corrosion enhancement from irradiation. 124
Zirconium
Anodic oxide films. Incorporation of ions. 508
Corrosion enhancement from irradiation. 124
Oxidation
In dry oxygen. 237
Low-pressure. 1086
Zirconium calcium oxide
Solid electrolyte. Mixed conduction. 752
Zirconium carbide
Oxidation. High-temperature. 1030
Zirconium dioxide
Anodic films. Permeation by potassium nitrate. 599, cor. 772
Zirconium-niobium alloy
Oxidation properties. 1089
Zone melting
See Electron beam zone melting
Zone refining
See Liquid encapsulation zone refining

National Meeting Subjects (Volume 114, 1967)

Acetone. Electrochemical coupling reaction. S, 75*C*
Acetylenic corrosion inhibitors. S, 74*C*
Alkaline bisulfates. Hydrogen and oxygen evolution, F, 194*C*
Alkyl carbonium ions. Formation. S, 66*C*
Alloy
Chromium-iron-nickel. Pitting. F, 201*C*
Chromium-nickel-titanium. F, 199*C*, 200*C*
Columbium-titanium. Silicided. F, 214*C*
Corrosion. Rotating disk electrode. F, 198*C*
Iron-chromium
Anodic dissolution. F, 201*C*
Pitting. F, 201*C*
Nickel-copper-aluminum. Passivity. F, 198*C*
Refractory. Fluidized bed coating. F, 215*C*
Silver-cadmium. Activity measurements. F, 214*C*
Super
Coating by vacuum pack process. F, 214*C*
Diffusion coatings. F, 214*C*
Dip coating. F, 214*C*
Pack cementation coating. F, 213*C*
Refractory. Metal diffused coatings. F, 213*C*
Titanium. Anodic behavior. F, 199*C*
Zirconium-niobium. Oxidation. F, 202*C*
Aluminum
Anodic Films. S, 57*C*
Anodization. Current decay. S, 57*C*
Chemical vapor deposited on steel. F, 215*C*
Coating process on steel. F, 215*C*
Electrodes
High surface gain. F, 205*C*
Relation between dielectric breakdown and edge structure. S, 59*C*
Foil
Etching. F, 205*C*
Oxidation at high temperature. F, 205*C*
Pitting. Effect of copper. S, 76*C*
Aluminum nitride. Epitaxial growth. S, 62*C*
Aluminum oxide
Anodic films. S, 57*C*
Anodic formation in phosphate solutions. S, 56*C*
Porous anodic. Current-voltage characteristics. S, 56*C*
Sulfuric-anodized. Infrared analysis. S, 58*C*
Aluminum phosphide. Solution in aluminum. F, 213*C*
Amalgam type chlorine cell. Economics. S, 69*C*
Amine
Anodic alkoxylation. S, 66*C*
Aromatic. Oxidation. S, 66*C*
Anode. For mercury cell. Design. S, 71*C*
Anodic alkoxylation of amines. S, 66*C*
Anodic coupling of organic anions. S, 67*C*
Anodic film
Aluminum
Effect of formation rate on structure. S, 57*C*
Growth, composition and vacuum-radiation stability. S, 57*C*
Cobalt, chromium and vanadium. S, 58*C*
Conduction. S, 55*C*
Electroluminescence. S, 55*C*
Electrolytic rectification. S, 55*C*
Heat-treated. S, 55*C*
Ionic conduction. S, 56*C*
Mobility of tantalum and oxygen ions in. S, 57*C*
Platinum. S, 74*C*
Tantalum. Activation energies of conduction. S, 58*C*

Titanium dioxide. S, 56C
Valve metals. Reanodization. S, 57C
Anodic oxidation
Cyanide ion. S, 66C
Formaldehyde. Galvanostatic studies. S, 65C
Anodic synthesis. Of cadmium sulfide. S, 58C
Anodization. Gas phase. Of tantalum. S, 58C
Antimony
Electrode kinetics. S, 76C
Liquid diffusion system. S, 63C
Aprotic solvents. Electrode reactions. S, 67C
Aryl iodonium ions. Electrochemical formation. S, 66C

Battery
Silver-cadmium. High rate charging. F, 198C
Silver-zinc. For spacecraft
Capacity. F, 198C
Heat generation. F, 198C
Load sharing. F, 198C
Battery oxides. Microscopic thin sectioning. F, 195C
Battery system. Nonaqueous. Thermodynamics. F, 193C
Bimetallic cell. Self-discharge. F, 195C
Bond. Ultrasonic and solder. S, 59C
Boron. Deposition on silicon. F, 212C
Boron carbide. Filaments. S, 77C
Boron nitride. Thin film. S, 62C
Boron trichloride. Diffusion system. S, 63C

Cadmium-air cell. Polarization. F, 197C
Cadmium sulfide
Film
Anodic synthesis. S, 58C
Deposition and structure. S, 54C
Thick. S, 54C
Calcium fluoride. Terbium-excited. S, 61C
Capacitor
Nonpolar electrolytic. S, 60C
Solid tantalum. Failure. S, 60C
Carbide-graphite composition. S, 77C
Carbide
Metal
Powders. S, 77C
Precipitated in alloy systems. S, 77C
Refractory. Submicron. S, 77C
Carbon. Diffusion in zirconium carbide. S, 77C
Carbon dioxide
Electrolysis using ceramic electrolytes. S, 72C
Reduced. Oxidation state. S, 74C
Carbon monoxide
Adsorption on tungsten. S. 73C
Oxidation on metals. S, 73C
Cathode
High energy density. F, 194C
Matrices in liquid ammonia cells. F, 194C
Mercuric oxide. Structure. S, 71C
Sulfur. In liquid ammonia electrolytes. S, 71C
Cathodic polarization. Of manganese dioxide electrode. S, 75C
Channel current. In silicon planar junction. S, 62C
Channel formation. In tantalum films. S, 54C
Charge compensation. Effects on optical spectra of terbium. S, 61C
Charge distribution. In MOS oxide. S, 58C
Chromic acid-sulfate baths. Electrolysis. F, 215C
Chromium. Anodic oxide films. S, 58C
Chromium carbide. Fiber reinforcing nichrome. S, 76C
Coating
By chemical vapor deposition. F, 215C
Continuous strip galvanized. F, 215C
Diffusion
In molten fluoride baths. F, 215C
Of super alloys. F, 214C
Dip. Of super alloys. F, 214C
Fluidized bed. Of refractory alloys. F, 215C
Fused silicide. For refractory metals. F, 214C
Metal-diffused. Of superrefractory alloys. F, 213C
Pack cementation. Of super alloys. F, 213C
Protective. By electrophoretic deposition. F, 215C
Slurry. Techniques. F, 215C
Super alloys. F, 214C
Vacuum pack processes. F, 214C
Cobalt. Anodic oxide films. S, 58C
Complex ions. Effects on solids. F, 199C
Conductance measurements. In aqueous and non-aqueous solutions. S, 69C
Conduction
Activation energies in tantalum anodic films. S, 58C
Anodic films. S, 55C
Asymmetric. In tantalum films. S, 55C
Dielectric liquids. F, 209C
Heat-treated anodic oxide films. S, 55C
Ionic. In anodic films on valve metals. S, 56C
Mechanism
In tantalum capacitors. S, 55C
In tantalum structures. S, 55C
Connections
Graphite to metal. S, 71C
Metal to graphite. S, 71C
Copper. Effect on aluminum pitting. S, 76C
Copper chloride. Cathode. Polarization. F, 193C
Copper fluoride-lithium system. Cell. F, 194C
Copper halide. Electrodes in propylene carbonate. F, 193C
Copper sulfide. On copper alloys. F, 204C
Crystal growth. Electron microscope study. F, 214C
Cuprous oxide
Mechanical properties. F, 202C
Single crystal growth. F, 213C
Current. Galvanic short-circuit. F, 199C
Current decay. In anodization of tantalum, aluminum and silicon. S, 57C
Current density distribution
In propagating stress corrosion crack. S, 69C
Influence of gas phase transport processes. S, 70C
Current distribution
In cylindrical geometries. S, 70C
In porous electrodes. S, 70C, 71C
In smeared transition zones. S, 70C
On rotating disk below limiting current. S, 70C
Cyanoalkyldimethylsulfonium ions. Electrochemical reduction. S, 67C

Dielectric behavior
Anodic films on valve metals. S, 56C
Silicon nitride films. S, 53C
Dielectric effects of electric fields. F, 209C
Dielectric film
Formation by sputtering. S, 54C
Growth phenomena. S, 54C
Structure and properties. S, 54C
Dielectric strength of silicon dioxide films. S, 59C
Dielectrophoresis. In study of cells. F, 210C
Diffusion
Boron trichloride. S, 63C
Gaseous. Into silicon. S, 63C
Liquid antimony. S, 63C
Phosphorus into silicon. S, 63C
Diffusion coefficient. Electrochemical determination. S, 76C
Dimethylformamide. As solvent for electrochemistry. S, 68C
Dimethlsulfoxide. Thermodynamic studies. S, 68C
Dimethylterephthalate. Ionization potential and electron affinity. F, 206C
Doping
Epitaxial. Density measurement. S, 63C
Semiconductor. By high energy ions. S, 63C

Electret
Applications. F, 208C
Behavior in alkali halides. F, 206C
Charge decay rates. F, 207C
Effect in ice. F, 206C
Foil. In microphones. F, 208C
Ice. Hydrogen fluoride-doped. F, 207C
Membrane. Heterocharges. F, 207C
Naphthalene. Glow peak analysis. F, 207C
Phenomenological theories. F, 206C
Polymer. Interfacial phenomena. F, 207C
Prosthetic materials. F, 208C
Surface charge
Effect of pressure. F, 208C
Measurement. F, 208C
Time-temperature superposition theory. F, 206C
Transmitter. For telephone set. F, 208C
Wax
Carnauba. F, 207C
Shellac. F, 208C
Electric contact
Contaminants in manufacturing. F, 203C
Degradation. In sulfur dioxide. F, 204C
Films
Dielectric breakdown. F, 203C
Force-resistance measurements. F, 203C
Photoelectric measurement. F, 202C
Resistance. In copper sulfide. F, 204C
Electrical double layer
At platinum electrodes. S, 75C
In nonaqueous solvents. S, 67C
Electrochemical cleavage. Of organo-aluminum compounds. S, 66C
Electrochemical coupling reaction. Of acetone to pinacol. S, 75C
Electrochemical organic reactions. Role of intermediates. S, 65C
Electrochemical oxidation
Alkyl and aryl iodides. S, 66C
Aromatic amines. S, 66C
Aromatic hydrocarbons. S, 65C
Crystalline aromatic hydrocarbons. S, 66C
Electrochemical power system. In nonaqueous solvents. S, 67C
Electrochemical reactions. Of methylene-cyclopropenes. S, 66C
Electrochemical reduction
Bis-activated olefins. S, 67C
Cyanoalkyldimethylsulfonium ions. S, 67C
Ketone to pinacol. S, 67C
Olefinic compounds. S, 67C
Oxygen. Hydrogen-deuterium substitution. S, 72C
Electrochemistry
Formamide. S, 68C
Lead in organic electrolytes. S, 68C
Nonaqueous solvents. S, 67C
Propylene carbonate. S, 68C
Pyridine. S, 67C
Electrode
Antimony. Kinetics. S, 76C
Auxiliary. For nickel-cadmium cells. F, 198C
Cadmium hydroxide. Electrochemical behavior. F, 198C
Calcium hydroxide. Charge acceptance. F, 198C
Copper. Oxidation in hydroxide. F, 199C
Hydrazine. S, 70C
Hydrogen
Effect of hydrogen absorption in coverage. S, 76C
Relation between hydrogen coverage and potential. S, 72C
Magnesium-lithium chloride, potassium chloride. F, 194C
Nickel hydroxide. Potential scan. F, 198C
Oxygen. In nonaqueous solvents. F, 193C
Pore resistance limiting. Computer study. F, 195C
Porous. Current distribution. S, 70C, 71C
Rotating ring disk. F, 198C, 199C
Valve. For use in fused salts. S, 71C
Electrode reactions. In aprotic solvents. S, 67C
Electrodeposition
Aluminum. F, 201C
Aspects of xerography. F, 209C
Early history. F, 209C
Lithium from nonaqueous electrolytes. S, 68C
Magnesium. F, 210C
State of the art. F, 209C
Electroluminescence. In anodic films. S, 55C
Electrolysis
Electrodeless. F, 210C
Sea-water. Magnesium hydroxide deposition. F, 210C
Electrolyte
Effect of water. F, 194C
Organic. F, 193C, 194C
Electrolytic capacitor
Aluminum. F. 206C
Aluminum foil. Alternating current properties. F, 204C
Electrolytes. DMF-based. F, 206C
Foil-type. Impedance. F, 204C
Paper and cellophane spacers. Conductivity. F, 204C
Tantalum
Effect of anode design. F, 205C
Equivalent series resistance. F, 204C
Electrolytic oxidation. For cleavage of tyrosyl-peptide bonds. S, 66C
Electrolytic rectification
Anodic oxide films. S, 56C
Mechanisms. S, 55C
Relation to proton space charge. S, 55C
Electromigration. In metal films. S, 59C
Electron beam radiation. Of silicon. S, 64C
Electron beam zone melting. Formation of germanium thin films. S, 53C
Electron
Motion in noncrystalline materials. S, 54C

Electrophoretic deposition
  Protective coatings on metals. F, 215C
  Theory. F, 209C
Electroprecipitation of gases. State of the art. F, 209C
Electrostatic forces. Field-induced. F, 210C
Electrostatic separation of minerals. F, 209C
Ellipsometry
  Dependence of refractive index on field strength. S, 57C
  Platinum oxidation. S, 57C
  Thin reaction product films. S, 74C
Energy transfer. Interaction between rare earth ions. S, 60C
Epitaxial deposition. Of silicon and germanium. S, 53C
Epitaxial doping density. Measurement. S, 63C
Epitaxial film
  Deposited in ultra-high vacuum. S, 64C
  Gallium arsenide. S, 64C
Epitaxial growth
  Aluminum nitride. S, 62C
  Gallium arsenide-phosphide alloys. S, 64C
  Germanium on spinel. S, 53C
  Silicon
    In ulra-high vacuum. S, 65C
    On sapphire. S, 65C
Epiaxial transistor
  Collector breakdown. S, 63C
  Secondary breakdown capability. S, 63C
Etching
  Gas phase. Of sapphire. F, 213C
  Vapor phase. Of semiconductors. S, 62C
Europium
  Dopant for rare earth vanadates. S, 60C
  Energy levels in luminescent systems. S, 61C
  Luminescence in indium orthoborate. S, 60C
  Mixed valence phosphors. S, 61C

Ferric oxide
  Blade-like platelets on iron. S, 75C
  Film deposition
    In sulfate solutions. F, 200C
    Optical study. F, 200C
  Whiskers on iron. S, 75C
Film
  Anodic oxide. Ductility. F, 201C
  Calcium stearate. Electric conduction. F, 207C
  Dielectric. S, 54C
    Tantalum oxide. S, 59C
  Evaporated. Residual stresses. F, 204C
  Insulating. F, 202C, 204C
  Metal
    Electromigration. S, 59C
    On quartz substrates. S, 58C
  Metal oxide. S, 55C
  Metallic interconnections. F, 204C
  Mylar. High-field conduction. F, 207C
  Oriented. S, 54C
  Oxide. Conduction properties. F, 203C
  Passive. Ductility. F, 201C
  Polycrystalline. S, 54C
  Teflon. High-field conduction. F, 207C
  Vapor-quenched. S, 53C
Formaldehyde. Anodic oxidation. S, 65C
Formamide. Electrochemistry. S, 68C
Fuel cells
  Finite contact angle meniscus. S, 76C
  Hydrogen-oxygen. S, 70C

Gallium arsenide
  Diodes. Spectrocharacteristics. S, 61C
  Epitaxial films. Deposited in ultra-high vacuum. S, 64C
  Heterojunction formation. S, 64C
  Ion-implanted. Properties. F, 212C
  Low-temperature vapor growth. S, 64C
  Thick film formation. F, 211C
Gallium arsenide-phosphide
  Epitaxial growth and properties. S, 64C
  Vapor growth and properties. S, 53C
Gas. Battery. Galvanic monitoring. F, 197C
Gas evolution. Technique for rate study. F, 197C
Gas phase transport processes. Influence on current density distribution. S, 70C
Germanium
  Epitaxial deposition on gallium arsenide. F, 216C
  Epitaxial growth
    On gallium arsenide. F, 210C
    On spinel. S, 53C
  Epitaxial layers on gallium arsenide. F, 210C
  Epitaxial surfaces. F, 211C
  Film deposition on sapphire. F, 211C
  Heteroepitaxial deposition. S, 53C
  Thin films formed on insulating substrates. S, 53C
Germanium-silicon. Heterojunctions. F, 213C
Germanium tetrachloride-hydrogen system. Growth rate and doping. S, 64C
Glass. Phosphosilicate. Deposition on silicon dioxide. F, 212C
Glass ceramics. Insulating material. F, 202C
Gold
  Contacts
    Lubrication. F, 203C
    Resistance and wear. F, 203C
  Electroplates. Porosity. F, 204C
Gold-aluminum system. Structures. S, 54C
Graphite. Lead-in rods. Contact resistance. S, 71C

Heterojunction formation. Gallium arsenide. S, 64C
Hydrazine. Electrode. S, 70C
Hydrocarbons
  Aromatic. Oxidation in methylene chloride. S, 65C
  Crystalline. Oxidation. S, 66C
Hydrogen
  Discharge on platinum. Diffusion control. S, 72C
  Effect of absorption on electrode coverage. S, 76C
  Electrode. Relation between hydrogen coverage and potential. S, 72C
Hydrogen peroxide. Stability in spacecraft control systems. S, 76C
Hypersonic vehicles. Environmental protection requirements. F, 214C

Impurity distribution
  Silicon. S, 63C
  Single crystals. S, 63C
Indium. Electrochemical behavior. F, 199C
Indium antimonide
  Crystal growth characteristics. S, 63C
  Diodes. Leakage current. S, 70C
  Photodiode. High-speed. S, 70C
Indium arsenide-gallium arsenide. Single crystal growth. S, 64C
Indium orthoborate. Europium-activated. S, 60C
Industrial electroorganic chemistry. S, 66C
Infrared analysis. Of anodic aluminum oxides. S, 58C
Infrared spectra. Of thin films formed by acetylenic corrosion inhibitors. S, 74C
Insulator. Contact electrification. F, 208C
Interface state analysis. By MOS conductance technique. S, 62C
Intermetallic compounds. Extraction from metallic matrices. S, 65C
Ionic mobility. Of tantalum and oxygen in anodic films. S, 57C
Ionic transport. In amorphous oxides. S, 55C
Iron
  Dissolution kinetics. F, 199C
  Oxidation rate. F, 200C
Iron-chromium alloy. Passivity. S, 74C

Ketone. Electroreduction to pinacol. S, 67C

Lanthanum silicate. Terbium-activated phosphors. S, 61C
Lead. Electrochemistry in organic electrolytes. S, 68C
Lead-acid battery. Reaction studied by radioactive techniques. F, 195C
Lead-calcium battery
  Accelerated life testing. F, 195C
  Pressure cast grids. Corrosion. F, 195C
Leakage current. Of indium antimonide diodes. S, 70C
Linear sweep voltammetry. Study of nickel oxide film formation. S, 75C
Liquids. Attraction by electric fields. F, 209C
Lithium
  Electrodeposition from nonaqueous electrolytes. S, 68C
  Wick electrode. S, 71C
Lithium-aluminum chloride. In propylene carbonate solution. F, 193C
Lithium-chlorine thermal batteries. F, 195C
Lithium-lithium perchlorate-dichloroisocyanuric acid system. For battery. F, 194C
Lithium-tellurium cell. Performance. F, 195C
Luminescence. Of europium in indium orthoborate. S, 60C

MOS conductance technique
  Interface state analysis. S, 62C
  Structure. Carrier mobilities in inversion layer. F, 212C
Magnesium hydroxide. Deposition in seawater electrolysis. F, 210C
Manganese dioxide. Electrode. S, 75C
Manganese oxides. Anodic oxidation. F, 197C
Mass spectrograph. For surface reaction studies. S, 74C
Membrane potentials. In amorphous oxides. S, 55C
Mercuric oxide. Cathode. Structure. S, 71C
Metal alkyls. Electrolytic production. S, 67C
Metal halides. Solubility in organic electrolytes. F, 193C
Metal oxide film. Preparation by sputtering. S, 55C
Metalliding reactions. F, 215C
Methylenecyclopropenes. Electrochemical reactions. S, 66C
Molecular orientation. In metal ion coordination sphere. S, 68C
Molten nitrates. Electrolysis. S, 71C
Molybdenum-gold system. Contact technology. S, 54C
Molybdenum-silicon nitride-metal structures. S, 58C
Mössbauer effect. Surface studies. F, 200C

Nichrome. Reinforced with chromium carbide. S, 76C
Nickel. Electrodeposited films. Stress. S, 59C
Nickel ferride. Electrodeposited films. F, 210C
Nickel oxides. Crystal field considerations. S, 75C
Nickel-oxygen interface. Surface potential measurements. S, 73C
Nitrogen. Diffusion in zirconium nitride. S, 77C
Nonaqueous electrolyte
  Batteries. Inorganic separators. S, 69C
  Lithium deposition. S, 68C
Nonaqueous solvent
  Electrical double layer. S, 67C
  Electrochemical power systems. S, 67C
  Electrochemistry. S, 67C
  Polarography in. S, 68C

Olefinic compounds. Reductive coupling. S, 67C
Olefins. Bis-activated. Electrolytic reductive coupling. S, 67C
Organic electrolytes. Electrochemistry of lead in. S, 68C
Organo-aluminum compounds. Electrochemical cleavage. S, 66C
Overpotential. Time variation during galvanostatic charging. S, 75C
Oxidation
  Phthalhydrazides. S, 66C
  Potential across oxide scale. F, 200C
Oxide
  Doped. As diffusion source. F, 211C
  Film
    Aluminum. Mechanical properties. F, 201C
    Cobalt and nickel. Solid solution effects. F, 202C
    Mild steel. Morphological change. F, 202C
Oxygen
  Cathodic reduction. S, 72C
  Electrode reactions. S, 72C
  Evolution on titanium dioxide. S, 56C
  Interaction with rhodium. S, 73C
  Reduction in nonaqueous solvents. F, 193C
  Transport through anodic tantalum oxide. S, 56C
Oxygen-peroxide system
  Dynamic behavior. S, 72C
  Static behavior. S, 72C

Palladium. Polymer formation on. F, 203C
Passivity. Of iron-chromium alloys. S, 74C
Phosphor
  Mixed valence europium. S, 61C
  Rare earth-activated. S, 60C
Phosphorus. Diffusion into silicon. S, 63C
Photoresist
  Adhesion performance related to surface constitution. F, 213C
  Removal method. F, 213C
Phthalhydrazides. Electrooxidation. S, 66C
Platinum
  Anodic oxide films. S, 74C
  Catalysts. Activity in solution. S, 73C
  Electrocatalysts. Influence of microcrystalline properties. S, 70C
  Electrode
    Potentiostatic current-potential. S, 72C
    Electrochemical activation. S, 73C

Oxidation studied by ellipsometry. S, 57C
Platinized. Structure and catalytic activity. S, 73C
Platinum alloy. Surface composition. S, 74C
Polarography. In ethylenediamine and acetic acid. S, 68C
Polycrystalline films. S, 54C
Polymer
Formation on palladium. F, 203C
System. Off-gassing. F, 203C
Polymethyleneimine. Effect on corrosion inhibition. F, 201C
Porosity. In zinc electrodes. S, 71C
Pre-electrolysis. Cause of electrolyte contamination. F, 195C
Propane. Oxidation with platinum catalyst. S, 70C
Propylene carbonate
Copper fluoride in. Solubility. F, 194C
Copper halide cathode in. Kinetics. F, 193C
Effect of water. F, 194C
Electrochemistry in. S, 68C
Lithium aluminum chloride in. Equilibria. F, 193C
Purification. F, 194C
Silver chloride in. Equilibria. F, 193C
Pyridine. Electrochemistry in. S, 67C

Rare earth vanadates. Europium-activated. S, 60C
Rare earths. Trace analysis methods. S, 61C
Refractive index. Dependence on field strength. S, 57C
Refractory metals. Gas reactions. F, 202C
Rhodium. Crystal surfaces. S, 73C

Semiconductor
Dislocations. F, 212C
Dissolution kinetics. Adsorption processes. F, 213C
Short-pulse techniques. S, 75C
Silicon
Anodization. Current decay. S, 57C
Electron beam irradiated. S, 64C
Epitaxial films. Surface reaction. S, 65C
Epitaxial growth on sapphire. S, 65C
Gaseous diffusion into. S, 63C
Gold-doped
Lifetime profile measurement. F, 212C
Surface characteristics. F, 212C
Growth from silicon tetrachloride. S, 53C
Heteroepitaxial deposition. S, 53C
Junction formation. S, 63C
Low-temperature epitaxial growth. S, 65C
Phosphorus diffusion into. S, 63C
Planar junction. Channel current. S, 62C
Polycrystalline
Deposition. F, 213C
Substrate for transistor pairs. S, 64C
Substrate. Radioactive tracer studies. F, 212C
Silicon dioxide
Effect of surface constitution on photoresist adherence. F, 213C
Films. Dielectric strength. S, 59C
Silicon nitride
Dielectric behavior of films. S, 53C
Films
Impurity-doped. F, 211C
Phosphorus-doped. F, 211C
Impurity redistribution after deposition. S, 62C
Silicon nitride-silicon dioxide films. S, 62C
Silicon oxynitride. Semiconductor surface protectant. S, 62C
Silver. Anode
Characterization in potassium hydroxide. F, 197C
Characterization by X-ray diffraction. F, 197C
Charging with varying current. F, 197C
Silver chloride. In propylene carbonate. F, 193C
Silver-zirconium interface. Internal oxidation. F, 204C
Sodium amalgam
Influence of ammonium salts. S, 69C
Reaction with sulfur dioxide. S, 69C
Sodium peroxide from. S, 69C
Sodium-bismuth cell. Performance. S, 69C
Sodium dithionate. Formation in nonaqueous media. S, 69C
Sodium perchlorate. Electrolytic production. S, 69C
Sodium trifluoromethanesulfonate. Conductance measurements. F, 193C
Sodium tungsten bronze. Electrode. F, 195C
Solvent
Organic. Sulfur-containing. Conductance. F, 193C
System. Influence on molecular orientation. S, 68C
Space charge. Injected by electrolyte. S, 56C
Spectroradiometer. Analog-computing. S, 61C
Steel
Aluminum coating process. F, 215C
Electrodeposition from chromic acid-sulfate bath. F, 215C
"Hinac" process. F, 216C
Stainless. Anodic polarization. F, 199C
Tin-free
Double-layered. F, 216C
Duplex coatings. F, 216C
Vapor-deposited aluminum on. F, 215C
Strain. In metal films on quartz plates. S, 58C
Stress
In electrodeposited nickel films. S, 59C
In evaporated thin films. S, 58C
Sulfur. Cathode. In liquid ammonia electrolytes. S, 71C
Surface reaction
Epitaxial silicon films. S, 65C
Products studied by mass spectroscopy. S, 74C

Tantalum
Activation energies of conduction. S, 58C
Anodic oxidation. Movement of atoms. S, 56C
Anodization. Current decay. S, 57C
Capacitors. Failure. S, 60C
Films. Asymmetric conduction. S, 55C
Galvanostatic anodization. F, 205C
Gas phase anodization. S, 58C
Low-density films. Channel formation. S, 54C
Mobility of ions in anodic films. S, 57C
Oxidation. Gold-induced break-away. S, 60C
Structures with tantalum pentoxide. S, 55C
Thin film capacitors. Conduction mechanism. S, 55C
Tantalum oxide
Anodic
Films. Flaws and flaw breakdown. S, 59C
Layers. S, 57C
Oxygen transport. S, 57C
Dependence of refractive index on field strength. S, 57C
Dielectric films. S, 59C
Field-induced growth. S, 60C
Phenomena at metal-oxide interface. F, 200C
Terbium
Dopant for lanthanum silicate phosphors. S, 61C
Optical spectra. Effects of charge compensation. S, 61C
Thermal oxidation. Using metered gases. F, 212C
Thick film
Cadmium sulfide. Vacuum-co-evaporated. S, 54C
Silicon. Low-temperature epitaxial growth. S, 65C
Thin film
Active devices. S, 54C
Analysis by X-ray emission. S, 73C
Anodic oxide
Effect of growth rate on stresses. F, 201C
Mechanical properties. F, 201C
Boron nitride. S, 62C
Electronic conduction mechanisms. S, 58C
Evaporated. Stress in. S, 58C
Failure. Study techniques. S, 59C
Germanium on insulating substrates. S, 53C
Growth effects. S, 53C
Nickel. Studied by linear sweep voltammetry. S, 75C
Reaction product. Studied by ellipsometry. S, 74C
Thin layer. Electrodeposited. Structure. S, 73C
Thiourea. Adsorption in mercury-indium-electrolyte interface. F, 200C
Tin. Whiskers and filamentary growths. S, 59C
Tinplate. Intermetallic layer. F, 216C
Titanium
Anodic behavior. F, 199C
Pitting corrosion in halide solutions. F, 201C
Titanium alloy. Polarization in sodium chloride solutions. F, 201C
Titanium carbide. Formation on iron. S, 77C
Titanium dioxide
Anodic films. Rectification. S, 56C
Semiconducting. Oxygen evolution. S, 56C
Transistor pairs. Dielectrically isolated. S, 64C
Tyrosyl-peptide bonds. Cleavage by electrolytic oxidation. S, 66C

Ultraviolet photons. Absorption by tungstates and vanadates. S, 60C

Valve metals. Anodic films
Ionic conduction and dielectric behavior. S, 56C
Reanodization. S, 57C
Vanadium. Anodic oxide films. S, 58C
Vanadium dioxide. Film preparation. S, 55C
Vapor growth. Of gallium arsenide-phosphide. S, 53C
Vapor quenching. In film formation. S, 53C

Wick electrode. Lithium. S, 71C
Wustite. Plastic behavior. F, 202C

X-ray diffraction. For identification of reaction products. S, 74C
X-ray emission analysis. Of surfaces. S, 73C

Yttrium oxide. Thin film capacitors. F, 205C
Yttrium vanadate. Europium-excited. S, 61C

Zinc
Anodic dissolution in potassium nitrate. F, 196C
Controlled current deposition. F, 196C
Dendrite deposition. F, 196C
Electrode
Anodic oxidation. F, 196C
Behavior in alkaline solutions. F, 196C
In nickel-zinc alkaline cells. F, 196C
Porosity. S, 71C
Surfactant additions. F, 197C
Zincate trapping kinetics. F, 197C
Passivated. Electrical behavior. F, 196C
Separator penetration. F, 197C
Zinc oxide
Film deposition and structure. S, 54C
Phosphors. S, 62C
Zinc oxide-potassium hydroxide. Electrolyte. F, 196C
Zinc selenide
Epitaxial deposition on germanium. F, 211C
Epitaxial films. High-purity. F, 211C
Zinc sulfide. Particle size and morphology. S, 61C
Zirconium
Anodic oxide films. Resistivity profile. F, 205C
Oxidation. Nonlattice diffusion. F, 200C
Zirconium carbide. Carbon diffusion. S, 77C
Zirconium nitride. Nitrogen diffusion. S, 77C